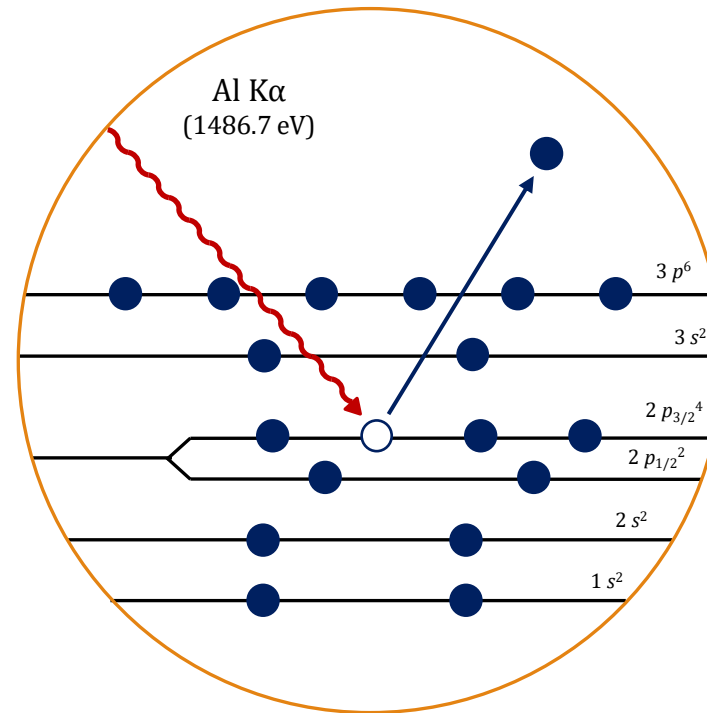


X-Ray Photoelectron Spectroscopy



XPS

X-Ray Photoelectron Spectroscopy

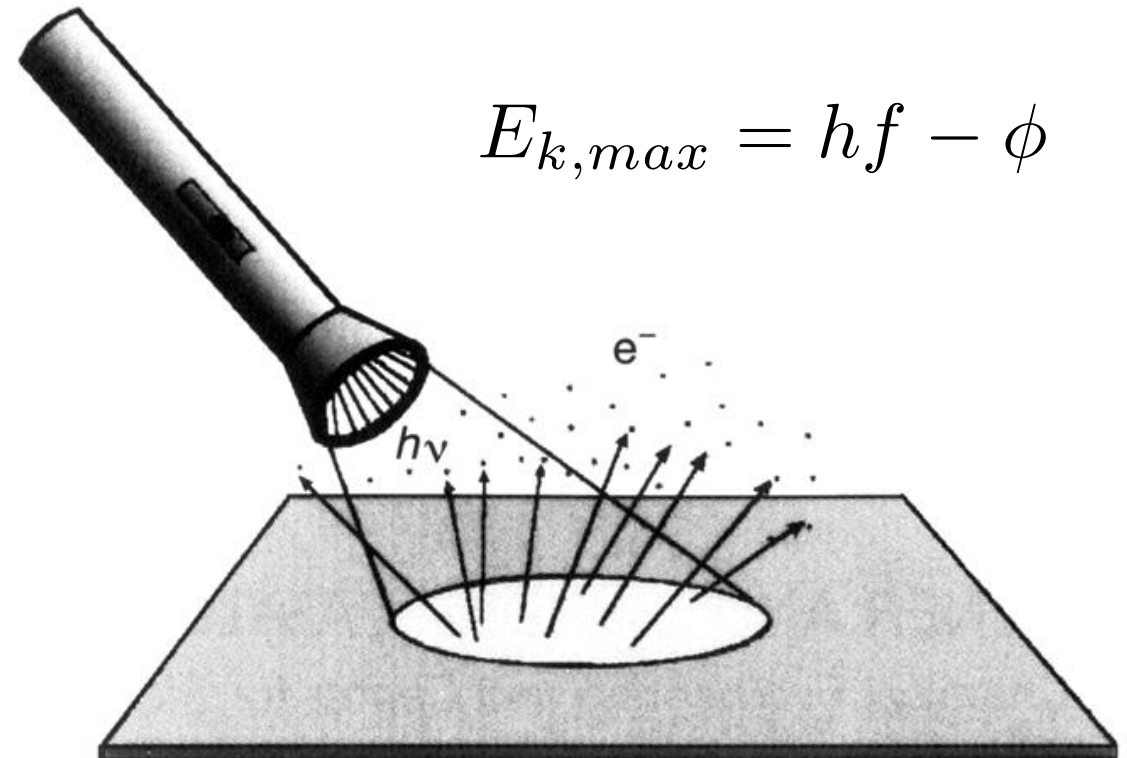
OUTLINE:

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 2. Instrumentation
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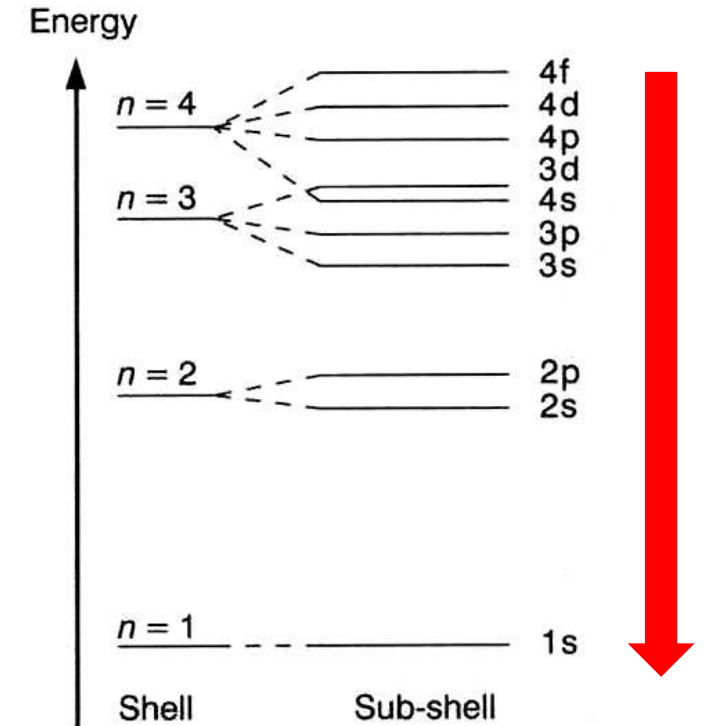
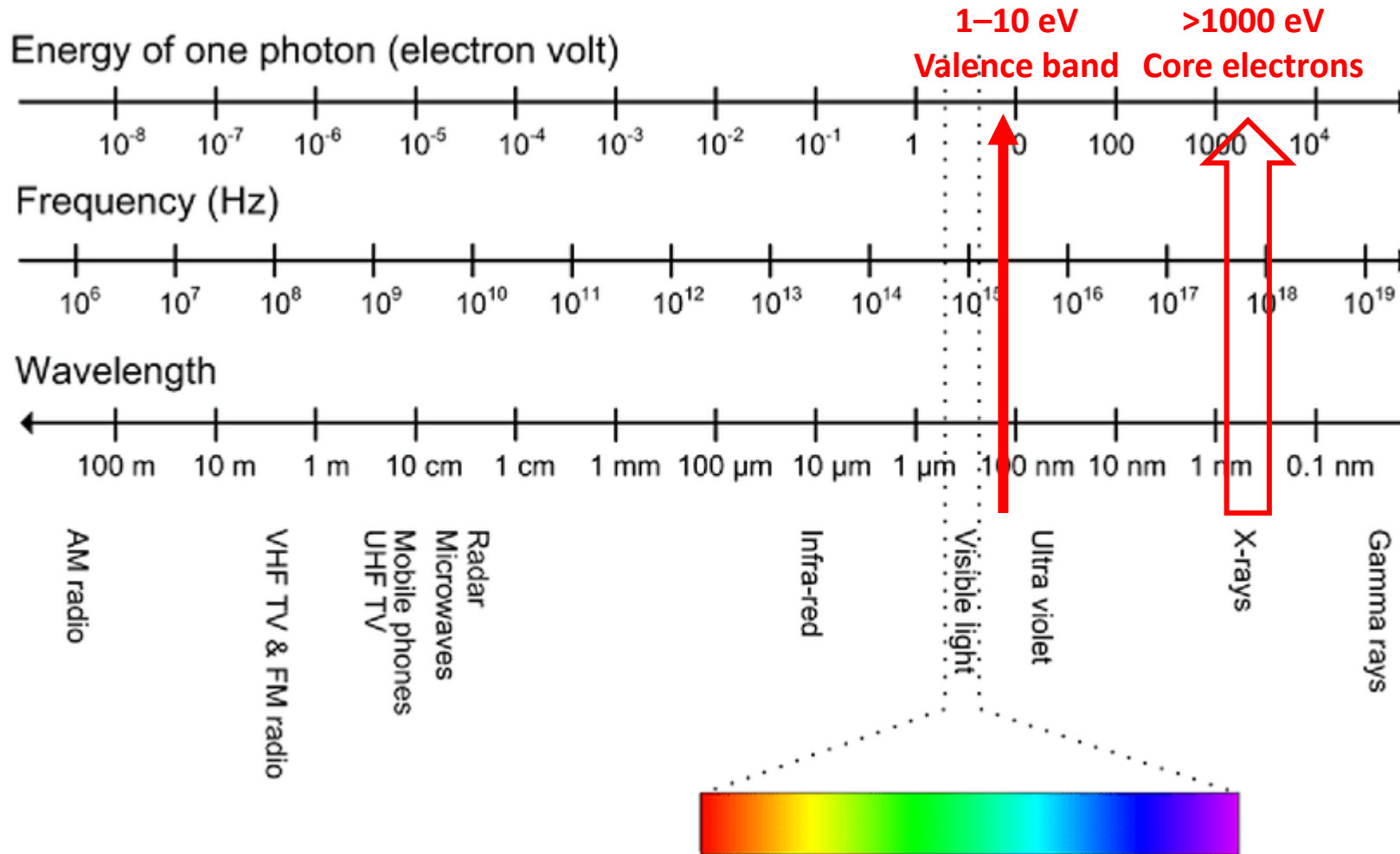
The photoelectric effect

Emission of electrons when light is shone onto a material:

- Photoelectrons
- Metal plate irradiated by UV light emits charged particles: H. Hertz, 1887
- Shown to be electrons: J. J. Thompson, 1899
- Theory on photon quanta: A. Einstein, 1905
- Verified through experiments: R. Millikan, 1915



The electromagnetic spectrum



- Core levels have larger differences in energy!

Photoemission as an analytical tool

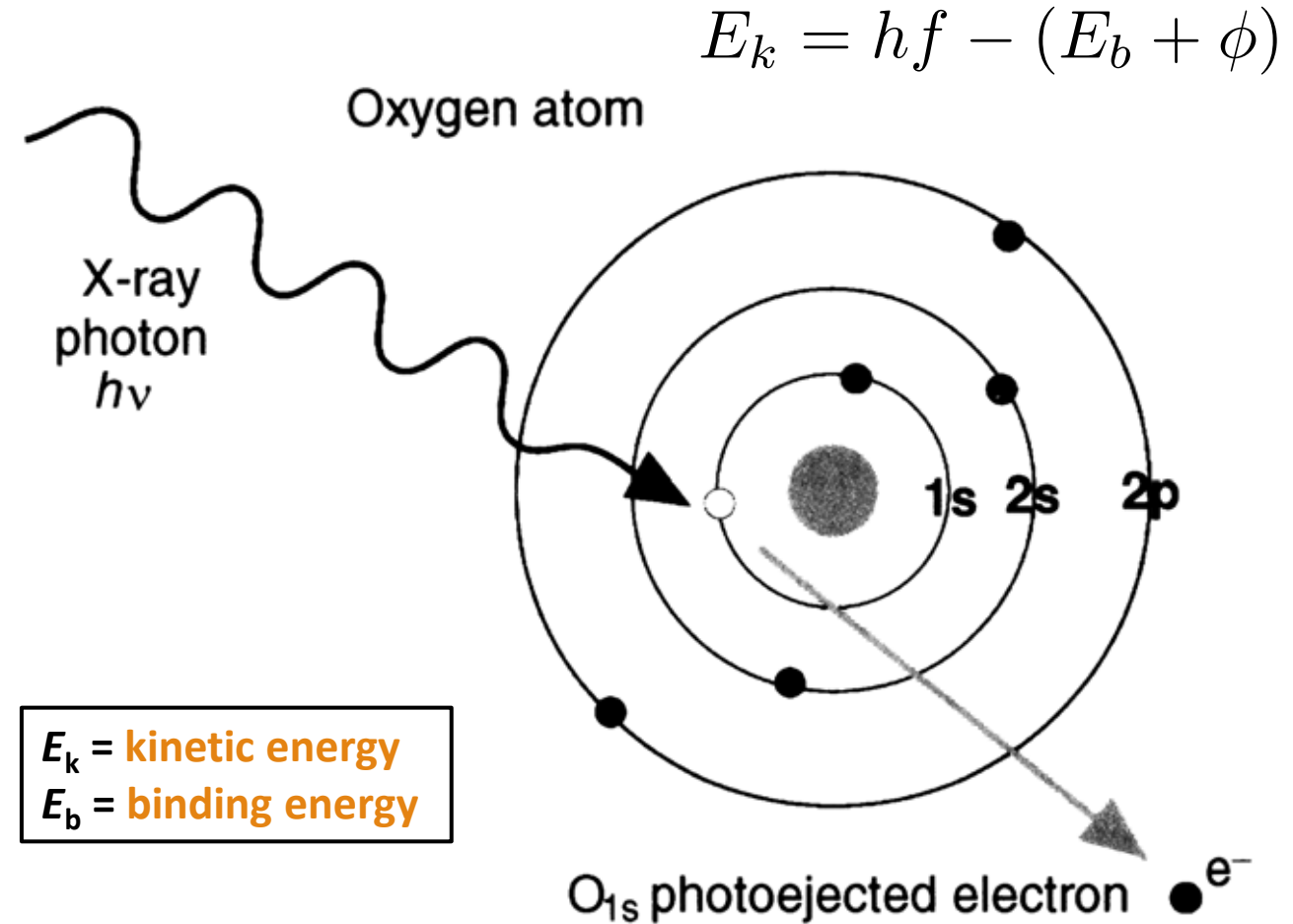
Electron Spectroscopy for Chemical Analysis (ESCA)

- Kai Siegbahn, 1957 (Nobel Prize 1981)
- Intensity of photoelectrons versus E_b or E_k
- Non-destructive analysis technique
- Elemental identification, surface stoichiometry, chemical environments, electronic structure, microscopy with chemical sensitivity...



Widely used technique for surface analysis:

- **XPS**: X-Ray Photoelectron Spectroscopy
- **ESCA**: Electron Spectroscopy for Chemical Analysis
- **UPS**: Ultraviolet Photoelectron Spectroscopy
- **PES**: Photoemission Spectroscopy



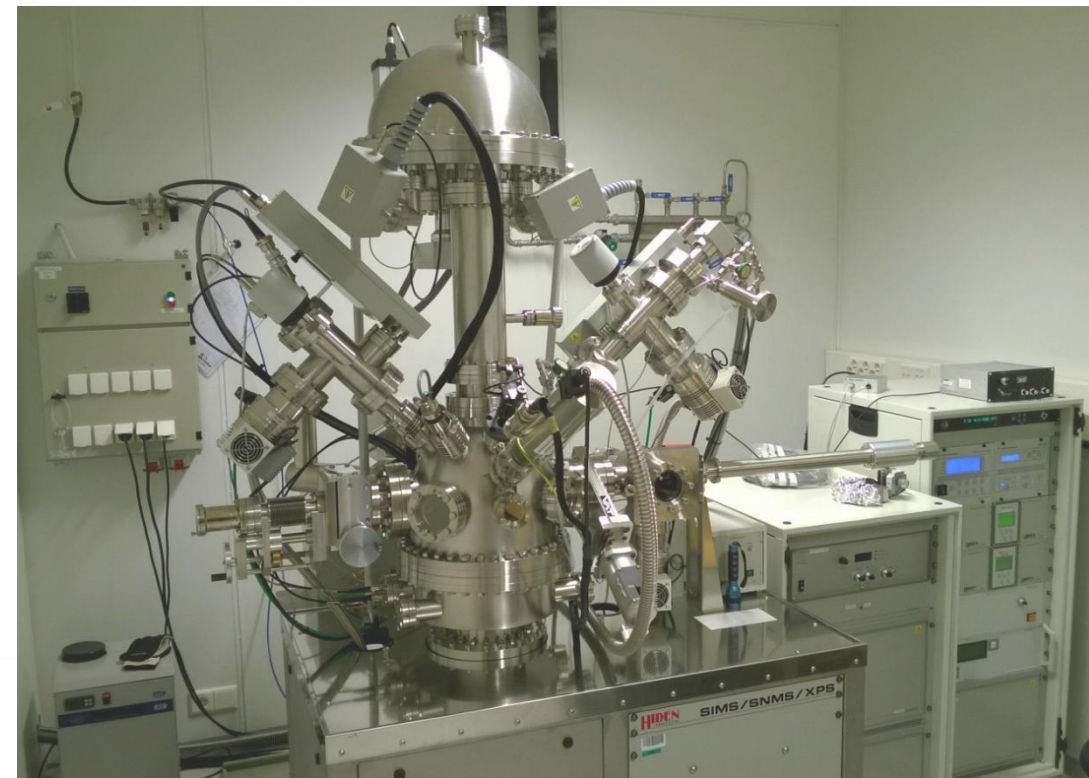
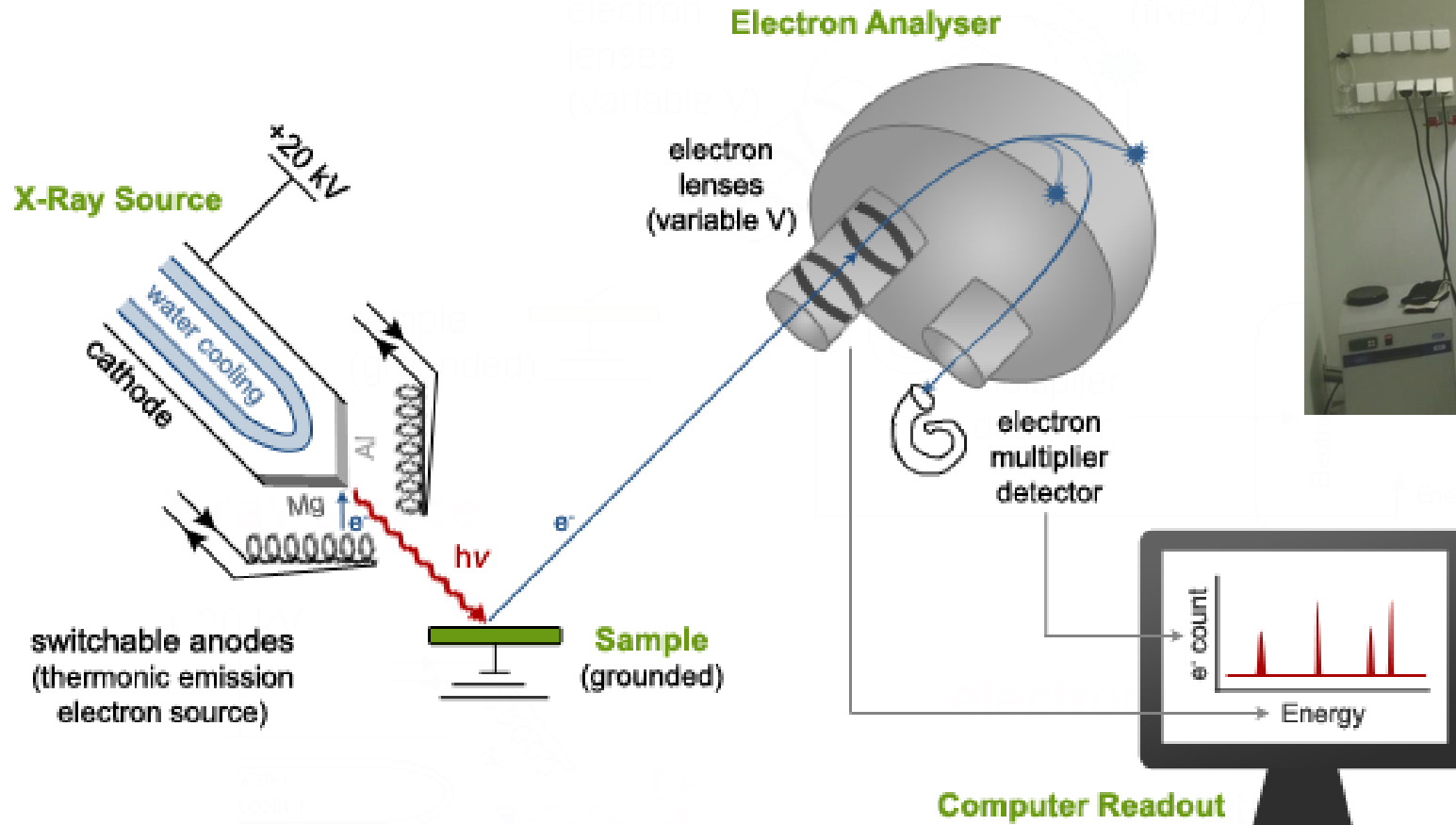
XPS in applied surface science

Quantification of elements at the surface of materials

- Analysis depth less than 10 nm
- Detection of all elements, except for hydrogen
- Chemical identification
- Surface distributions in the first 10 nm (such as films vs islands?)

- Allows for insulating, conducting or heterogeneous samples
- Including composites and organic samples (even biological specimens)
- Easy sample preparation
- Non-destructive (no particle bombardment, only very soft X-rays)

Instrumentation

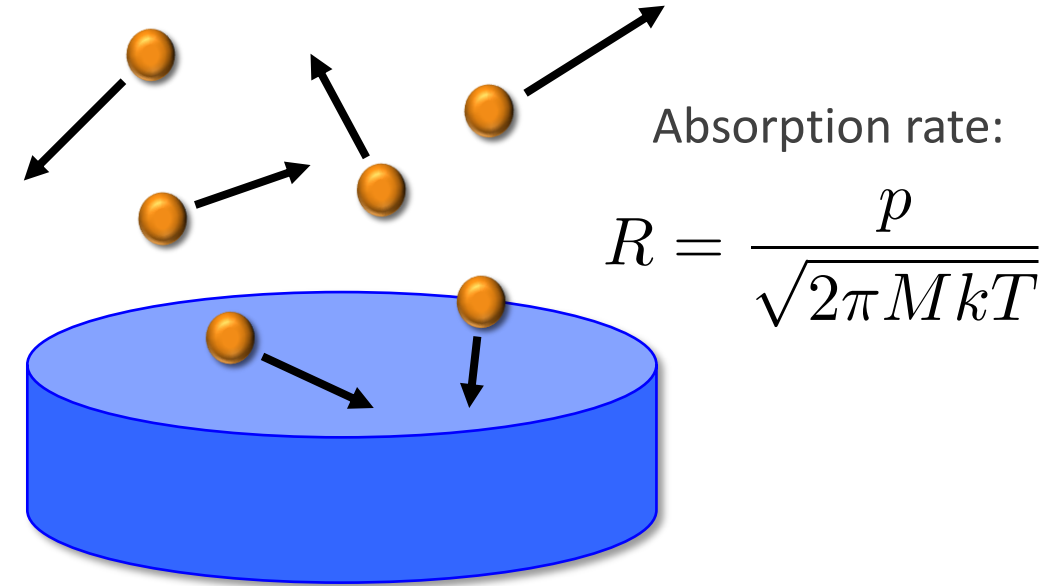


- X-ray source (typically Mg or Al anode)
 - Electron energy analyzer
 - Electronics & computer system
- Vacuum chamber:
- Ar ion gun
 - Low energy electron flood gun
 - Cooling system

Degree of vacuum

Improved vacuum:

- Increases the mean free path for photons and electrons
- Removes adsorbed gases from the sample
- Eliminates adsorption of contaminants on sample surface



Low vacuum	$10^3 - 10^0$ mbar
Medium vacuum	$10^0 - 10^{-3}$ mbar
High vacuum	$10^{-3} - 10^{-6}$ mbar
Very high vacuum	$10^{-6} - 10^{-9}$ mbar
Ultra-high vacuum	$10^{-9} - 10^{-12}$ mbar

Example:

- $p = 10^{-6}$ mbar
- O_2 ($M=32$)
- $T = 300$ K

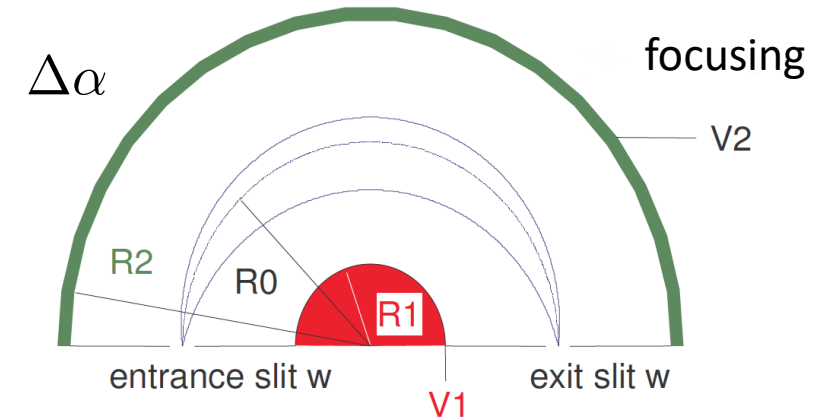
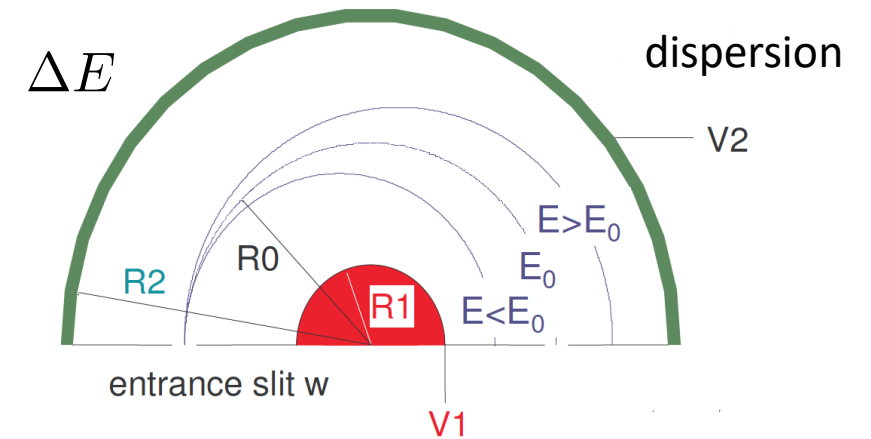
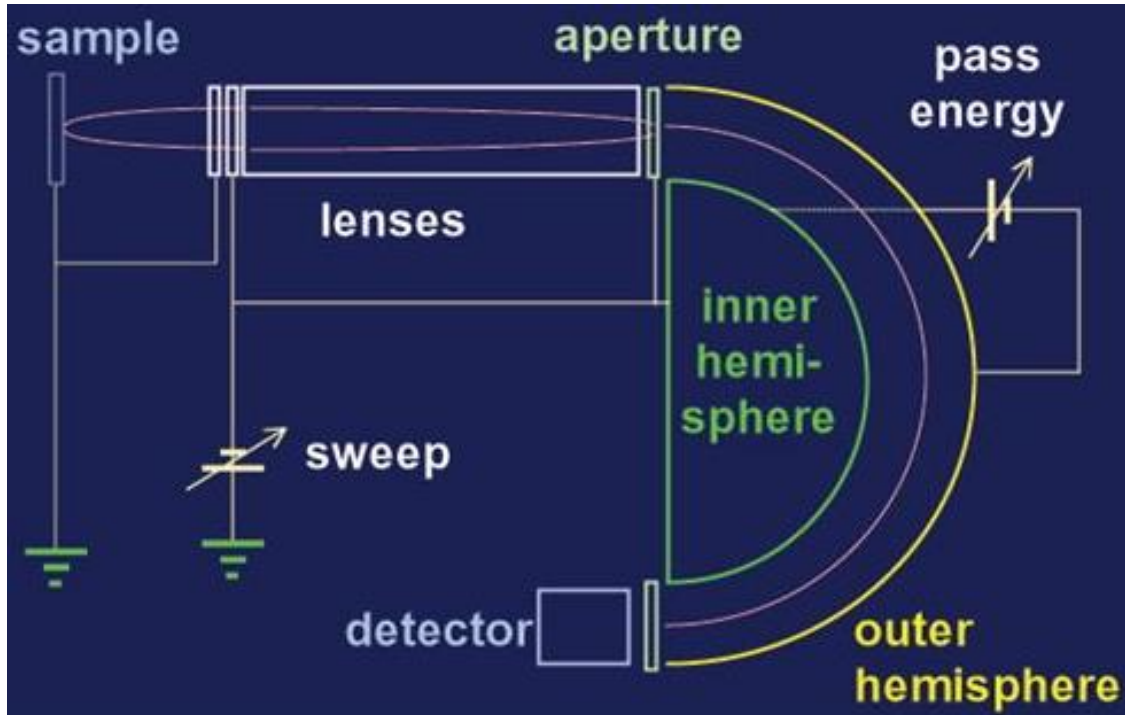
$$\longrightarrow R = 4.7 \cdot 10^{14} \frac{1}{\text{cm}^2 \text{s}}$$

Complete coverage: $1\text{ML} \sim 1 \cdot 10^{15}$ atoms/cm²

- Surface will be clean for about 1 second...

Analyzer

- Concentric hemispherical analyzer
- Lens system for focusing and retarding electronics – **pass energy** kept constant



Pass energy:
$$E_0 = \frac{2(V_2 - V_1)}{R_0} \left(\frac{1}{R_1} - \frac{1}{R_2} \right)^{-1}$$

Energy resolution:
$$\frac{\Delta E}{E_0} = \frac{\omega}{2R_0} + \frac{\alpha^2}{4}$$

- Decrease E_0 or increase R_0 – Better energy resolution!

AXIS 165 / AXIS Ultra^{DLD}

at Aalto CHEM 1995-2021 (L-S Johansson)

Cellulosic materials (ca 50 % of samples):

- Pulps surface analysis & process evaluations
- Paper coatings, contamination, fundamentals
- Model surfaces, mono/multicomponent film formation, and reaction dynamics
- Cellulose nanofibrils, whiskers& bacterial cellulose, fundamentals & applications
- Wood hydrothermal modification, adhesion
- Derivatisations TEMPO, click, CMC, silylation...
- Functional surfaces, bio-interfaces, biological surfaces, biomimetic materials
- Composites cellulose and derivatives, polymers, clay, lignin, chitosan, graphene, CNTs
- Textiles: flax, cotton, MMC, synthetic fibers
- Carburisedcelluloses: e.g. catalysis

Materials other than celluloses (50 % samples):

- Ultra-thin inorganic and organic films: ALD deposited, spin-coated, LB films, CVD, plasma, graphenes, CNTs, DLCs
- Surface analysis of metals, alloys, oxides, composites, polymers, powders, fibers, deposits
- Contamination analyses: e.g. semiconductor devices, quality control



Limitations

XPS can only analyze the outermost surface (0-20 nm)

- It will not tell you the average sample composition
- Surface contamination is a big issue
- Samples must tolerate Ultra High Vacuum ($<10^{-9}$ mbar)

Samples

- Almost any solid sample can be analyzed, provided it tolerates ultra high vacuum. Even insulating powders and fibers.
- Sample preparation: As little as possible.
- Samples are secured on the holder with springs or with vacuum compatible tape and then evacuated.



XPS

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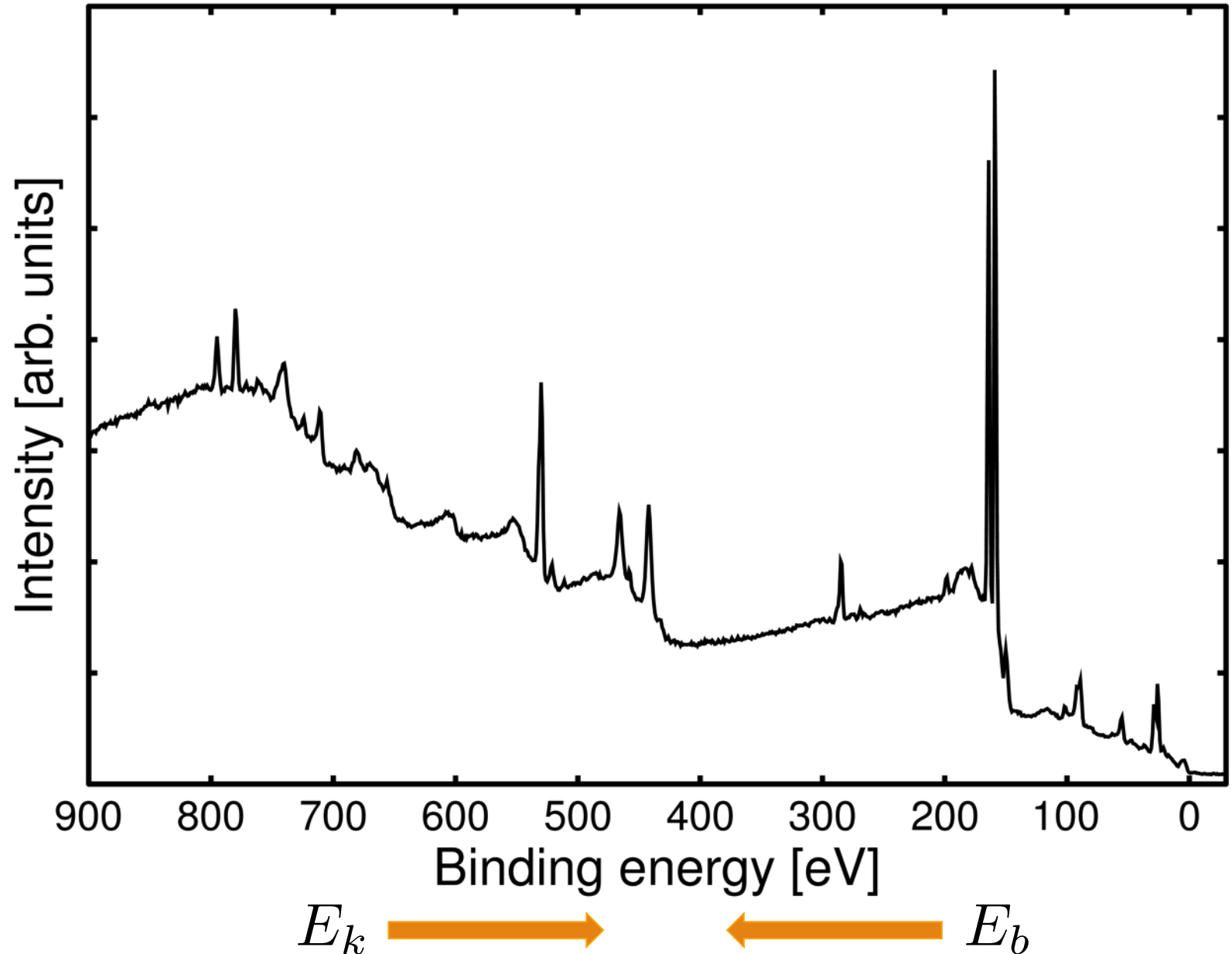
Experiment

Measurement:

- Retarding potential is step-wise decreased
- Dwell time for each step: a few 100 ms
- Number of electrons measured for each energy

Results:

- Photoemission spectrum
- High intensity peaks at core level binding energies
- **Survey spectra** – large range, low resolution
- **High-resolution spectra** – small range, high resolution



Binding energies

Core level energies are element specific:

- Each peak in the survey spectrum can be assigned to the binding energy of electrons from a specific energy level and element

Identification:

- Start with the strongest peaks – find energy level that matches (C 1s, O 1s + Auger lines are usually present)
- Compare other energy levels in element with spectrum – assign peaks
- Usually **fixed ratios** between **peak heights** for same element
- If there is a strong peak, but the other lines for that element do not appear – try to find another element!

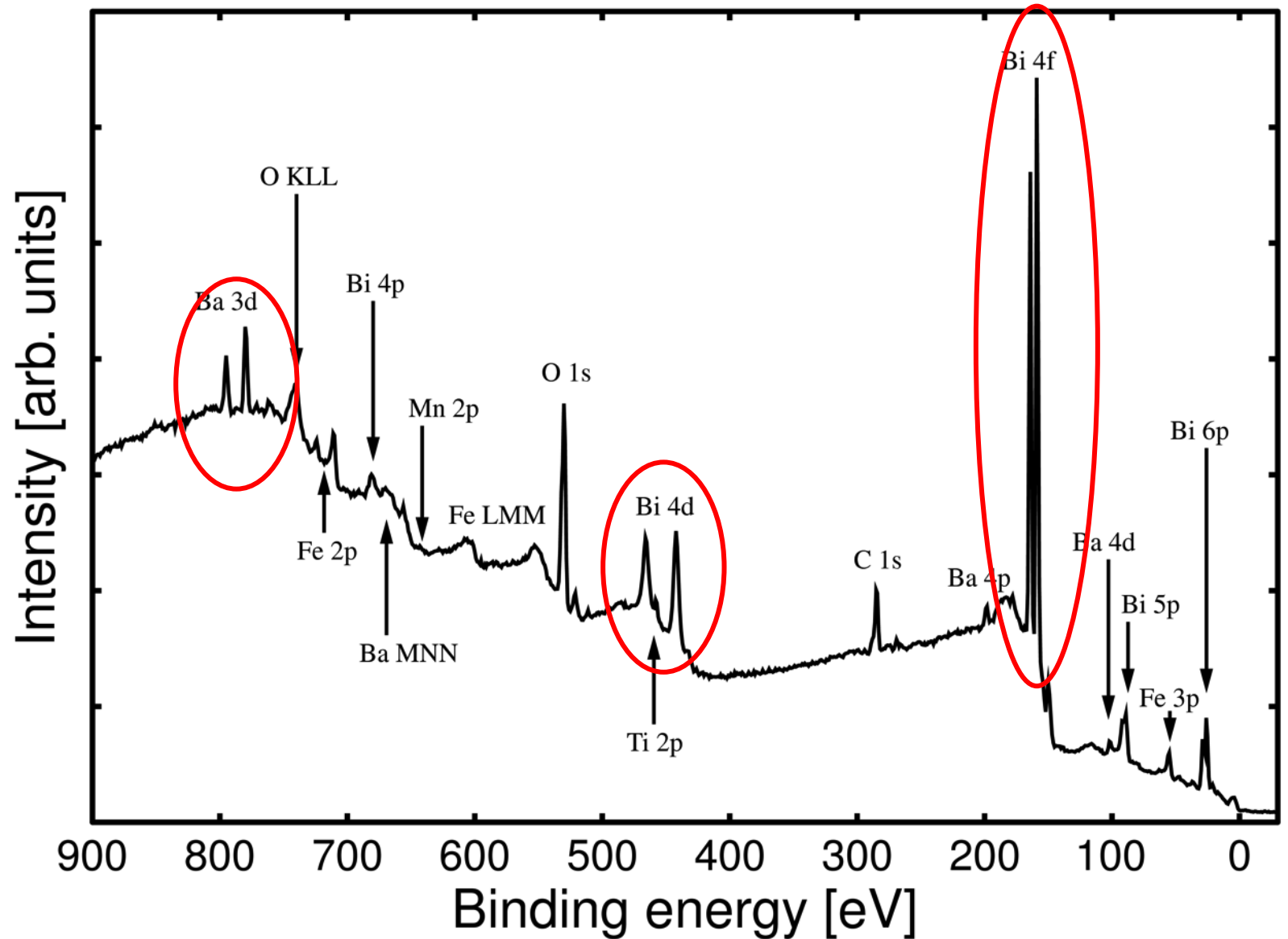
Table 4.2. Binding energies of some elements

Z	El	1s _{1/2} K	2s _{1/2} L ₁	2p _{1/2} L ₂	2p _{3/2} L ₃	3s _{1/2} M ₁	3p _{1/2} M ₂	3p _{3/2} M ₃	3d _{3/2} M ₄	3d _{5/2} M ₅
1	H	14								
2	He	25								
3	Li	55								
4	Be	111								
5	B	188			5					
6	C	284			6					
7	N	399			9					
8	O	532	24		7					
9	F	686	31		9					
10	Ne	867	45		18					
11	Na	1072	63		31	1				
12	Mg	1305	89		52	2				
13	Al	1560	118	74	73	1				
14	Si	1839	149	100	99	8				
15	P	2149	189	136	135	16		10		
16	S	2472	229	165	164	16		8		
17	Cl	2823	270	202	200	18		7		
18	Ar	3202	320	247	245	25		12		
19	K	3608	377	297	294	34		18		
20	Ca	4038	438	350	347	44		26		5
21	Sc	4493	500	407	402	54		32		7
22	Ti	4965	564	461	455	59		34		3
23	V	5465	628	520	513	66		38		2
24	Cr	5989	695	584	575	74		43		2
25	Mn	6539	769	652	641	84		49		4
26	Fe	7114	846	723	710	95		56		6
27	Co	7709	926	794	779	101		60		3
28	Ni	8333	1008	872	855	112		68		4
29	Cu	8979	1096	951	932	120		74		2
30	Zn	9659	1194	1044	1021	137		90		9
31	Ga	10367	1299	1144	1117	160		106		20
42	Mo	20000	2866	2625	2520	505	410	393	208	205
46	Pd	24350	36304	3330	3173	670	559	531	340	335
48	Ag	25514	3806	3523	3351	718	602	571	373	367
73	Ta*	67416	11681	11136	11544	*566	*464	*403	*24	*22
79	Au*	80724	14352	13733	14208	*763	*643	*547	*88	*84

* 4s, 4p et 4f levels indicated, respectively

Survey

- Peaks can now be labeled
- When all peaks are accounted for, elemental constituents have been found
- Some features are not necessarily discrete peaks from core level electrons:
 - Double peaks
 - Broad peaks in bunches
 - Etc...



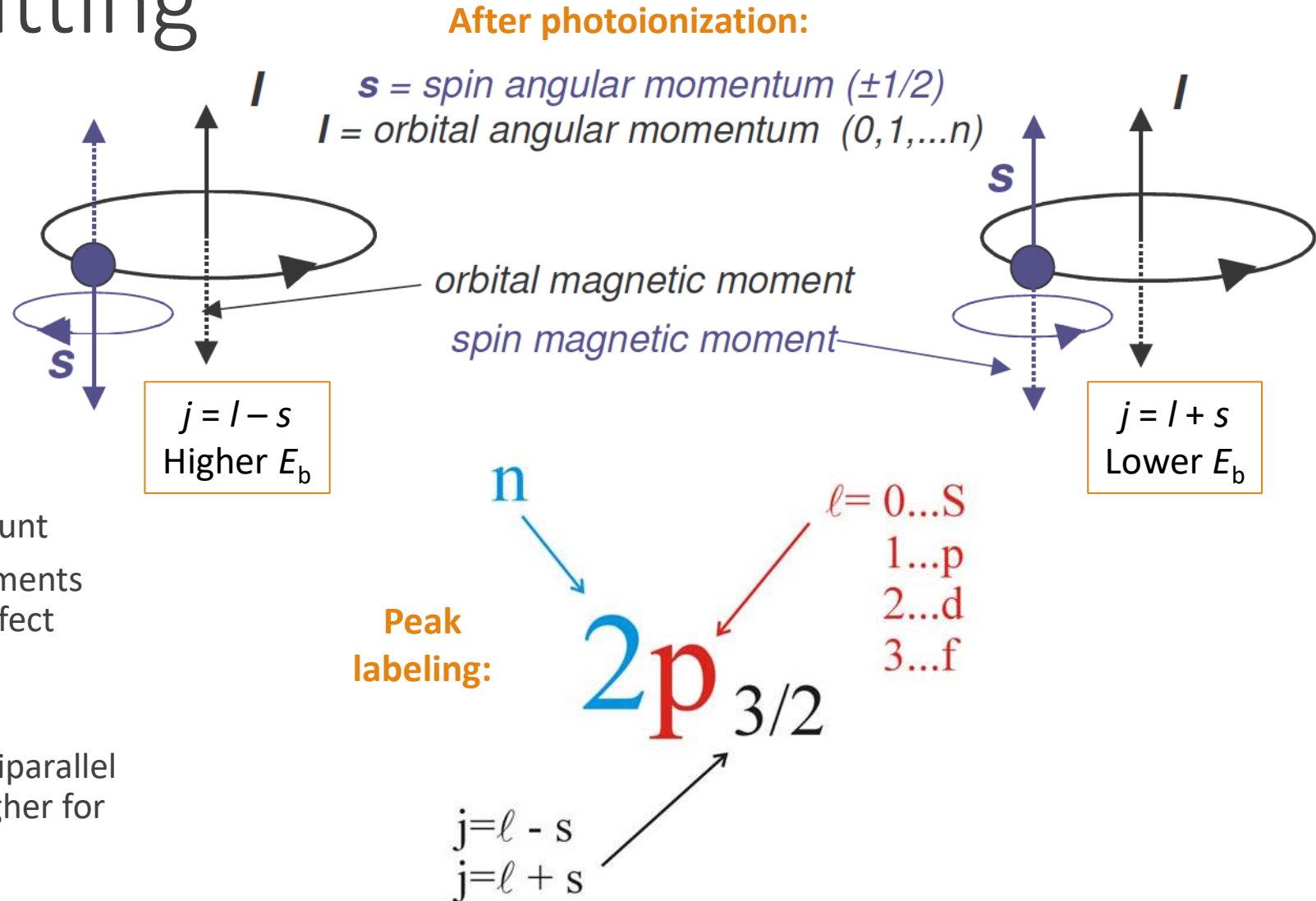
Spin-orbit splitting

Before ionization

- Inner shells are filled
- No spin-orbit interactions

After ionization

- Un-paired electrons
- Spin-orbit coupling taken into account
- Interaction between magnetic moments from electron spin and orbit will affect final energies
- Potential energy minimized for antiparallel moments – E_k of photoelectron higher for parallel spins: E_b lower



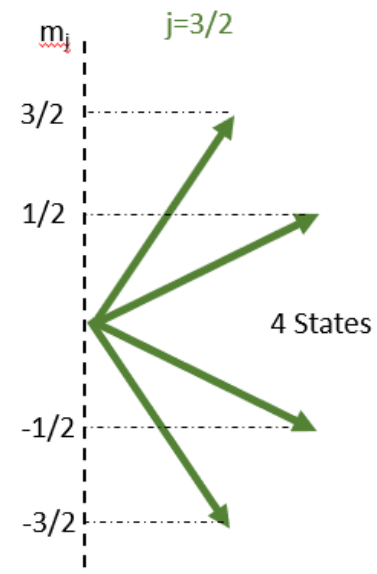
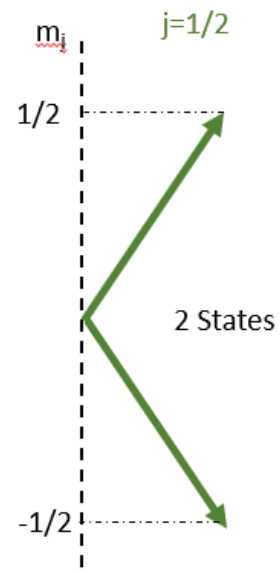
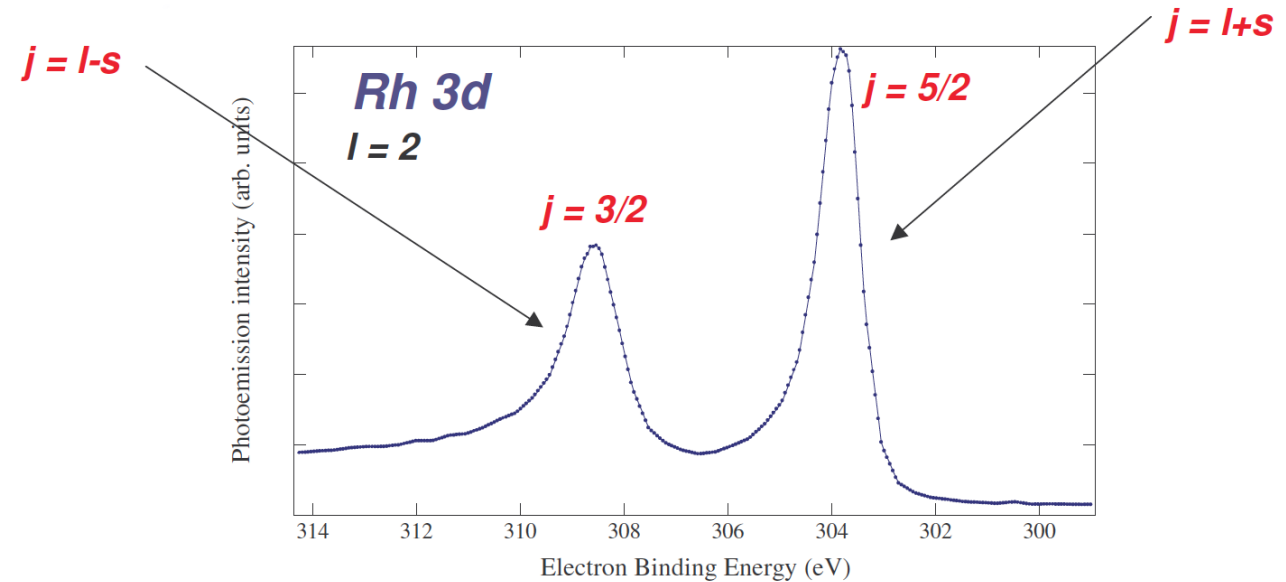
Doublet peak ratios

Spin-orbit splitting results in the formation of **doublets**

- Fixed area ratios between peaks!
- Degeneracy of states: The total momentum j can have different orientations in space (m_j) with the same spin orbit-coupling energy

n	l	m_l
1	0	0
2	0	0
1	1	-1, 0, +1
3	0	0
1	1	-1, 0, +1
2	2	-2, -1, 0, +1, +2

- Can be used for identification of elements
- For the same element ΔE_b will be approx. constant independent of compound

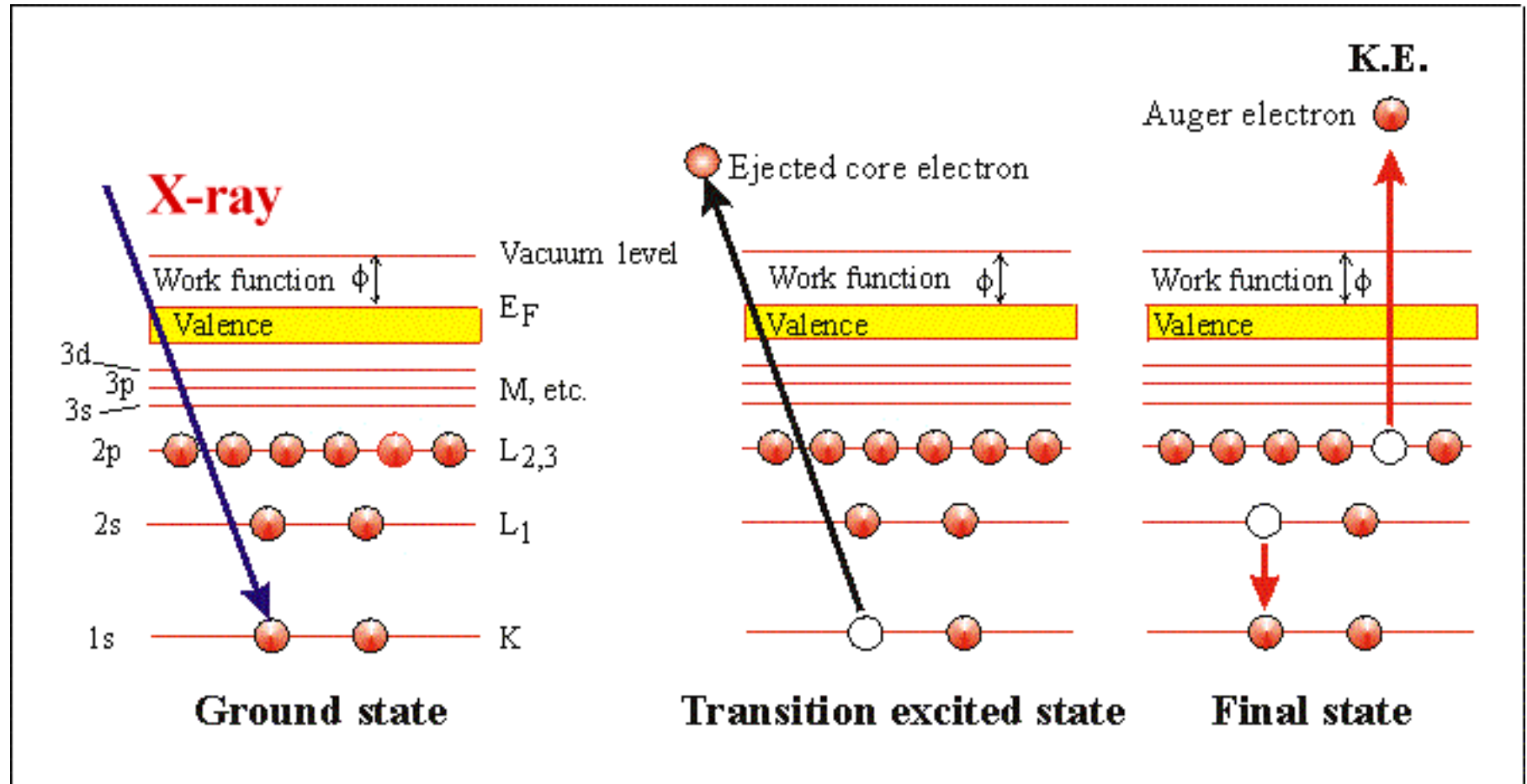


Degeneracy Ratio 1:2 (p orbital)

Orbital	Total Angular Momentum j	Degeneracy	Ratio
p	1/2	2	1:2
	3/2	4	
d	3/2	4	2:3
	5/2	6	
f	5/2	6	3:4
	7/2	8	

Auger electrons

- Atoms are in transitional excited states after core electrons are ejected
- Auger electrons can be emitted when excited states are relaxed
- E_k is independent of X-ray photon energy
- Position in E_b scale will depend on X-ray source



Characteristic X-rays

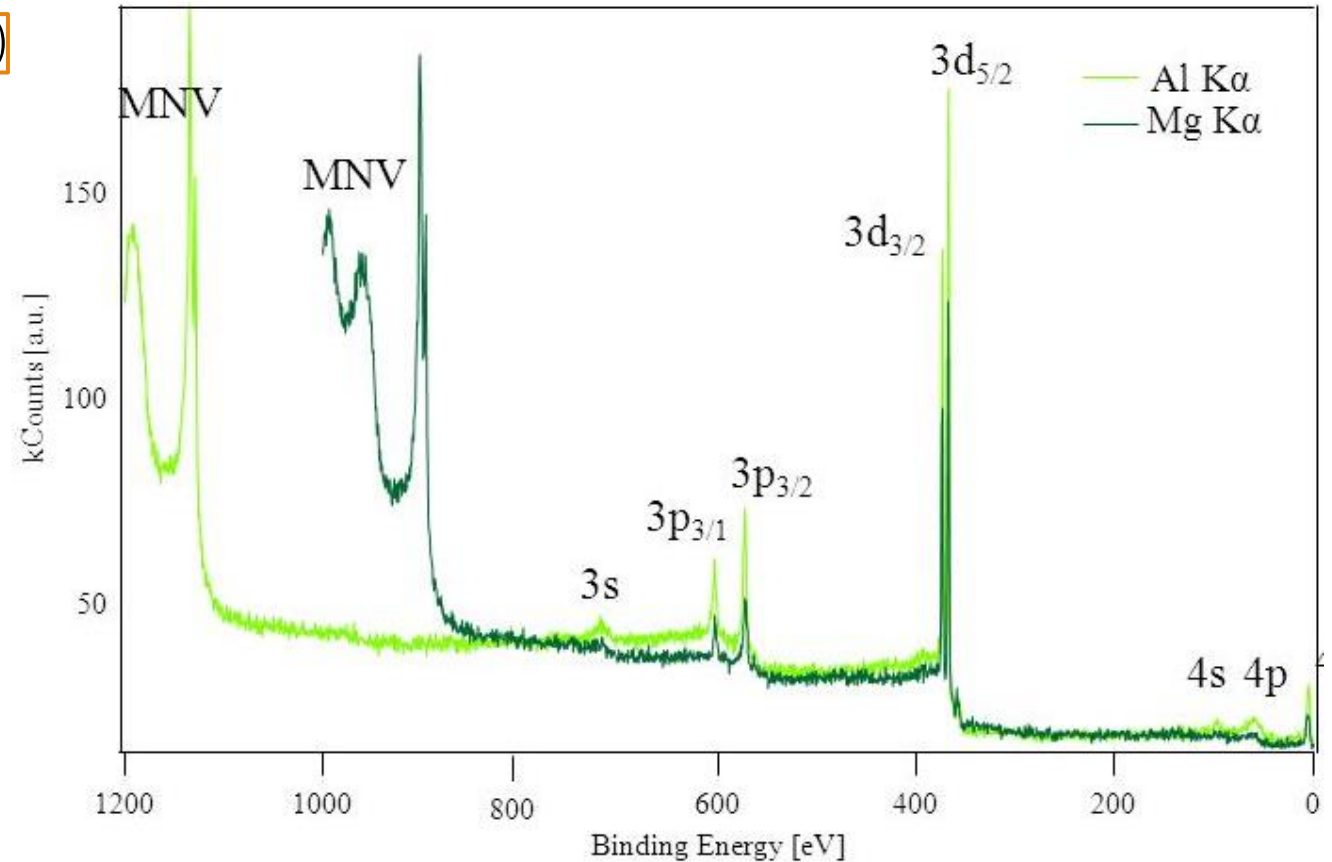
Different X-rays:

- Binding energy constant $E_k = hf - (E_b + \phi)$
- Auger transition (“binding”) energy varies (kinetic energy for Auger electrons is constant)

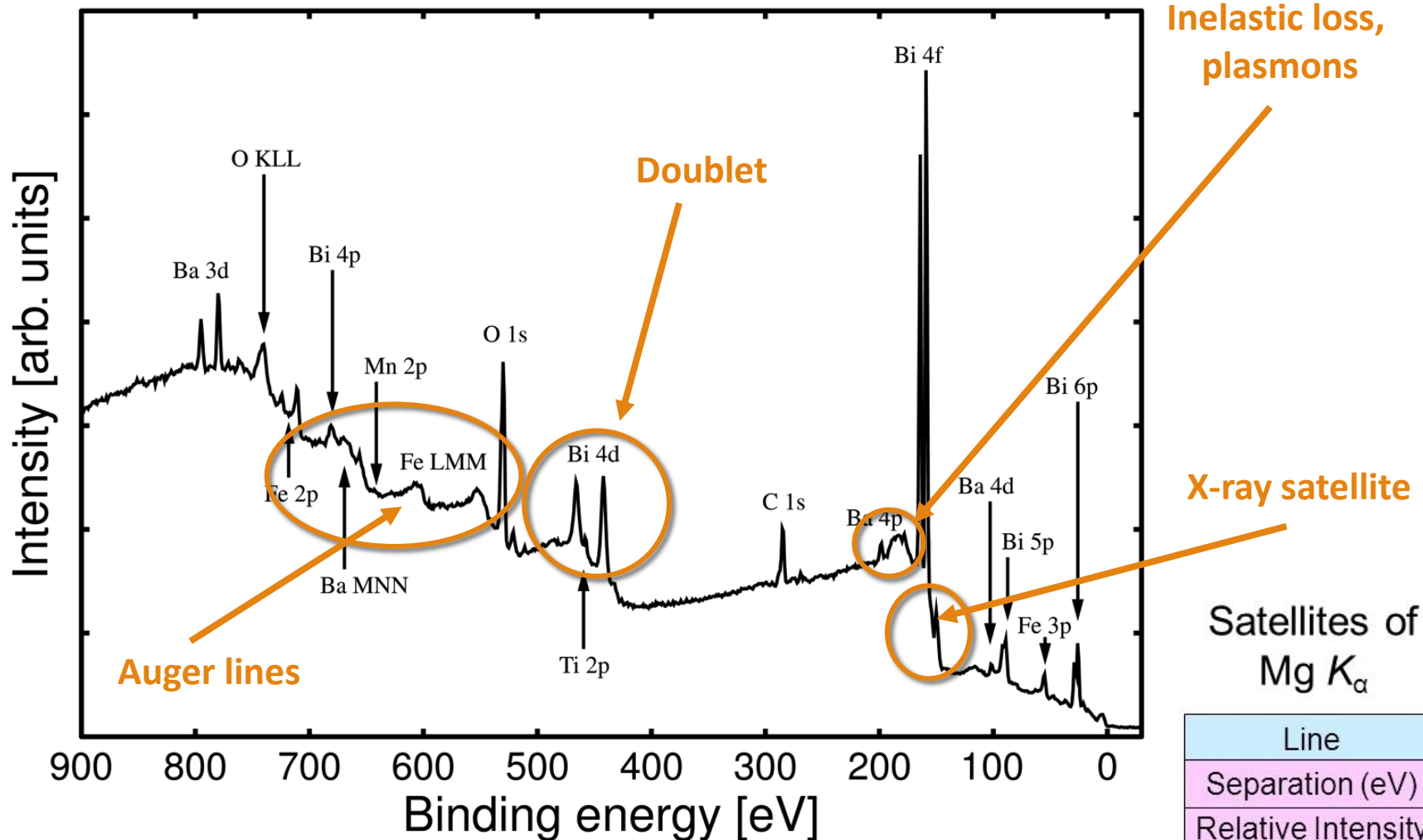
Line	Energy (eV)	Width (eV)
Y M_ζ	132.3	0.47
Zr M_ζ	151.4	0.77
Cr L_α	572.8	3.0
Cu L_α	929.7	3.8
Mg K_α	1253.6	0.7
Al K_α	1486.6	0.85
Si K_α	1739.5	1.0
Cu K_α	8048.0	2.6



Typical Ag spectra:



Other features



Intrinsic loss features:

- Finite probability that the emitted core-shell electron will interact with a valence electron (that ends up in higher/unbound state) in the same atom – “shake-up/off” satellites, lower E_k

Extrinsic loss features:

- Photoelectrons travelling in a solid will interact with other electrons – lower E_k

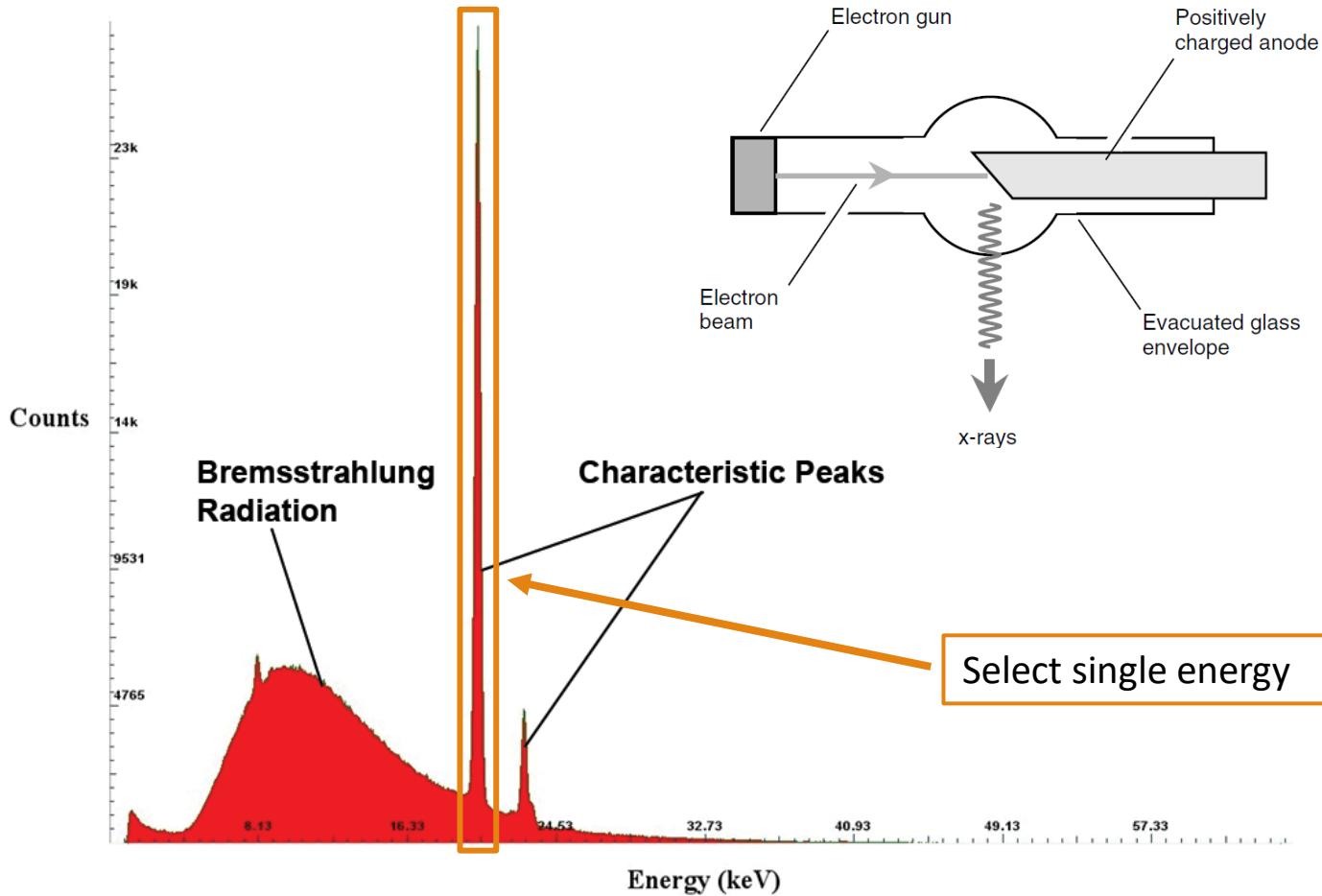
X-ray effects:

- Satellites** – minor X-ray components from anode material – higher $E_0=hf$
- Ghosts** – X-rays from other element (very rare)

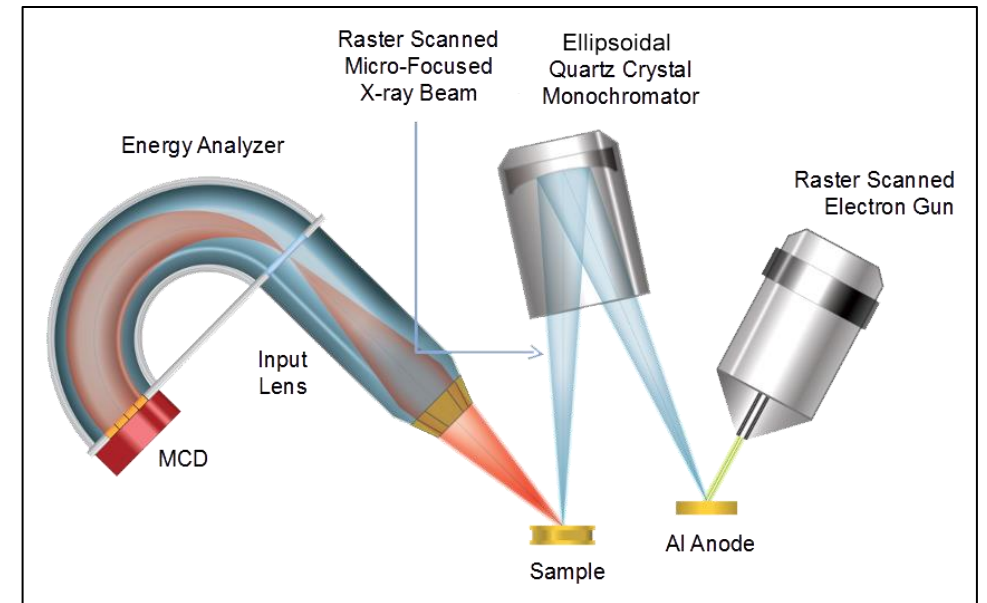
Satellites of Mg K α

Line	α_{12}	α_3	α_4	α_5	α_6	β
Separation (eV)	0.0	8.4	10.2	17.5	20	48.5
Relative Intensity	100	8.0	4.1	0.55	0.45	0.5

X-Ray production



- X-ray tubes:
 - Continuous Bremsstrahlung
 - Characteristic peaks that depend on the anode material
- Unnecessarily large X-ray load & unwanted satellites in the spectra
- Solution: Monochromator



X-Ray monochromator

Advantages of X-monochromator:

- Narrow peak width, focusing of beam
- Reduced background, no satellite or ghost peaks

Disadvantage:

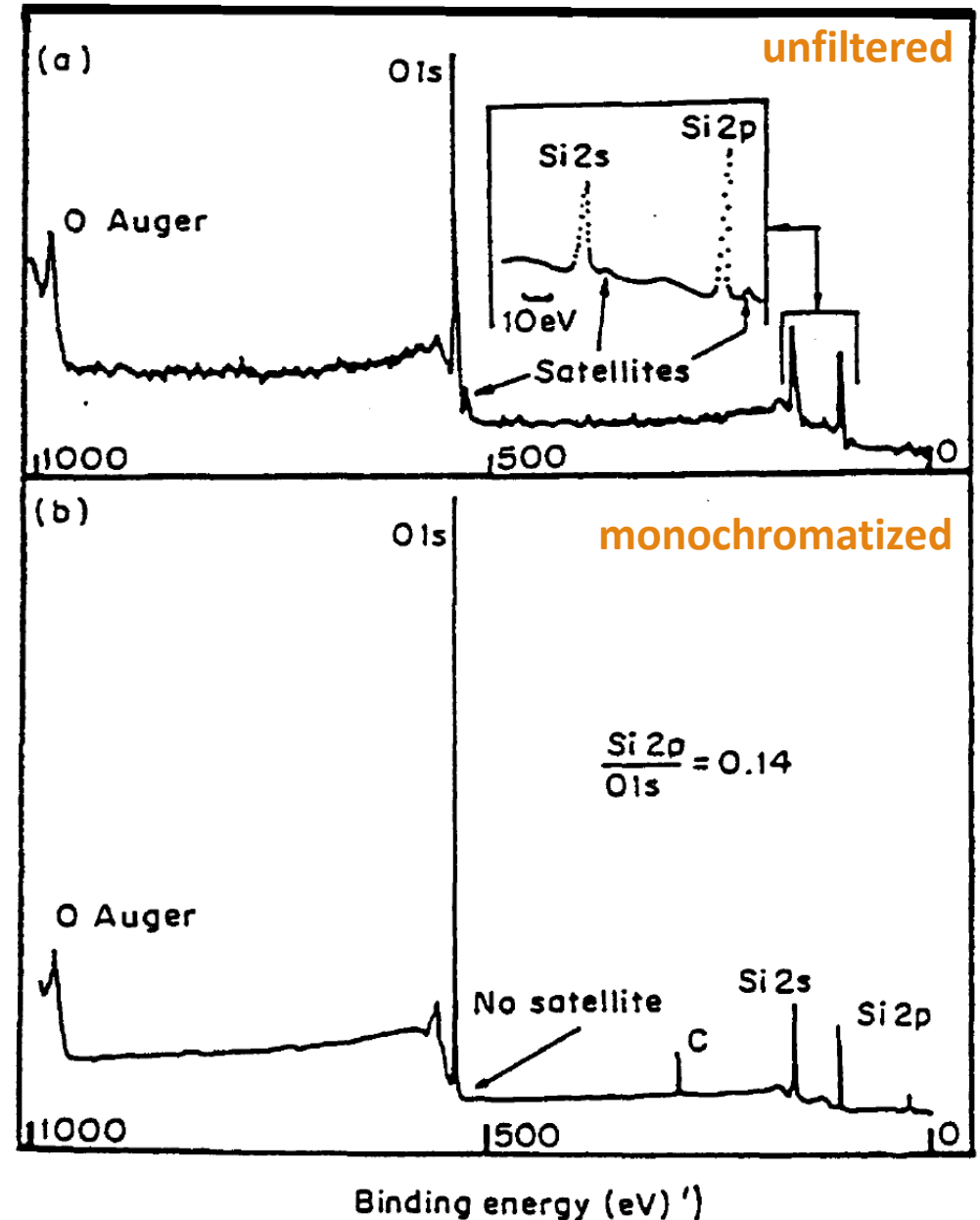
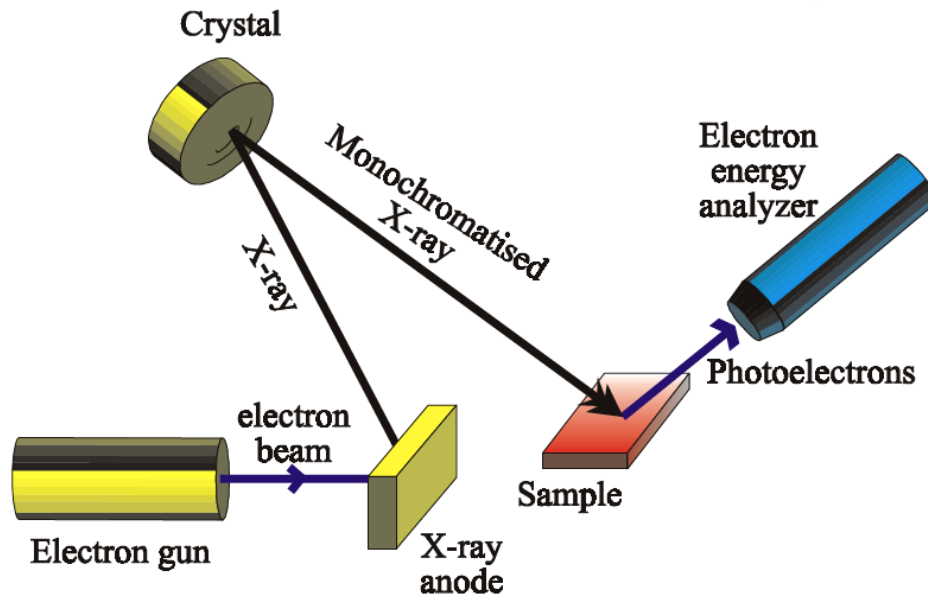
- 10-40 times lower intensity

Bragg diffraction:

$$n\lambda = 2d \sin \theta$$

For Al K_{α} :
 $\lambda = 8.3 \text{ \AA}$

Quartz (10 $\bar{1}$ 0)
 planes:
 $d = 4.25 \text{ \AA}$
 $\theta = 78.5^{\circ}$



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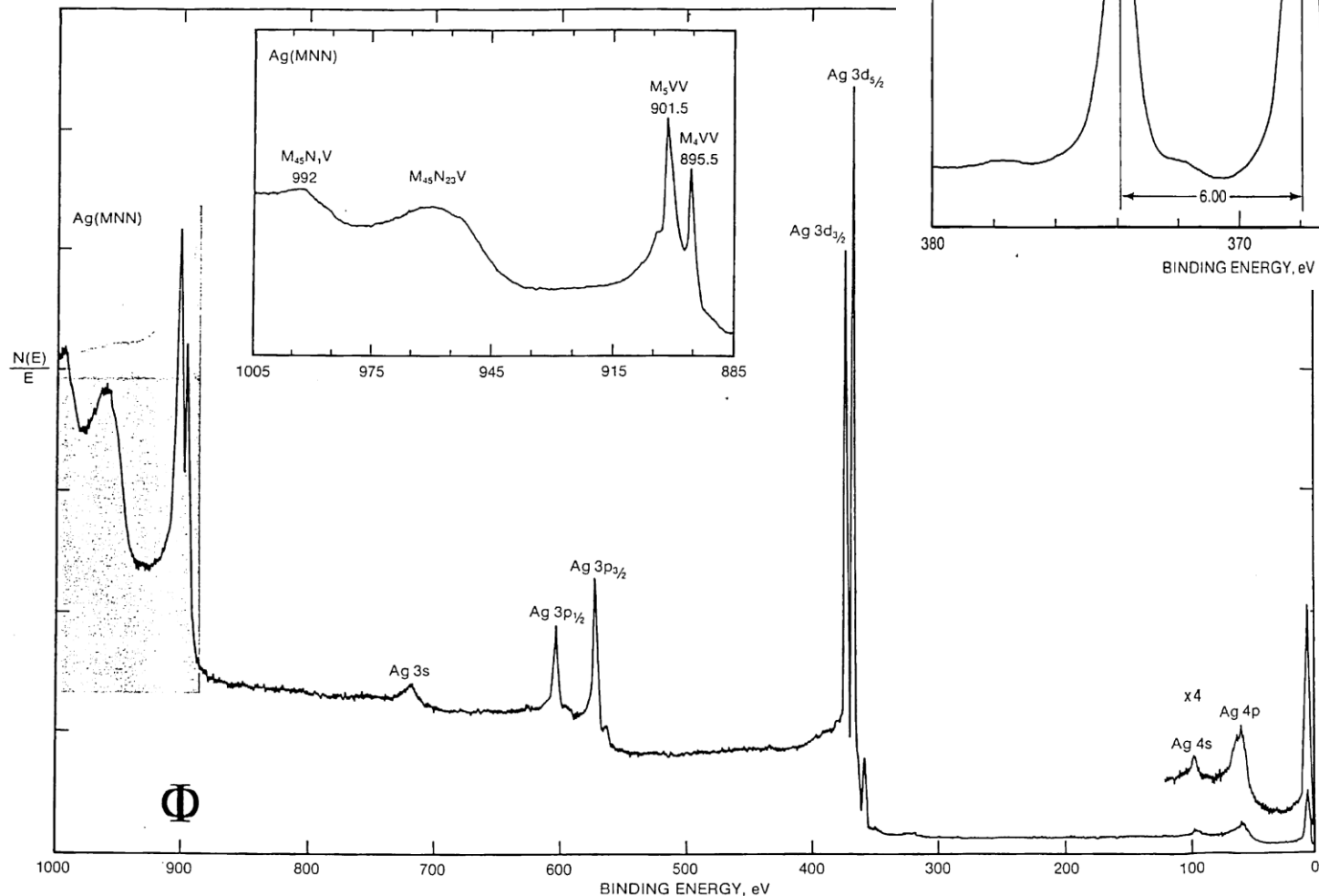
Reference spectra

HANDBOOK OF X-RAY PHOTOELECTRON SPECTROSCOPY

A Reference Book of Standard Data
For Use In
X-Ray Photoelectron Spectroscopy

Handbooks with reference
data:

- Vital for identification of elements
- Reference survey and high-resolution spectra



Reference tables

Table 1. Line Positions^{a)} from Mg X-rays, by Element

Element	Atomic No.	Range (eV)	Photoelectron Lines ^{b)}										Range (eV)	Auger Lines					
			1s	2s	2p _{1/2}	2p _{3/2}	3s	3p _{1/2}	3p _{3/2}	3d _{3/2}	3d _{5/2}	4s		4p _{1/2}	4p _{3/2}	KL ₁ L ₁	KL ₁ L ₂₃	KL ₂₃ L ₂₃ ^{c)}	
Li	3	4	56																
Be	4	4	113																
B	5	8	151																
C	6	12	287																1082
N	7	9	402																
O	8	4	531	23															
F	9	6	686	30															
Ne	10	0	863	41	14														
Na	11	2	1072	54	31														
Mg	12	2	90	51															
Al	13	4	119	74															
Si	14	6	153	103	102														
P	15	8	191	134	133	14													
$L_{2,3}M_{2,3}M_{2,3}^{**}$ $L_{2,3}M_{2,3}M_{2,3}^{**}$ $L_{2,3}M_{2,3}M_{2,3}^{**}$ $L_{2,3}M_{2,3}M_{2,3}^{**}$ $L_{2,3}M_{2,3}M_{2,3}^{**}$ $L_{2,3}M_{2,3}M_{2,3}^{**}$ $L_{2,3}M_{2,3}M_{2,3}^{**}$ $L_{2,3}M_{2,3}M_{2,3}^{**}$																			
S	16	8	229	166	165	17													
Cl	17	11	270	201	199	17													
Ar	18	0	319	243	241	22													
K	19	1	378	296	293	33	17												
Ca	20	2	429	350	347	44	25												
Sc	21	6	501	407	402	53	31												
Ti	22	8	565	464	458	62	37												
V	23	6	626	506	501	69	40												
Cr	24	6	696	566	557	77	46	45											
Mn	25	2	770	652	641	83	49	48											
Fe	26	8	847	723	710	93	56	55											
Co	27	6	927	796	781	103	63	61											
Ni	28	6	1009	873	855	112	69	67											
Cu	29	4	1098	956	934	124	79	77											
Zn	30	2	1196	1045	1022	140	92	89											
Ga	31	2	1144	1117	1103	168	105	10											
Ge	32	4	1212	1144	1128	124	112	31											
As	33	7	1277	1207	1190	143	124	45											
Se	34	4	1344	1264	1246	163	138	57											
Br	35	7	1411	1321	1302	182	152	69											
Kr	36	0	1478	1378	1358	208	168	88											
Rb	37	1	1545	1435	1414	224	184	100											
Sr	38	2	1612	1492	1470	240	194	110											
Y	39	2	1679	1559	1536	256	204	120											
Zr	40	6	1746	1626	1602	272	214	130											

a) Lines enclosed in boxes are the most intense and are the most suitable for use of line energies in identifying chemical states.
 b) For brevity, 2p_{1/2} equals 2p₂, 3d_{5/2} equals 3d_{5/2}, etc.
 c) Designation is oversimplified.
 d) Includes LVV when M levels are not in core, and MVV when N levels are not in core.
 e) No sample 4p_{1/2} line exists for this group of elements.
 f) The 4d doublet for these elements is complex and is variable with chemical state because of multiplet splitting and multielectron processes.

Table 3. Line Positions from Mg X-rays, in Numerical Order

17 Hf 4f, (2)	102 Si 2p _{3/2} (1)	206 Nb 3d _{5/2} (3)	359 Lu 4p _{3/2} (53)	575 Te 3d _{5/2} (10)	863 Ne 1s
23 O 2s	105 Ga 3p _{3/2} (3)	208 Kr 3p _{3/2} (8)	359 Hg 4d _{5/2} (20)	577 Cr 2p _{3/2} (9)	872 Cd (A)
25 Ta 4f, (2)	108 Ce 4d _{5/2} (4)	213 Hf 4d _{5/2} (11)	362 Gd (A)	594 Ce (A)	875 N (A)
30 F 2s	110 Rb 3d _{5/2} (1)	229 S 2s	364 Nb 3p _{3/2} (15)	599 F (A)	882 Ce 3d _{5/2} (18)
31 Ge 3d _{5/2} (1)	113 Be 1s	229 Ta 4d _{5/2} (12)	368 Ag 3d _{5/2} (6)	618 Cd 3p _{3/2} (34)	897 Ag (A)
34 W 4f, (2)	113 Ge (A)	230 Mo 3d _{5/2} (3)	378 K 2s	619 I 3d _{5/2} (11)	920 Sc (A)
40 V 3p	114 Pr 4d	238 Rb 3p _{3/2} (9)	380 U 4f, (11)	632 La (A)	928 Pd (A)
41 Ne 2s	118 Ti 4f, (4)	241 Ar 2p _{3/2} (2)	385 Ti 4d _{5/2} (21)	641 Mn 2p _{3/2} (11)	930 Pr 3d _{5/2} (20)
43 Re 4f, (2)	119 Al 2s	245 W 4d _{5/2} (12)	396 Mo 3p _{3/2} (17)	657 Ba (A)	934 Cu 2p _{3/2} (20)
44 As 3d _{5/2} (1)	120 Nd 4d	263 Re 4d _{5/2} (14)	402 N 1s	666 In 3p _{3/2} (38)	954 Rh (A)
45 Cr 3p _{3/2} (1)	124 Ge 3p _{3/2} (4)	264 Na (A)	402 Eu (A)	670 Mn (A)	961 Ca (A)
48 Mn 3p _{3/2} (1)	132 Sm 4d	265 Zn (A)	402 Sc 2p _{3/2} (5)	672 Xe 3d _{5/2} (13)	970 U (A)
50 I 4d _{5/2} (2)	133 P 2p _{3/2} (1)	269 Sr 3p _{3/2} (11)	405 Cd 3d _{5/2} (7)	677 Th 4d _{5/2} (37)	980 Nd 3d _{5/2} (21)
51 Mg 2p	133 Sr 3d _{5/2} (2)	270 Cl 2s	410 Ni (A)	684 Cs (A)	981 Ru (A)
52 Os 4f, (3)	136 Eu 4d	279 Os 4d _{5/2} (15)	413 Pb 4d _{5/2} (22)	686 F 1s	993 C (A)
55 Fe 3p _{3/2} (1)	138 Pb 4f, (5)	282 Ru 3d _{5/2} (4)	435 Ne (A)	710 Fe 2p _{3/2} (13)	1003 K (A)
56 Li 1s	143 As 3p _{3/2} (5)	284 Tb 4p _{3/2} (33)	439 Ca 2s	711 Xe (A)	1005 Th (A)
57 Se 3d _{5/2} (1)	150 Tb 4d	287 C 1s	440 Sm (A)	715 Sn 3p _{3/2} (42)	1022 Zn 2p _{3/2} (23)
61 Co 3p _{3/2} (2)	153 Si 2s	293 Dy 4p _{3/2} (36)	443 Bi 4d _{5/2} (24)	724 Cs 3d _{5/2} (14)	1035 Ar (A)
62 Ir 4f, (3)	154 Dy 4d	293 K 2p _{3/2} (3)	445 In 3d _{5/2} (8)	729 Cr (A)	1071 Cl (A)
63 Xe 4d _{5/2} (2)	158 Y 3d _{5/2} (2)	297 Ir 4d _{5/2} (16)	458 Ti 2p _{3/2} (6)	737 I (A)	1072 Na 1s
64 Na 2s	159 Bi 4f, (5)	301 Y 3p _{3/2} (12)	463 Ru 3p _{3/2} (22)	739 U 4d _{5/2} (42)	1082 B (A)
67 Ni 3p _{3/2} (2)	161 Ho 4d	306 Ho 4p _{3/2} (39)	483 Co (A)	743 O (A)	1083 Sm 3d _{5/2} (27)
69 Br 3d _{5/2} (1)	163 Se 3p _{3/2} (6)	309 Rh 3d _{5/2} (5)	486 Sn 3d _{5/2} (8)	765 Te (A)	1088 Nb (A)
73 Pt 4f, (3)	165 S 2p _{3/2} (1)	316 Pt 4d _{5/2} (17)	498 Rh 3p _{3/2} (24)	784 V (A)	1103 S (A)
74 Al 2p	169 Er 4d	319 Ar 2s	501 Sc 2s	780 Ba 3d _{5/2} (15)	1117 Ga 2p _{3/2} (27)
75 Cs 4d _{5/2} (2)	180 Tm 4d	320 Er 4p _{3/2} (42)	515 V 2p _{3/2} (8)	781 Co 2p _{3/2} (15)	1136 Eu 3d _{5/2} (30)
77 Cu 3p _{3/2} (2)	181 Zr 3d _{5/2} (2)	331 Zr 3p _{3/2} (14)	519 Nd (A)	784 V (A)	1155 Bi (A)
85 Au 4f, (4)	182 Br 3p _{3/2} (7)	333 Tm 4p _{3/2} (45)	530 Sb 3d _{5/2} (9)	794 Sb (A)	1162 Pb (A)
87 Zn 3p _{3/2} (3)	185 Yb 4d _{5/2} (9)	335 Th 4f _{7/2} (9)	531 O 1s	819 Sn (A)	1169 Ti (A)
88 Kr 3d _{5/2} (1)	189 Ga (A)	336 Au 4d _{5/2} (18)	534 Pd 3p _{3/2} (27)	822 Te 3p _{3/2} (51)	1176 Hg (A)
90 Ba 4d _{5/2} (2)	191 B 1s	337 Pd 3d _{5/2} (5)	553 Fe (A)	834 La 3d _{5/2} (17)	1184 Au (A)
90 Mg 2s	191 P 2s	337 Cu (A)	555 Pr (A)	839 Ti (A)	1186 Gd 3d _{5/2} (33)
100 Hg 4f, (4)	197 Lu 4d _{5/2} (10)	342 Yb 4p _{3/2} (50)	565 Ti 2s	846 In (A)	1192 Pt (A)
101 La 4d _{5/2} (3)	199 Cl 2p _{3/2} (2)	347 Ca 2p _{3/2} (3)	573 Ag 3p _{3/2} (31)	855 Ni 2p _{3/2} (18)	

An A in parentheses denotes Auger line. Numbers in parentheses are spin doublet separations in electron volts. The sharpest Auger line and the two most intense photoelectron lines per element are included in the table. For brevity, 2p_{1/2} equals 2p₂, 3d_{5/2} equals 3d_{5/2}, etc.

Survey spectra: example 1

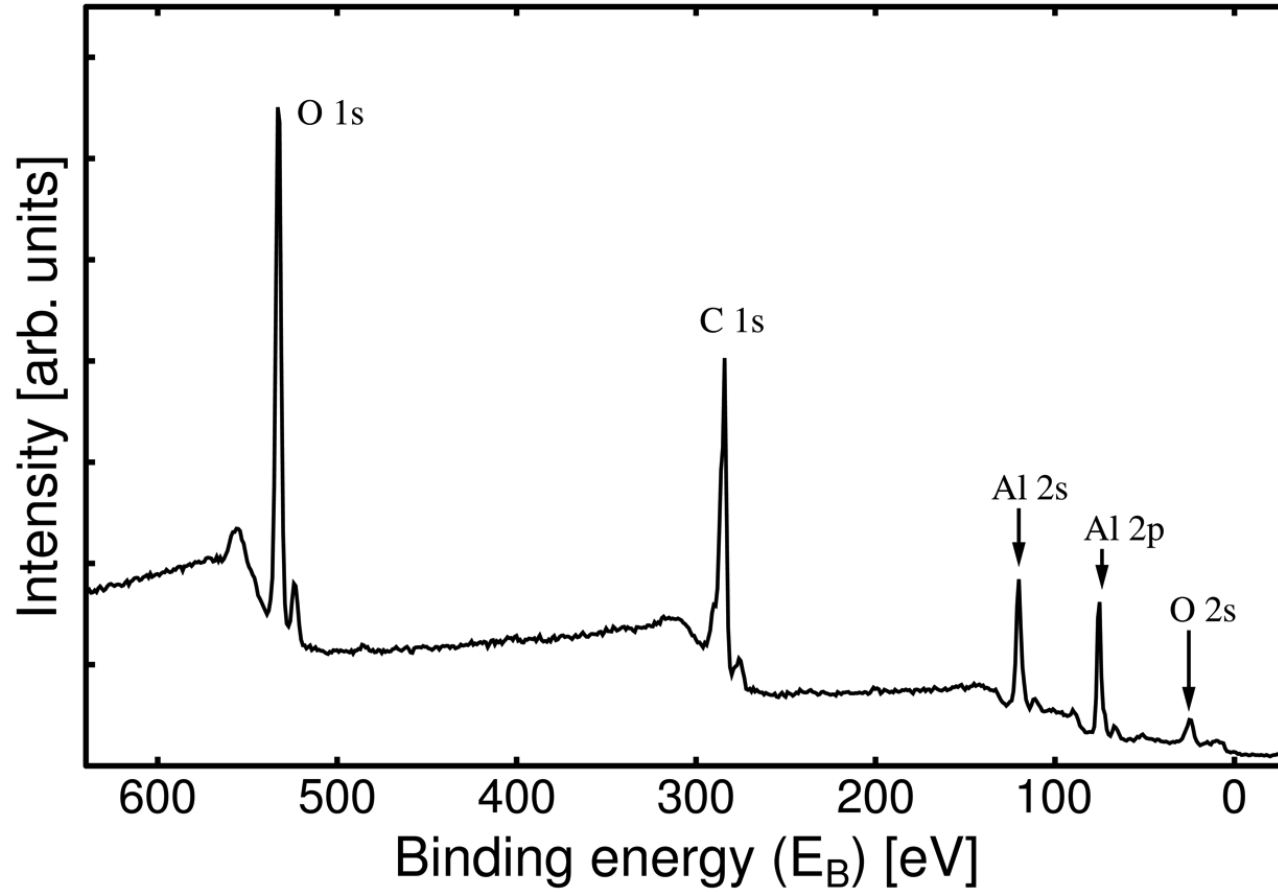
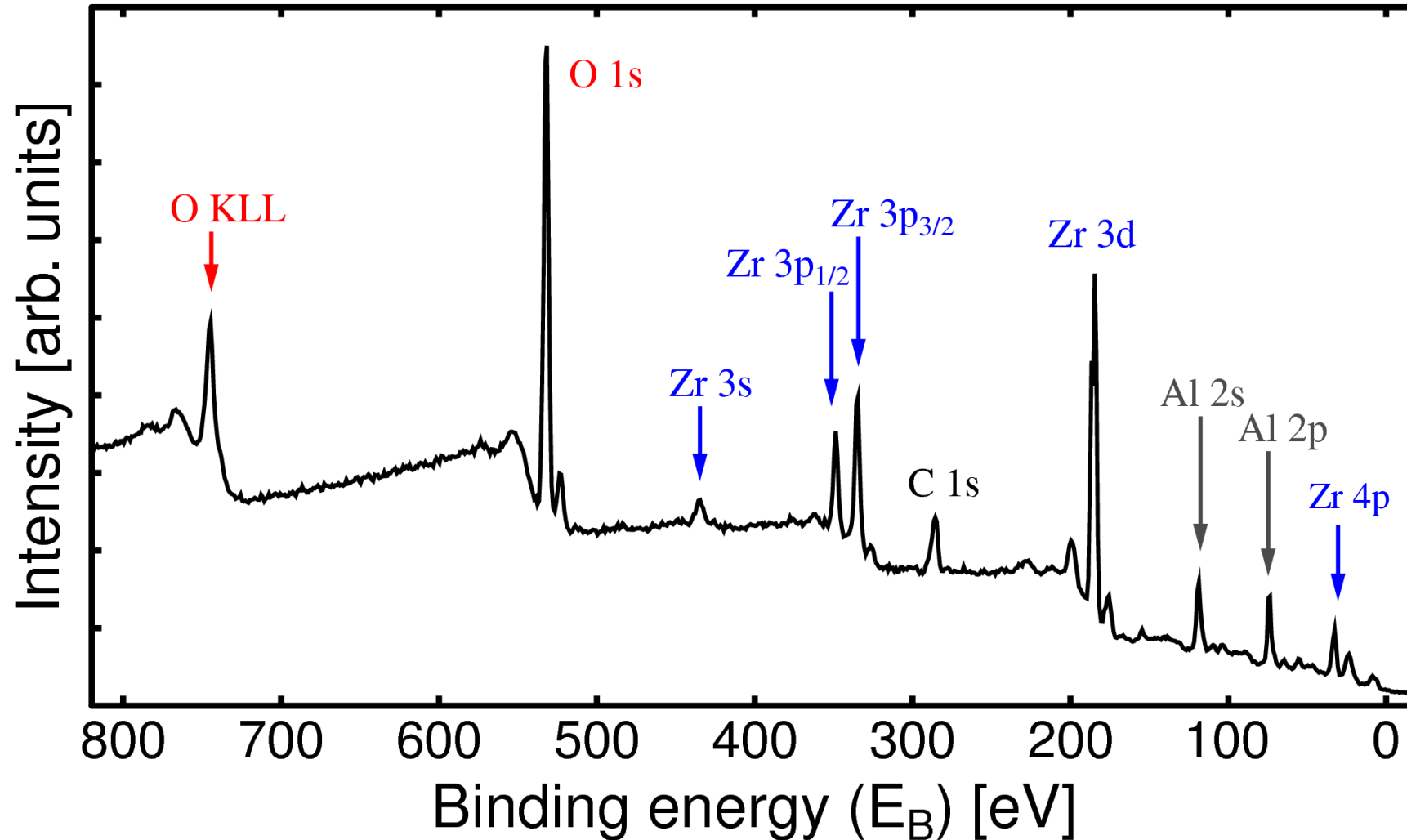


Table 3. Line Positions from Mg X-rays, in eV

17 Hf 4f ₇ (2)	102 Si 2p ₃ (1)	206 Nb 3d ₅ (3)	359 Lu 4p ₃ (53)
23 O 2s	105 Ga 3p ₃ (3)	208 Kr 3p ₃ (8)	359 Hg 4d ₅ (20)
25 Ta 4f ₇ (2)	108 Ce 4d ₅ (4)	213 Hf 4d ₅ (11)	362 Gd (A)
30 F 2s	110 Rb 3d ₅ (1)	229 S 2s	364 Nb 3p ₃ (15)
31 Ge 3d ₅ (1)	113 Be 1s	229 Ta 4d ₅ (12)	368 Ag 3d ₅ (6)
34 W 4f ₇ (2)	113 Ge (A)	230 Mo 3d ₅ (3)	378 K 2s
40 V 3p	114 Pr 4d	238 Rb 3p ₃ (9)	380 U 4f ₇ (11)
41 Ne 2s	118 Tl 4f ₇ (4)	241 Ar 2p ₃ (2)	385 Tl 4d ₅ (21)
43 Re 4f ₇ (2)	119 Al 2s	245 W 4d ₅ (12)	396 Mo 3p ₃ (17)
44 As 3d ₅ (1)	120 Nd 4d	263 Re 4d ₅ (14)	402 N 1s
45 Cr 3p ₃ (1)	124 Ge 3p ₃ (4)	264 Na (A)	402 Eu (A)
48 Mn 3p ₃ (1)	132 Sm 4d	265 Zn (A)	402 Sc 2p ₃ (5)
50 I 4d ₅ (2)	133 P 2p ₃ (1)	269 Sr 3p ₃ (11)	405 Cd 3d ₅ (7)
51 Mg 2p	133 Sr 3d ₅ (2)	270 Cl 2s	410 Ni (A)
52 Os 4f ₇ (3)	136 Eu 4d	279 Os 4d ₅ (15)	413 Pb 4d ₅ (22)
55 Fe 3p ₃ (1)	138 Pb 4f ₇ (5)	282 Ru 3d ₅ (4)	435 Ne (A)
56 Li 1s	143 As 3p ₃ (5)	284 Tb 4p ₃ (33)	439 Ca 2s
57 Se 3d ₅ (1)	150 Tb 4d	287 C 1s	440 Sm (A)
61 Co 3p ₃ (2)	153 Si 2s	293 Dy 4p ₃ (36)	443 Bi 4d ₅ (24)
62 Ir 4f ₇ (3)	154 Dy 4d	295 K 2p ₃ (3)	445 In 3d ₅ (8)
63 Xe 4d ₅ (2)	158 Y 3d ₅ (2)	297 Ir 4d ₅ (16)	458 Ti 2p ₃ (6)
64 Na 2s	159 Bi 4f ₇ (5)	301 Y 3p ₃ (12)	463 Ru 3p ₃ (22)
67 Ni 3p ₃ (2)	161 Ho 4d	306 Ho 4p ₃ (39)	483 Co (A)
69 Br 3d ₅ (1)	163 Se 3p ₃ (6)	309 Rh 3d ₅ (5)	486 Sn 3d ₅ (8)
73 Pt 4f ₇ (3)	165 S 2p ₃ (1)	316 Pt 4d ₅ (17)	498 Rh 3p ₃ (24)
74 Al 2p	169 Er 4d	319 Ar 2s	501 Sc 2s
75 Cs 4d	180 Tm 4d	320 Er 4p ₃ (42)	515 V 2p ₃ (8)
77 Cu 3p ₃ (2)	181 Zr 3d ₅ (2)	331 Zr 3p ₃ (14)	519 Nd (A)
85 Au 4f ₇ (4)	182 Br 3p ₃ (7)	333 Tm 4p ₃ (45)	530 Sb 3d ₅ (9)
87 Zn 3p ₃ (3)	185 Yb 4d ₅ (9)	335 Th 4f ₇ (9)	531 O 1s
88 Kr 3d ₅ (1)	189 Ga (A)	336 Au 4d ₅ (18)	534 Pd 3p ₃ (27)
90 Ba 4d ₅ (2)	191 B 1s	337 Pd 3d ₅ (5)	553 Fe (A)
90 Mg 2s	191 P 2s	337 Cu (A)	555 Pr (A)
100 Hg 4f ₇ (4)	197 Lu 4d ₅ (10)	342 Yb 4p ₃ (50)	565 Ti 2s
101 La 4d ₅ (3)	199 Cl 2p ₃ (2)	347 Ca 2p ₃ (3)	573 Ag 3p ₃ (31)

An A in parentheses denotes Auger line. Numbers in parentheses are spin doublet separations in electron volts. The photoelectron lines per element are included in the table. For brevity, 2p₃ equals 2p_{3/2}, 3d₅ equals 3d_{5/2}, etc.

Example 2



XPS

X-Ray Photoelectron Spectroscopy

OUTLINE:

1. Background
 1. Phenomenon
 2. Instrumentation
2. Typical measurement data
 1. Qualitative analysis & spectral features
 2. Peak identification
3. Analysis and results
 1. Quantitative analysis & effects of sample
 2. Chemical environment & peak fitting
4. Technical issues & Auxiliary features
 1. Ion beam sputtering & depth profiling
 2. Angle resolved XPS
 3. Surface charging & energy calibration
 4. Small area analysis and imaging

Quantification

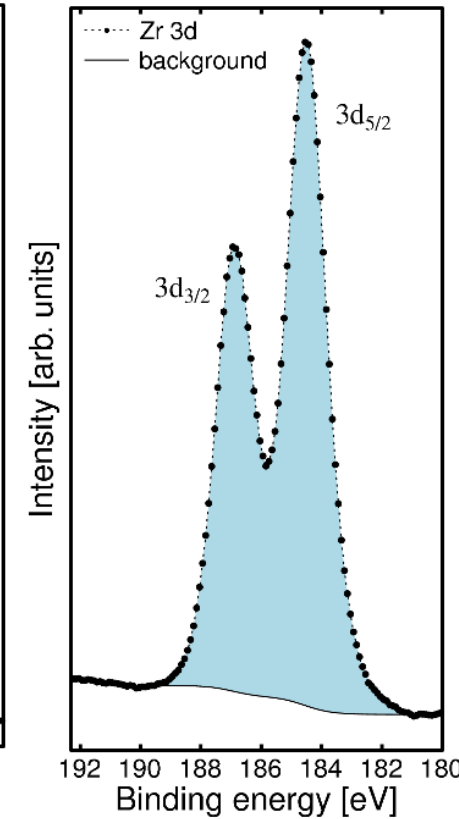
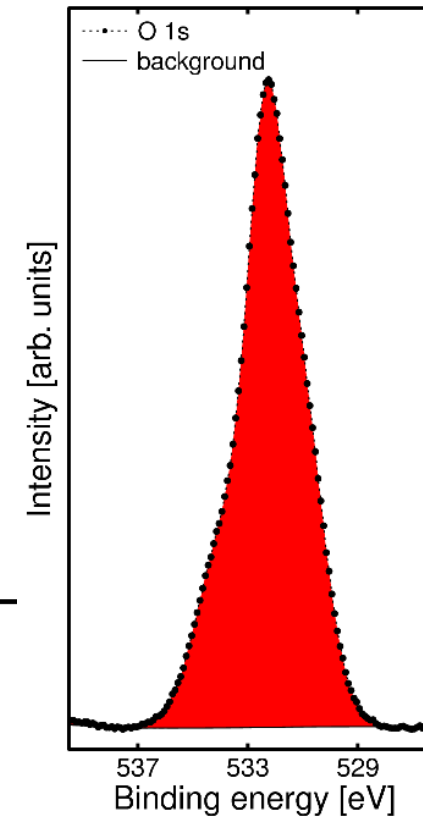
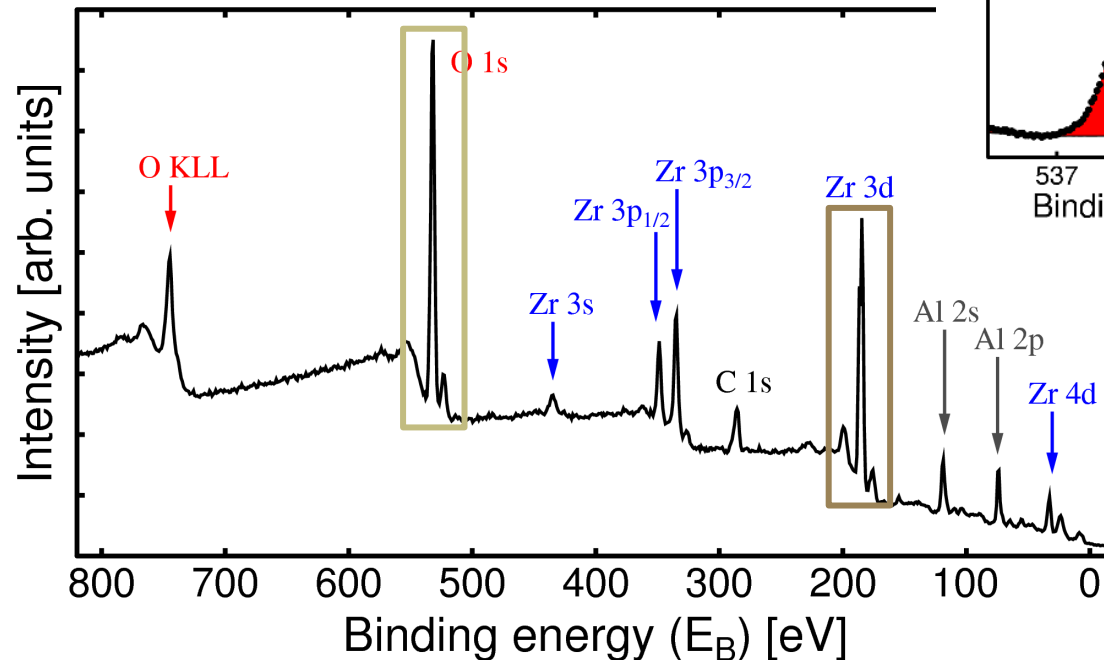
Peak intensity related to relative surface concentration:

$$I_i \propto N_i a_i$$

- I_i = peak intensity
- N_i = atomic concentration
- a_i = atomic sensitivity factor
- Stoichiometry can be calculated using intensities and sensitivity factors
- Peak areas best measure of intensity

For multi-element surface layer:

$$N_A = \frac{I_A / a_A}{\sum_i I_i / a_i}$$



Stoichiometry:

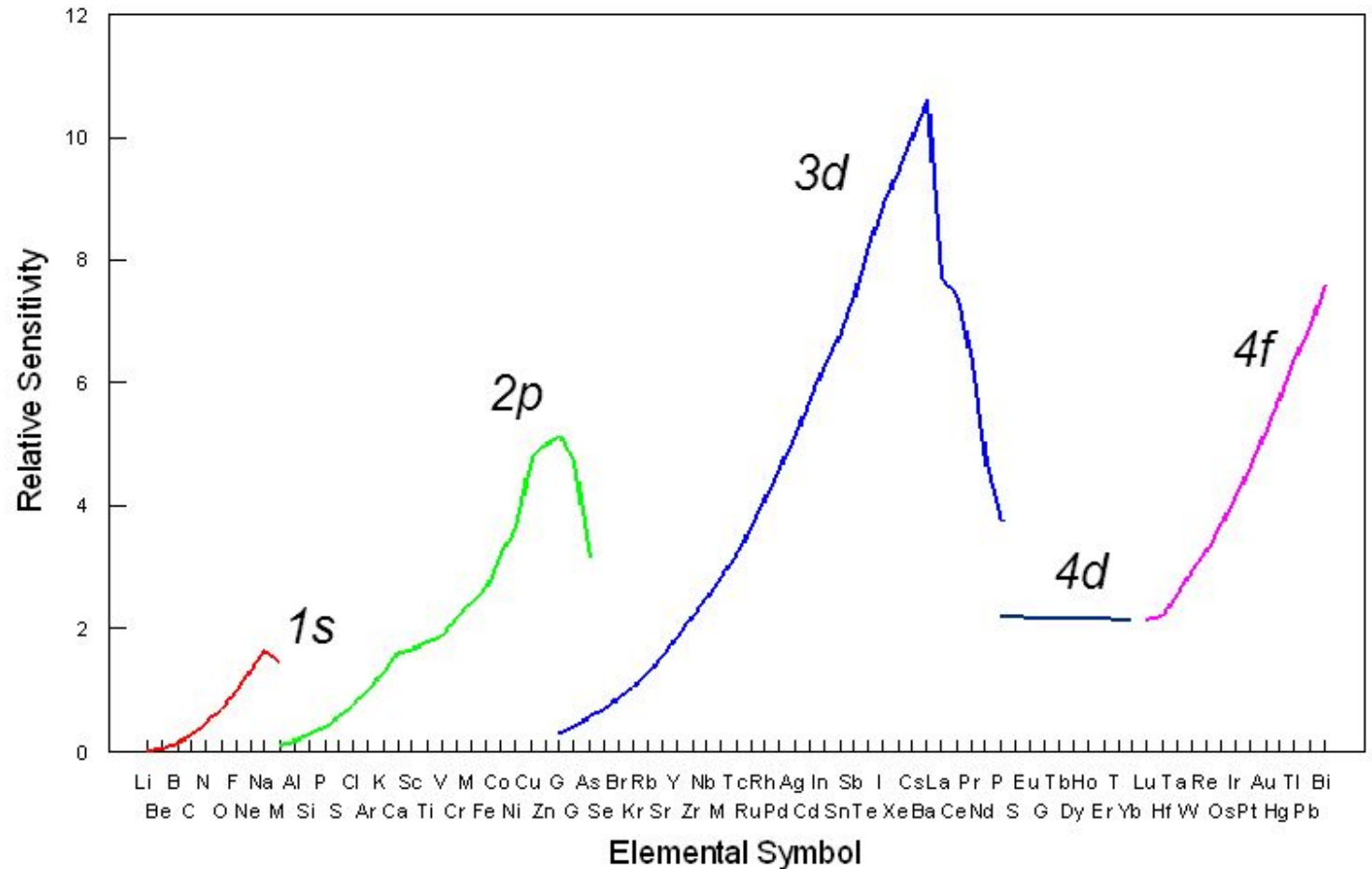
Zr: 12.56 %
 Al: 28.10 %
 O: 41.46 %
 C: 17.77 %

Atomic sensitivity factors (ASF)

Combination of several factors:

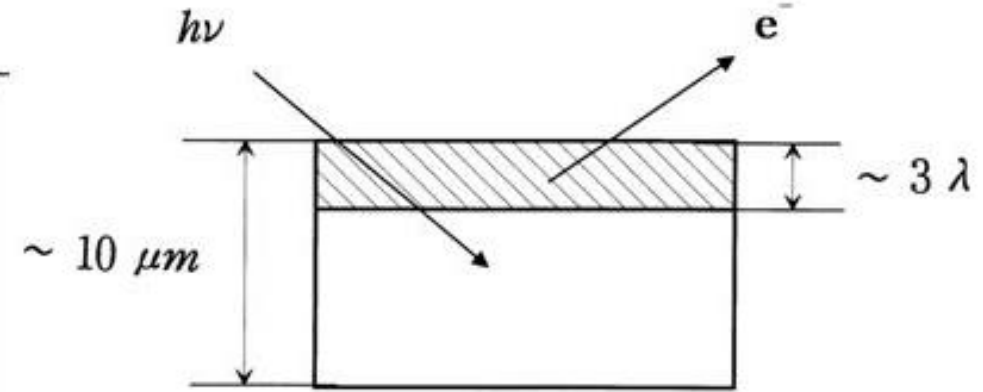
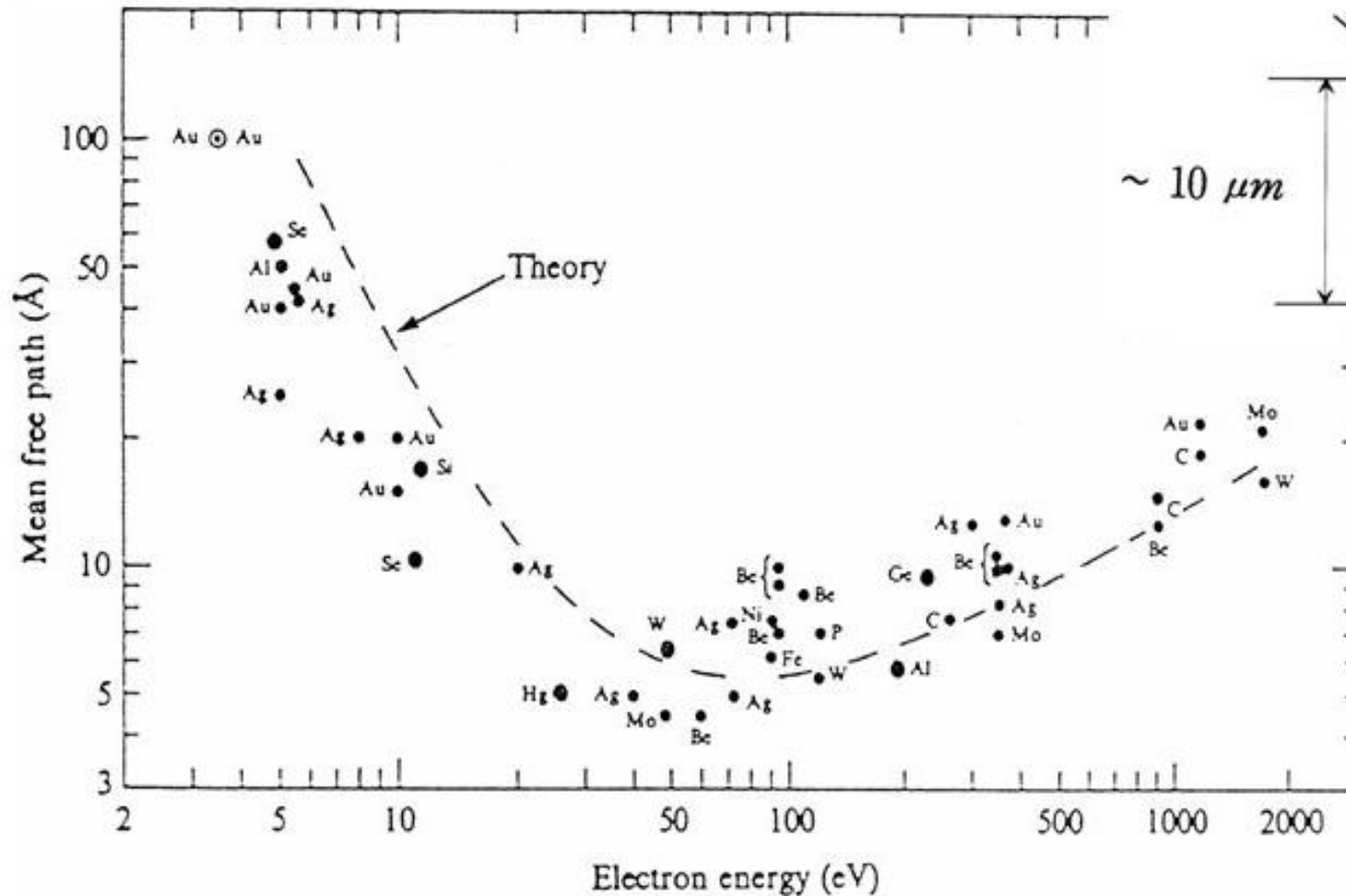
$$a_i = \sigma_i \lambda_i$$

- σ_i : Scofield cross-sections (probability of X-ray producing photoelectron)
- λ_i : inelastic mean free path of photoelectron (likelihood electron will make it to the surface)
- ASF:s will vary greatly for different elements



Inelastic mean free path

$$I = I_0 e^{-\frac{d}{\lambda}}$$



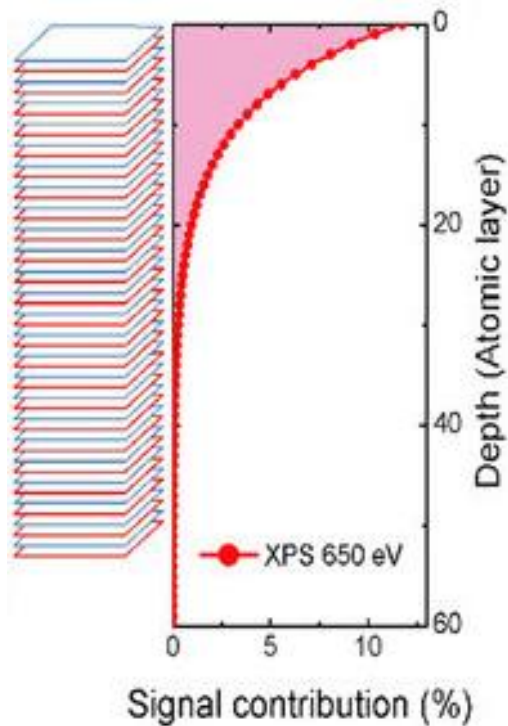
- 63 % of all electrons scattered within one λ
- 95 % scattered in 3λ – **sampling depth**

Loss processes:

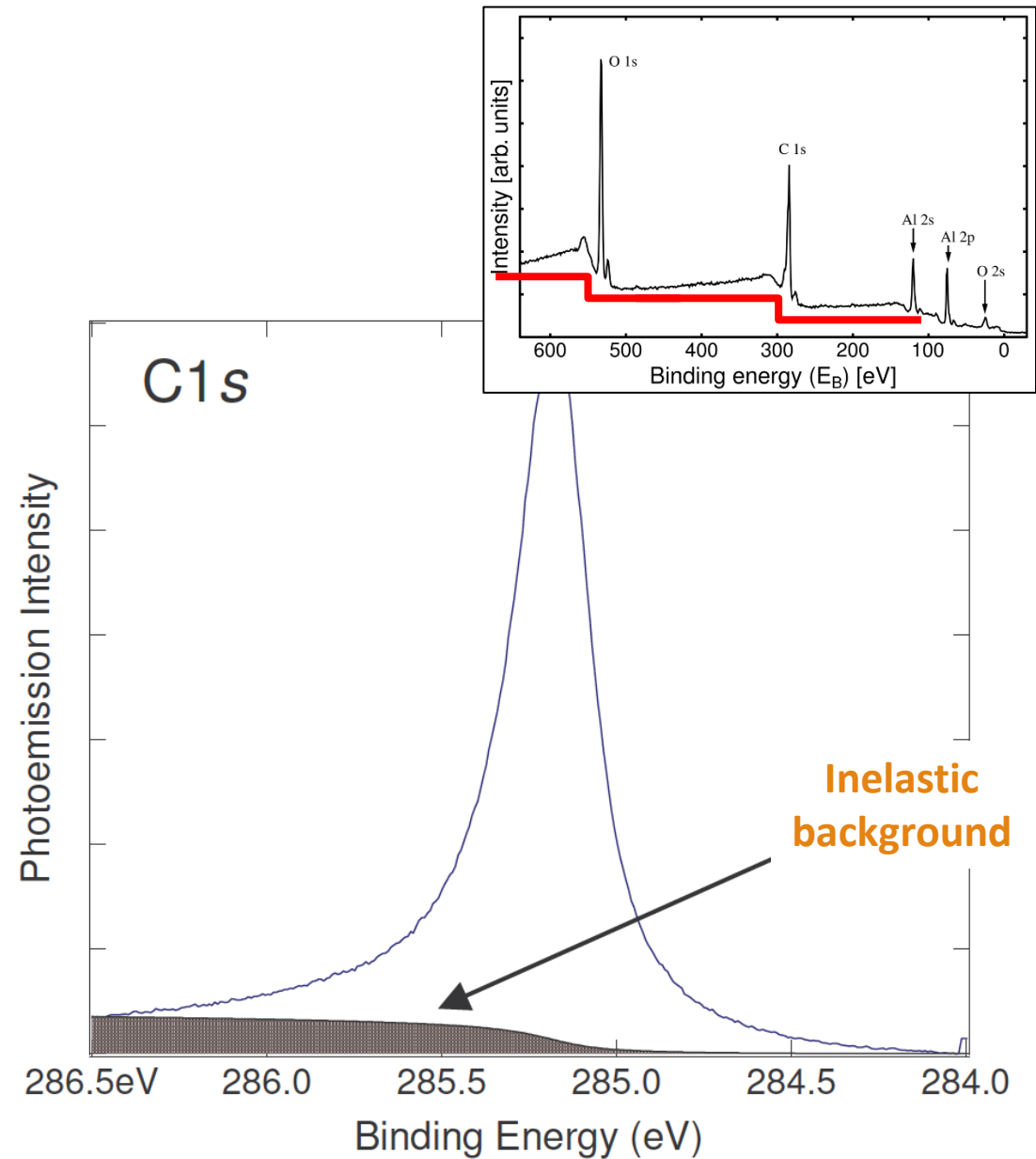
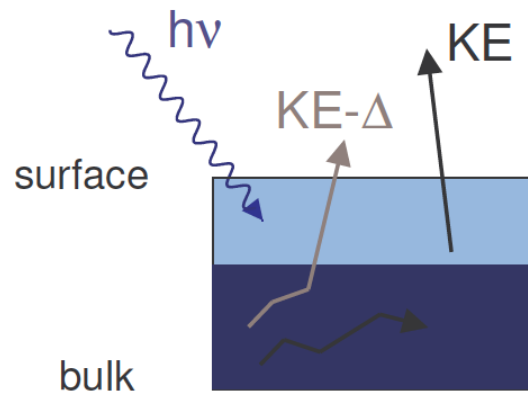
- Phonons: collective excitations of atoms (10 meV – 10 eV)
- Plasmons: collective excitations of electrons (5 eV – 20 eV)
- One electron excitations (50 eV –)

Inelastic background

- Core level peaks only account for a small part of all measured photoelectrons
- Exponential decrease in intensity with depth of photoionization



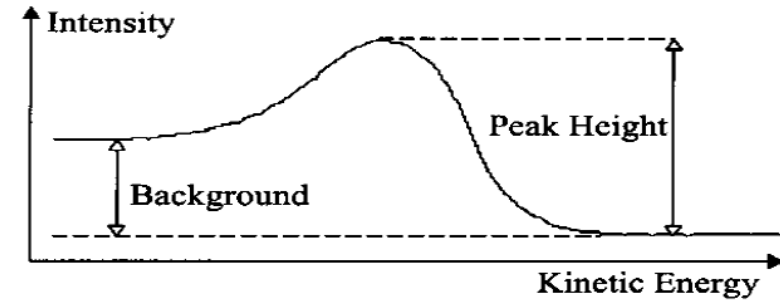
- Scattering losses result in a large increase in photoelectron intensity directly after each core level peak
- Inelastic background**



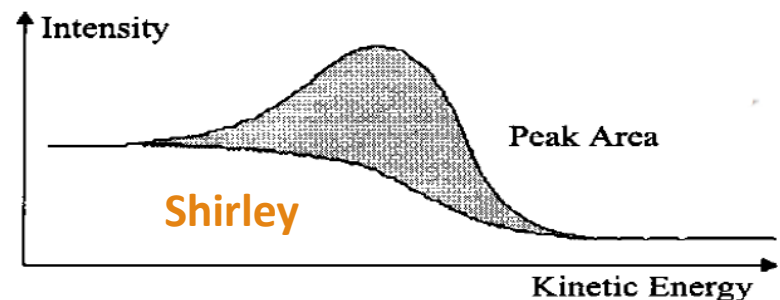
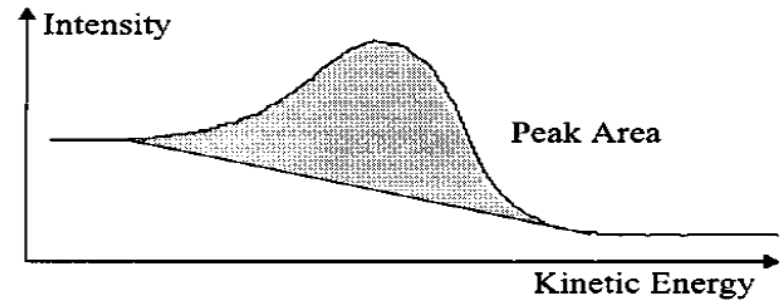
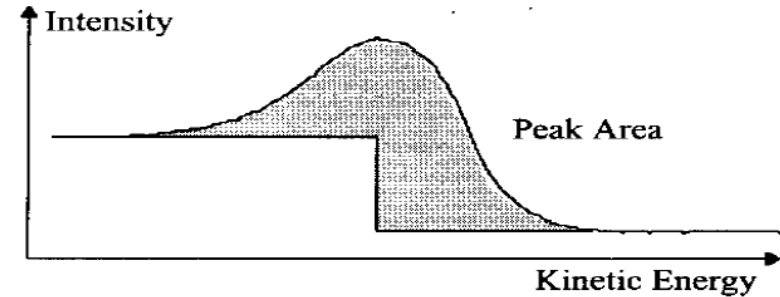
Background removal

How is peak intensity measured?

- Peak heights can sometimes be used
- Result not very good – shapes not always the same
- **Area** is almost always used
- But background is not constant (nor linear) near peak
- **Shirley** background is most commonly used
- With ASF's: accuracy better than 15 %
- With standard samples on same instrument: ~5 %
- Reproducibility (precision) better than 2 %



Worst



Best

Surface morphologies

Traditional XPS quantification assumes:

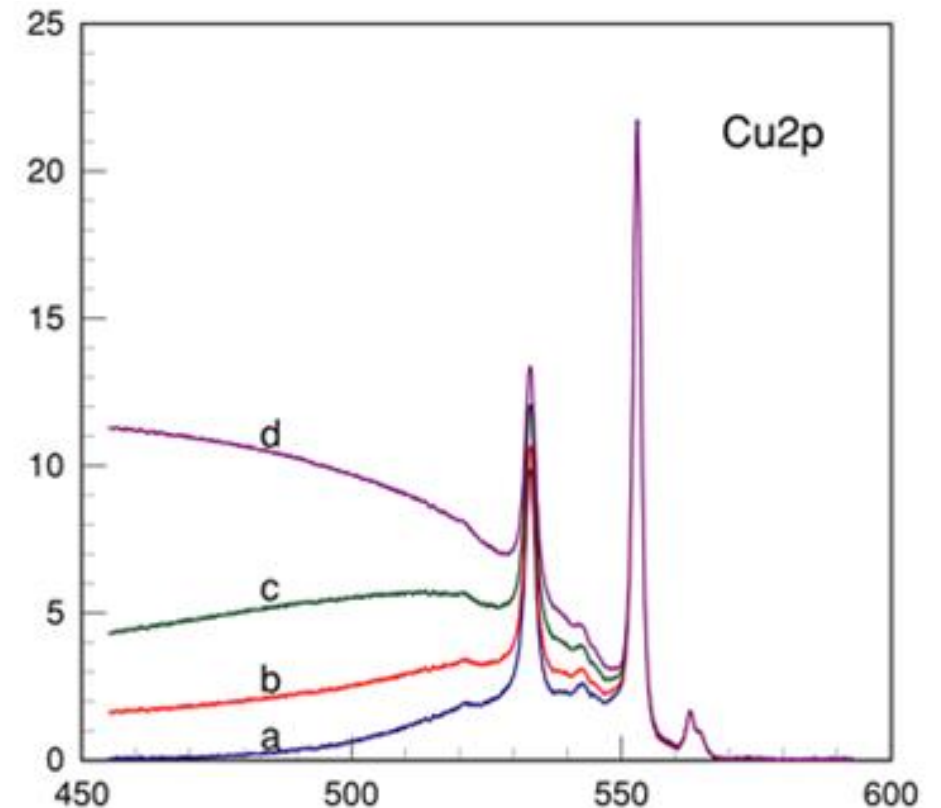
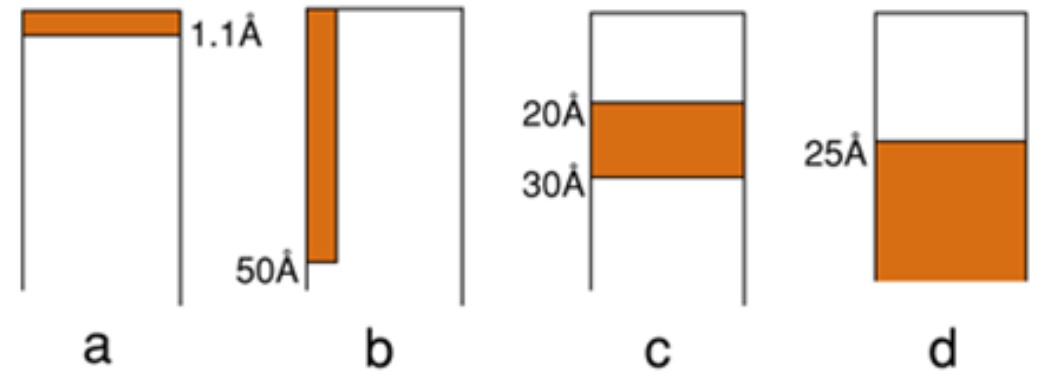
- Outer surface of sample is homogeneous
- Outer surface concentration is directly proportional to the main peak intensity

However, at a certain energy detected photoelectrons result from two processes:

- *Intrinsic* electrons: energy from photoelectron process
- *Extrinsic* electrons: energy resulting from multiple scattering events (initial energy same as intrinsic)

Depending on the depth and lateral distribution of emitting atoms the extrinsic portion will change dramatically

- Extrinsic part (background) can give information on morphology, e.g. continuous film, clusters, etc...



XPS

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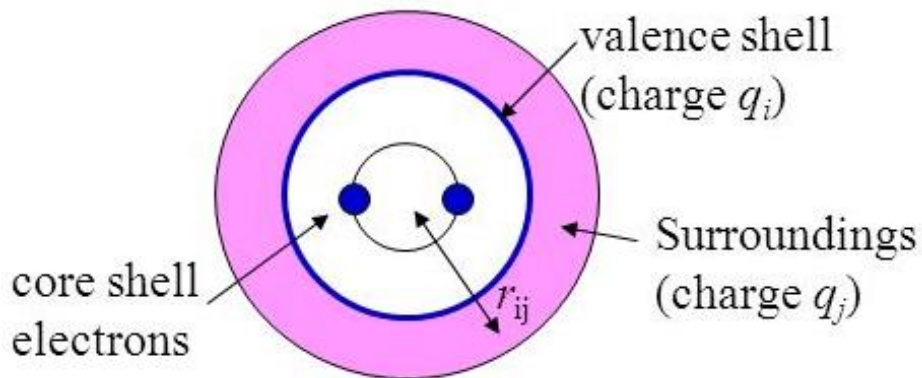
Chemical effect in XPS

Chemical shift:

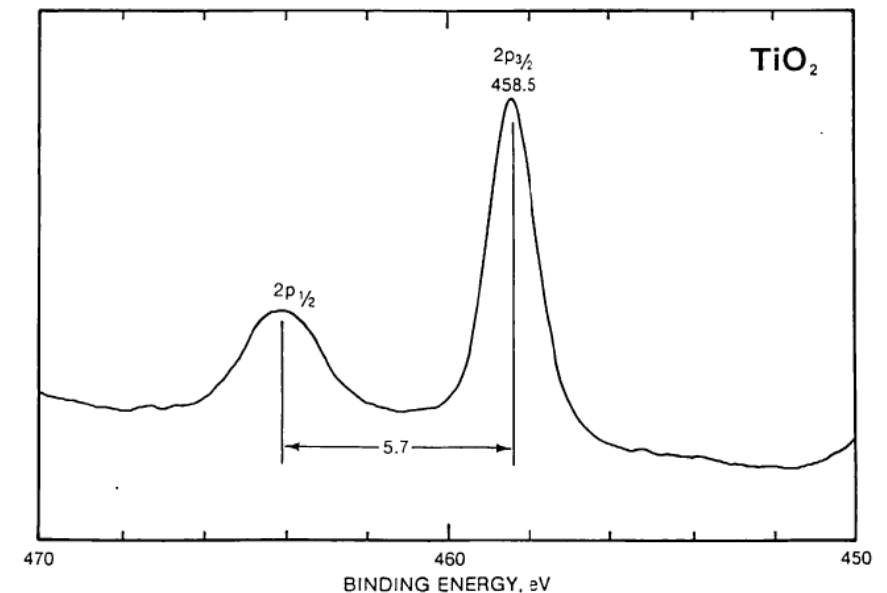
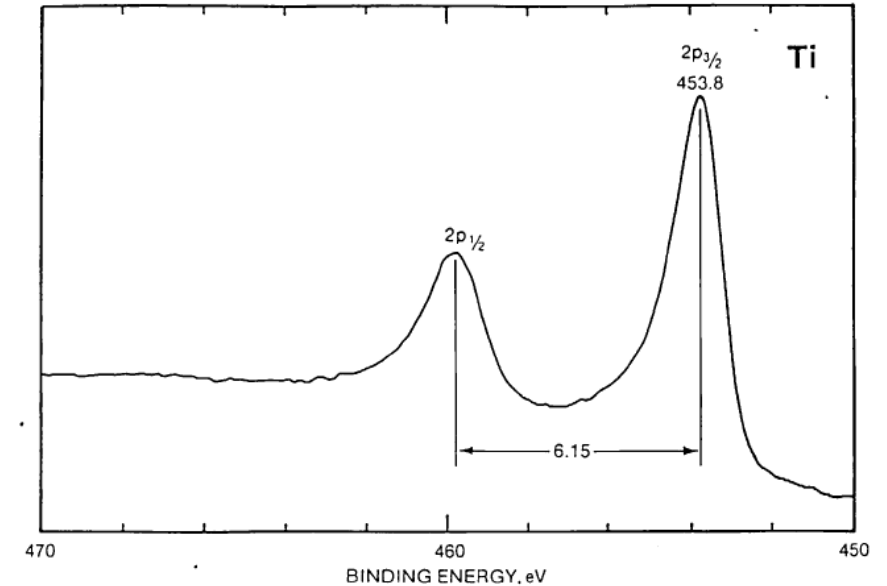
- Changes in the chemical bonding of an element will cause changes in the binding energy of core electrons

Core binding energies are determined by:

- Electrostatic interaction between electron and nucleus
- All other electrons (including valence) shield nuclear charge
- Removal or addition of electronic charge will alter this shielding



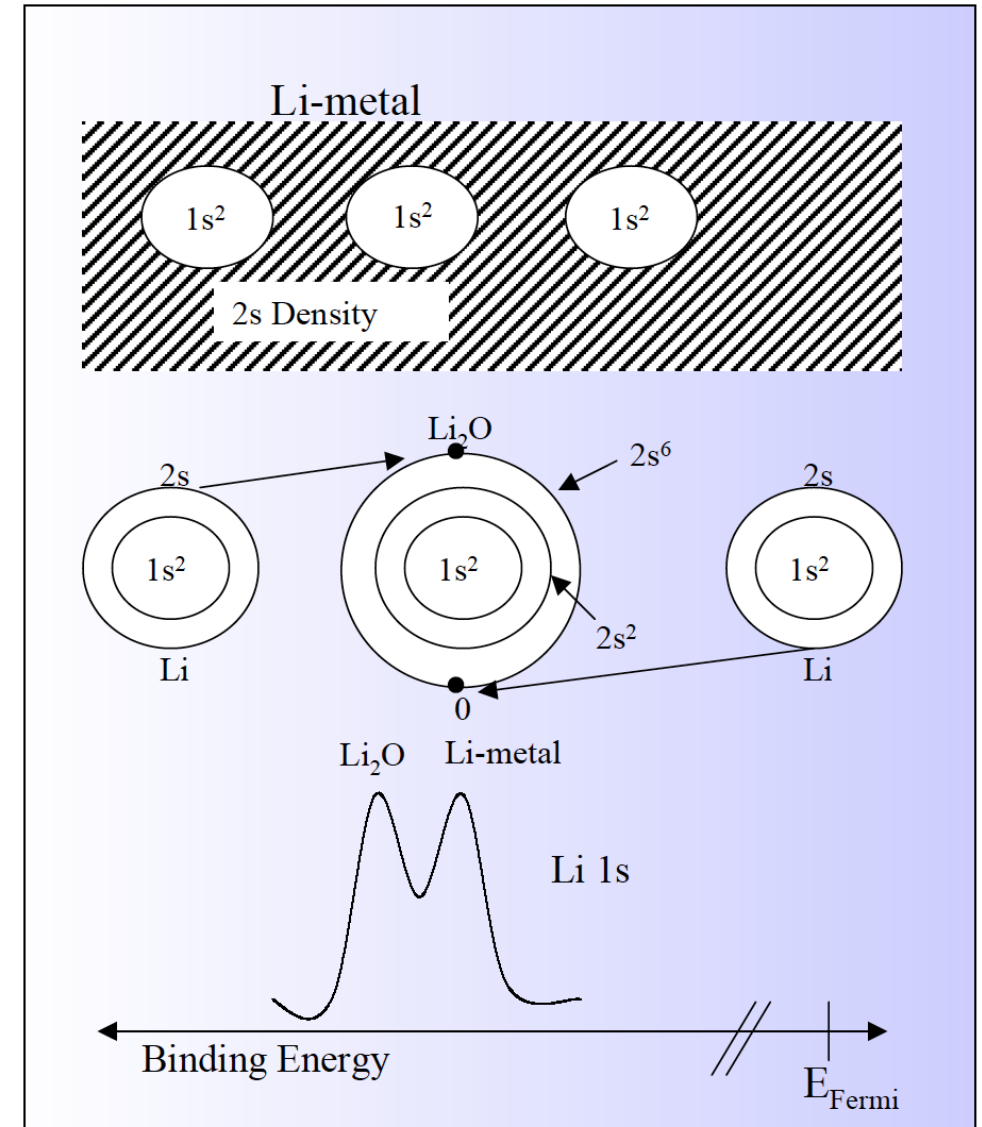
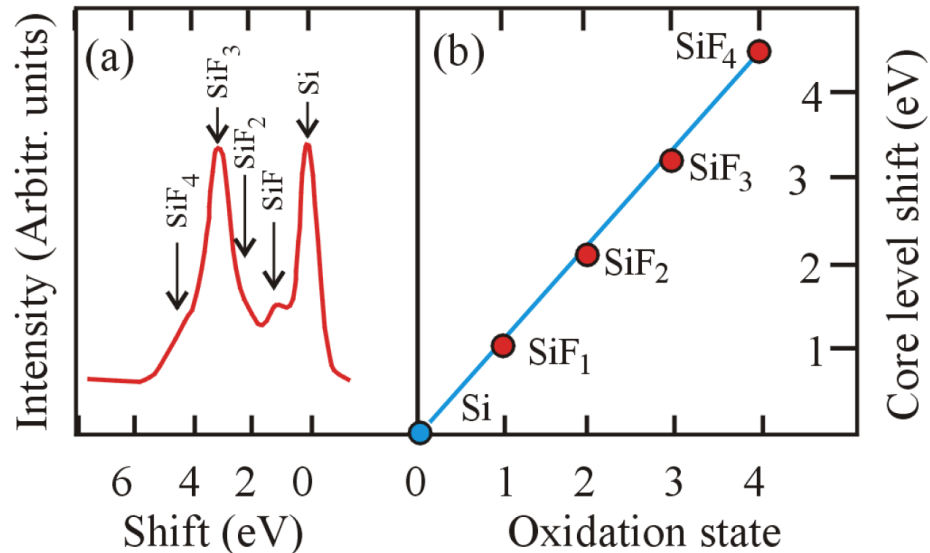
- Withdrawal of negative charge (oxidation) – increase in E_b
- Addition of negative charge – decrease in E_b



Chemical shift

Oxides compared to metals:

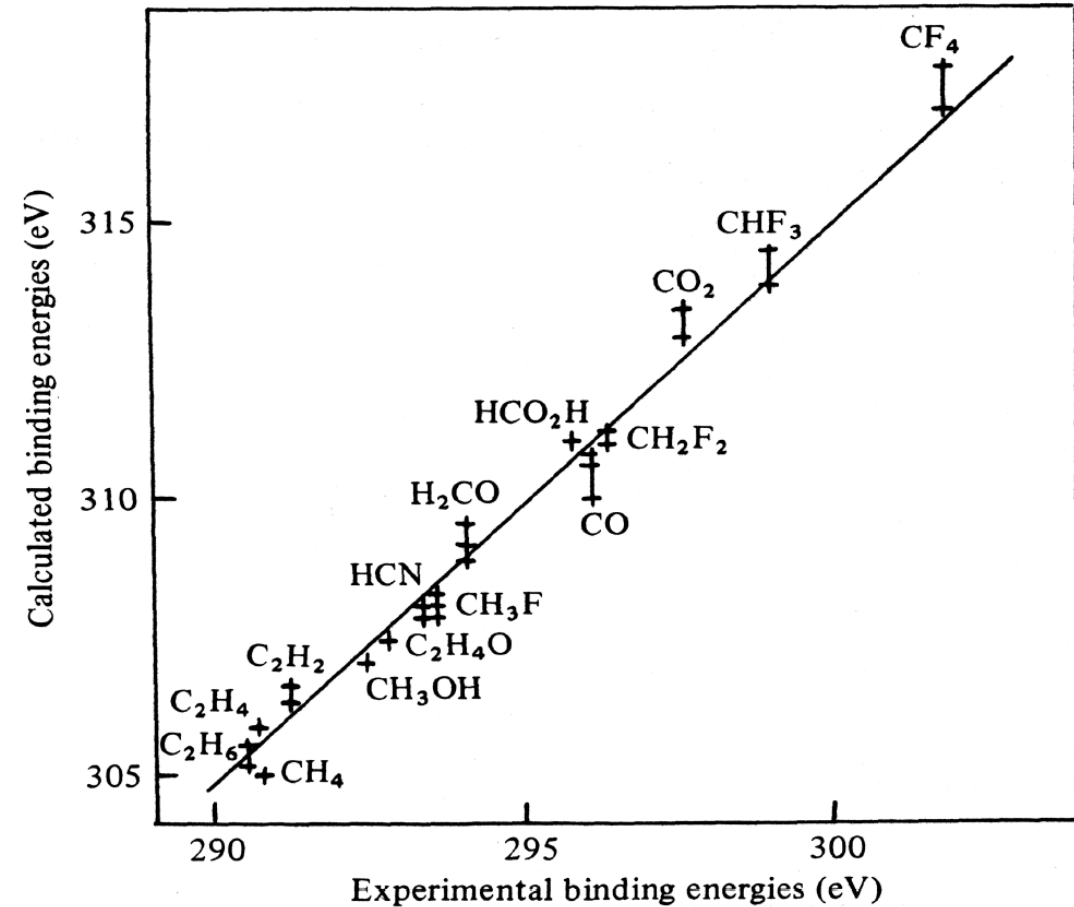
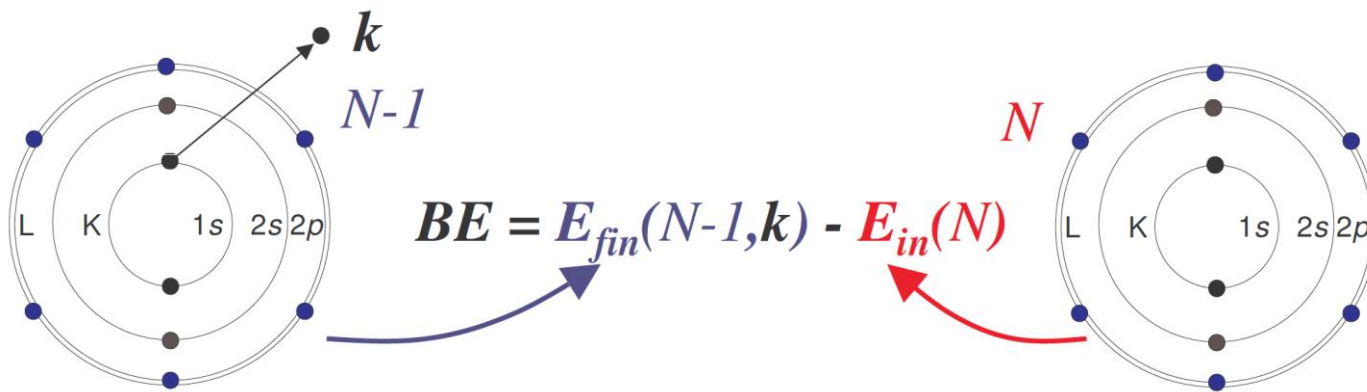
- Binding energy is lower in pure metals due to screening by conduction electrons
- Binding energy higher in metal oxides because electron density is lost to oxygen
- Ionic compounds: binding energy shift 1 eV / oxidation state!



Calculations – Koopman's theorem

The binding energy of an electron is simply the difference between the initial state and the final state

- (atom with n electrons) - (atom with $n-1$ electrons and free electron)
- Only works if no electronic rearrangement followed photoemission
- Can be calculated with Hartree-Fock methods



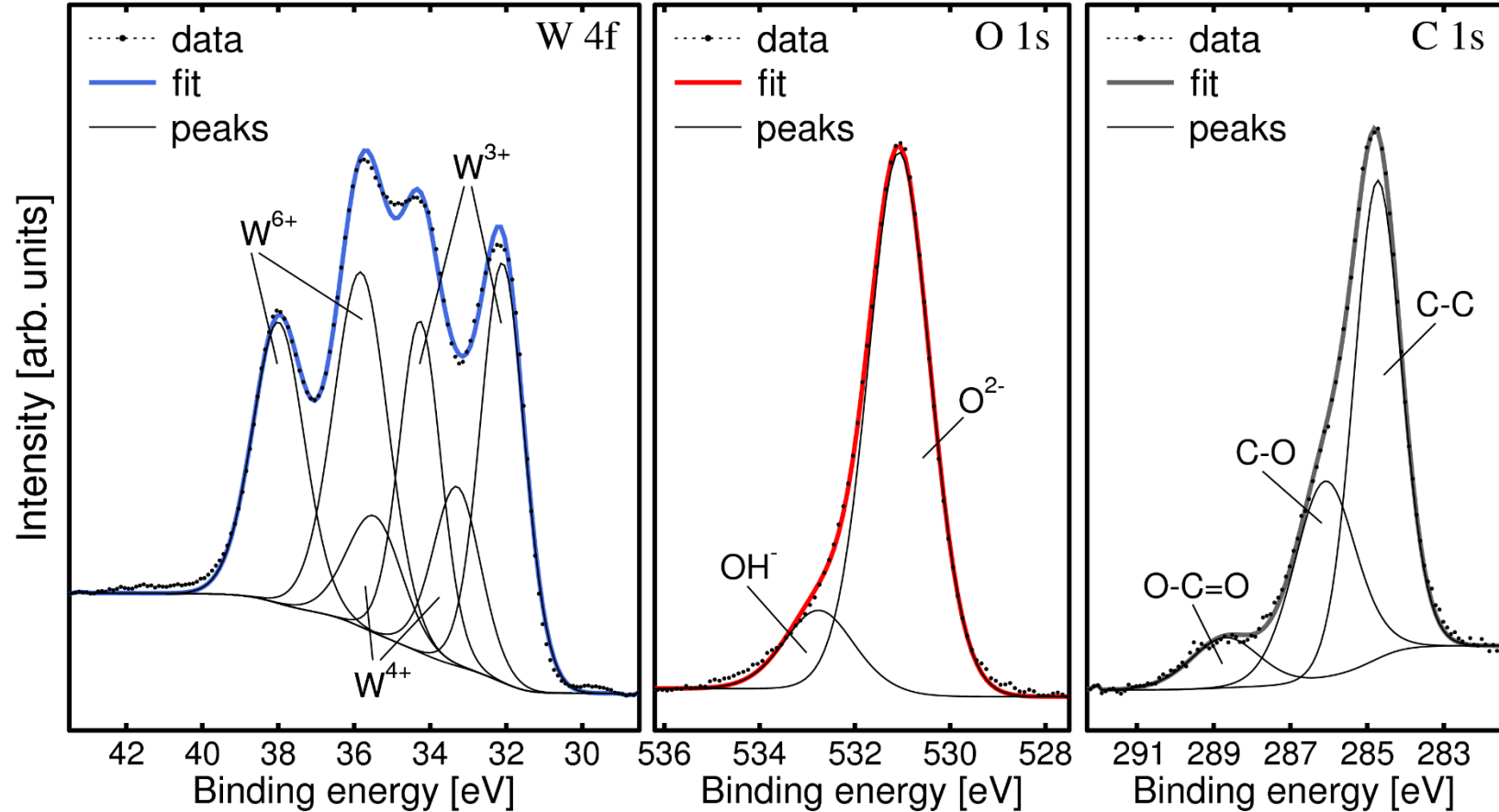
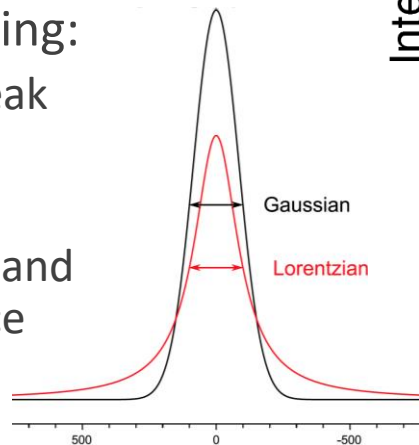
Peak fitting

Measured peaks usually contain signals from atoms in many different chemical environments

- Chemical species can be deconvoluted from spectra using peak fitting algorithms
- Gaussian (70 %) – Lorentzian (30 %) peak shapes (other GL ratios also common)

Useful in peak fitting:

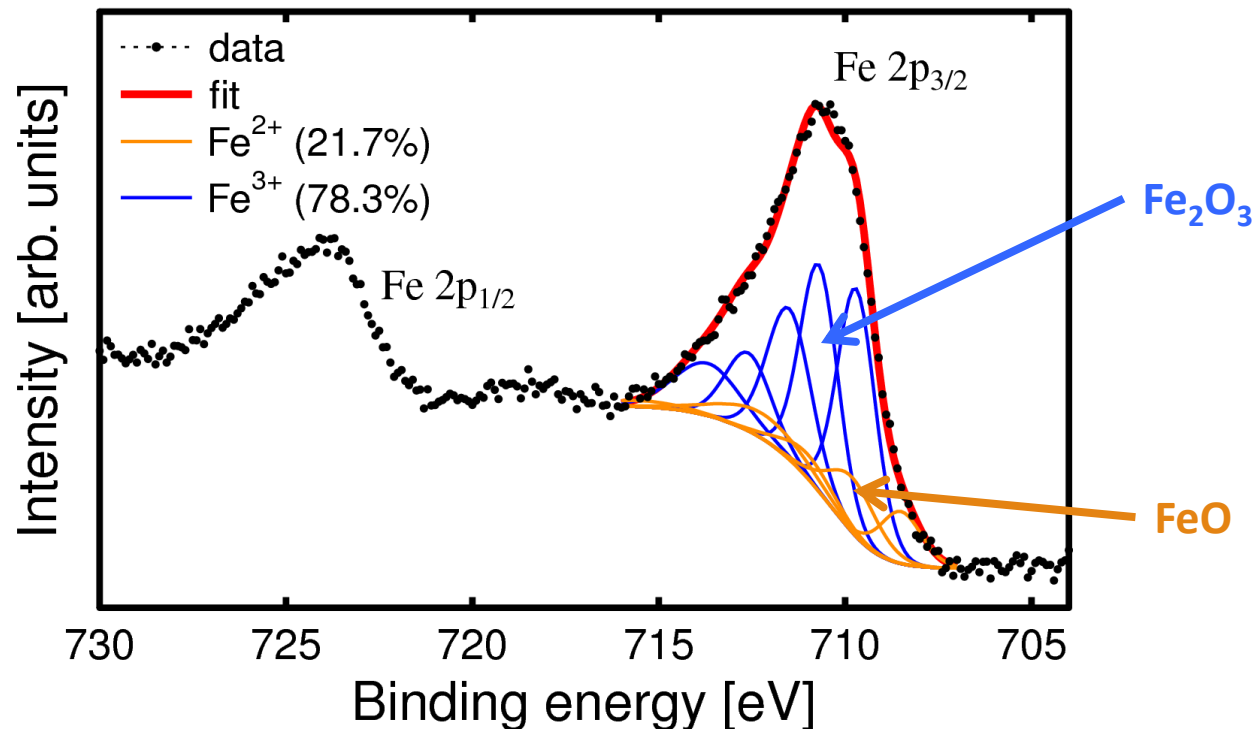
- Fixed ΔE_b and peak area ratios for doublets
- Known energies and FWHM (reference data)



Multiplet splitting

Complex peak shapes are typical for many materials

- Usually occurs if there is one (or more) unpaired valence electron(s)
- A single compound will result in an asymmetric peak shape
- Several GL peaks have to be fitted in order to get reproducibility



COMPOUND	2p _{3/2} BINDING ENERGY, eV			REF.
	705	710	715	
Fe				Φ
Fe ₂ B				MEC
FeB				MEC
FeS ₂				B4
Fe(C ₅ H ₅) ₂				CDH
Fe(C ₅ H ₅) ₂ I ₃				CDH
Zn ₂ Fe(CN) ₆				CSC
K ₄ Fe(CN) ₆				CSC
K ₄ Fe(CN) ₆				V
Na ₃ Fe(CN) ₅ N ₂				YN2
Na ₂ Fe(CN) ₅ NO				YN2
K ₃ Fe(CN) ₆				V
Fe ₂ P ₂ S ₆				B4
KFeS ₂				B4
FeS				CSC
Fe(CO) ₅				BC1
Fe(CO) ₂ (NO) ₂				BC1
Fe(C ₅ H ₅)(CO) ₃ BPh ₄				CDH
FeO				MZ
FeO				AC2
Fe ₂ O ₃				Φ
Fe ₂ O ₃				MZ
Fe ₂ O ₃				AC2
FeOOH				AC2
FeOOH				MZ
Fe ₃ O ₄				AC2
NaFeO ₂				AC2
NiFe ₂ O ₄				MZ
FeBr ₂				CSC
FeBr ₃				CSC
FeCl ₂				CSC
FeCl ₃				CSC
FeF ₂				CSC
FeF ₃				CSC
K ₃ FeF ₆				CSC

NIST database

National Institute of Standards and Technology

- srdata.nist.gov/xps/
- Large database with reference XPS data
- Very useful for determining chemical states
- Literature references for all given data

- [Introduction](#)
- [Search Menu](#)
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NIST X-ray Photoelectron Spectroscopy Database

NIST Standard Reference Database 20, Version 4.1

Data compiled and evaluated by

Alexander V. Naumkin, Anna Kraut-Vass, Stephen W. Gaarenstroom, and Cedric J. Powell

Co	2p3/2	[N(C2H5)4]2CoBr4	780.10	Click
Co	2p3/2	[N(C2H5)4]2CoCl4	780.60	Click
Co	2p3/2	[N(C4H9)4]2[Co(NCC(S)C(S)CN)2]	780.00	Click
Co	2p3/2	[N(C4H9)4]2[Co(NCC(S)C(S)CN)2]	780.20	Click
Co	2p3/2	[N(CH3)4]2[CoSe(CN)4]	779.40	Click
Co	2p3/2	Al2CoO4	781.10	Click
Co	2p3/2	Al2CoO4	780.60	Click
Co	2p3/2	Al2CoO4	780.80	Click
Co	2p3/2	Co	778.30	Click
Co	2p3/2	Co	777.90	Click
Co	2p3/2	Co	778.32	Click
Co	2p3/2	Co	778.50	Click
Co	2p3/2	Co	778.10	Click
Co	2p3/2	Co	778.50	Click
Co	2p3/2	Co	778.20	Click
Co	2p3/2	Co	777.80	Click
Co	2p3/2	Co	778.00	Click
Co	2p3/2	Co	778.30	Click
Co	2p3/2	Co((C6H5)3PO)2(NO3)2	781.20	Click
Co	2p3/2	Co(NH3)6Cl3	781.10	Click
Co	2p3/2	Co(NH3)6Cl3	782.20	Click

Step 1. Choose type of data:

- Binding Energy
- Auger Kinetic Energy
- Auger Parameter
- Doublet Separation
- Surface/Interface Core-Level Shift
- Chemical Shift:

[Go to Step 2](#)

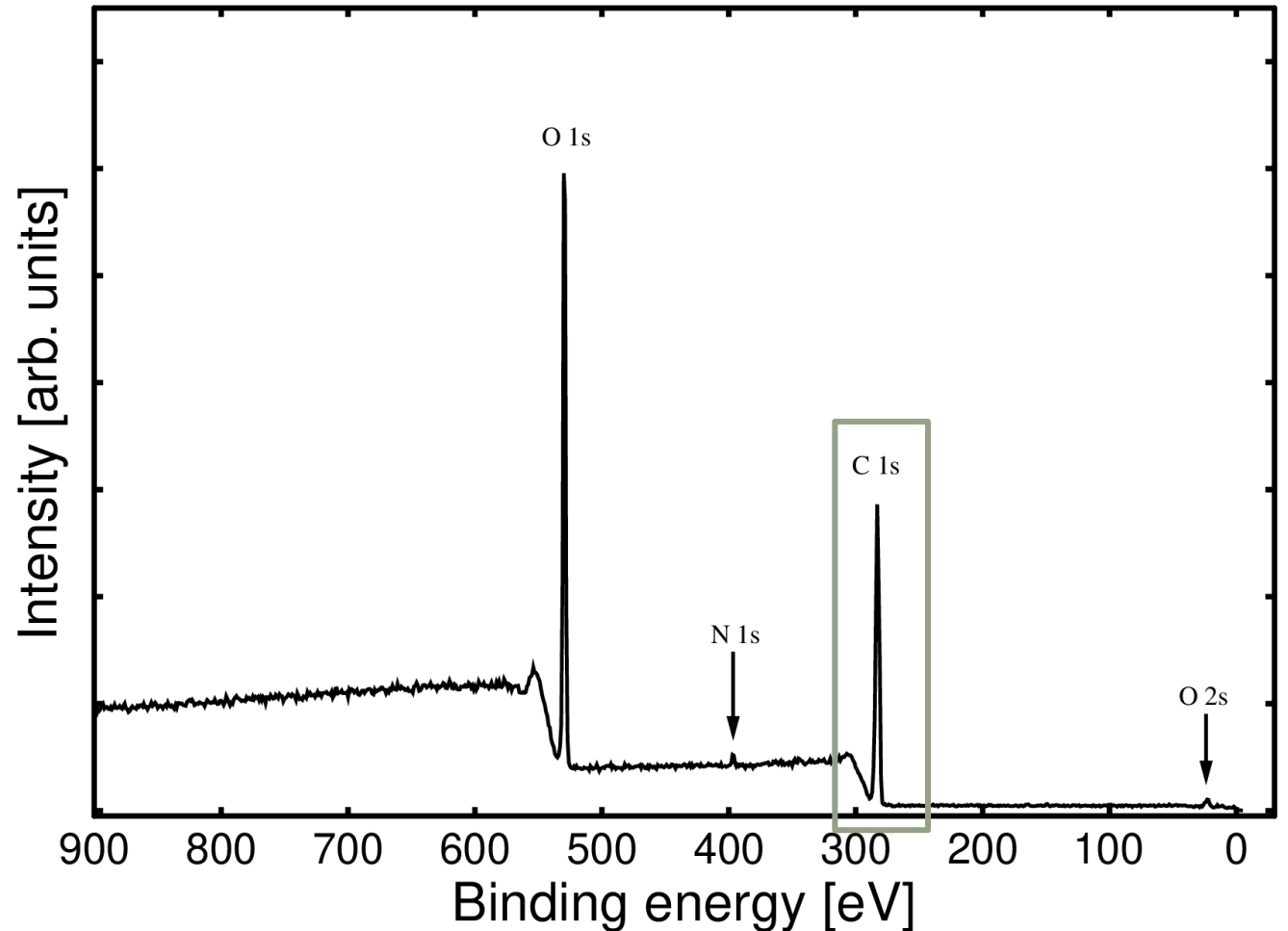
Step 2. Select an element for binding energy:

IA	IIA	IIIB	IVB	VB	VIB	VIIIB	VIII	IB	IIB	IIIA	IVA	VA	VIA	VIIA	VIIIA		
¹ H															² He		
³ Li	⁴ Be					Metals						⁵ B	⁶ C	⁷ N	⁸ O	⁹ F	¹⁰ Ne
¹¹ Na	¹² Mg					Transition metals						¹³ Al	¹⁴ Si	¹⁵ P	¹⁶ S	¹⁷ Cl	¹⁸ Ar
						Metalloids											
						Nonmetals											
¹⁹ K	²⁰ Ca	²¹ Sc	²² Ti	²³ V	²⁴ Cr	²⁵ Mn	²⁶ Fe	²⁷ Co	²⁸ Ni	²⁹ Cu	³⁰ Zn	³¹ Ga	³² Ge	³³ As	³⁴ Se	³⁵ Br	³⁶ Kr
³⁷ Rb	³⁸ Sr	³⁹ Y	⁴⁰ Zr	⁴¹ Nb	⁴² Mo	⁴³ Tc	⁴⁴ Ru	⁴⁵ Rh	⁴⁶ Pd	⁴⁷ Ag	⁴⁸ Cd	⁴⁹ In	⁵⁰ Sn	⁵¹ Sb	⁵² Te	⁵³ I	⁵⁴ Xe
⁵⁵ Cs	⁵⁶ Ba	⁵⁷ La	⁷² Hf	⁷³ Ta	⁷⁴ W	⁷⁵ Re	⁷⁶ Os	⁷⁷ Ir	⁷⁸ Pt	⁷⁹ Au	⁸⁰ Hg	⁸¹ Tl	⁸² Pb	⁸³ Bi	⁸⁴ Po	⁸⁵ At	⁸⁶ Rn
⁸⁷ Fr	⁸⁸ Ra	⁸⁹ Ac	¹⁰⁴ Rf	¹⁰⁵ Db	¹⁰⁶ Sg	¹⁰⁷ Bh	¹⁰⁸ Hs	¹⁰⁹ Mt									
lanthanides			⁵⁸ Ce	⁵⁹ Pr	⁶⁰ Nd	⁶¹ Pm	⁶² Sm	⁶³ Eu	⁶⁴ Gd	⁶⁵ Tb	⁶⁶ Dy	⁶⁷ Ho	⁶⁸ Er	⁶⁹ Tm	⁷⁰ Yb	⁷¹ Lu	
actinides			⁹⁰ Th	⁹¹ Pa	⁹² U	⁹³ Np	⁹⁴ Pu	⁹⁵ Am	⁹⁶ Cm	⁹⁷ Bk	⁹⁸ Cf	⁹⁹ Es	¹⁰⁰ Fm	¹⁰¹ Md	¹⁰² No	¹⁰³ Lr	

Practical example – Cellulose

Large area survey scan from cellulose:

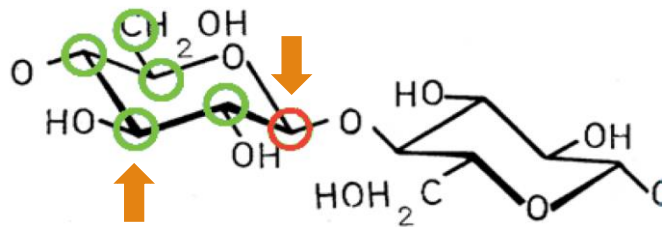
- Carbon and oxygen
- Elemental composition can be calculated
- O/C ratio measured
- Trace level impurities detected – nitrogen
- Zooming in on individual peaks will give you a lot more information!



Practical example – Cellulose

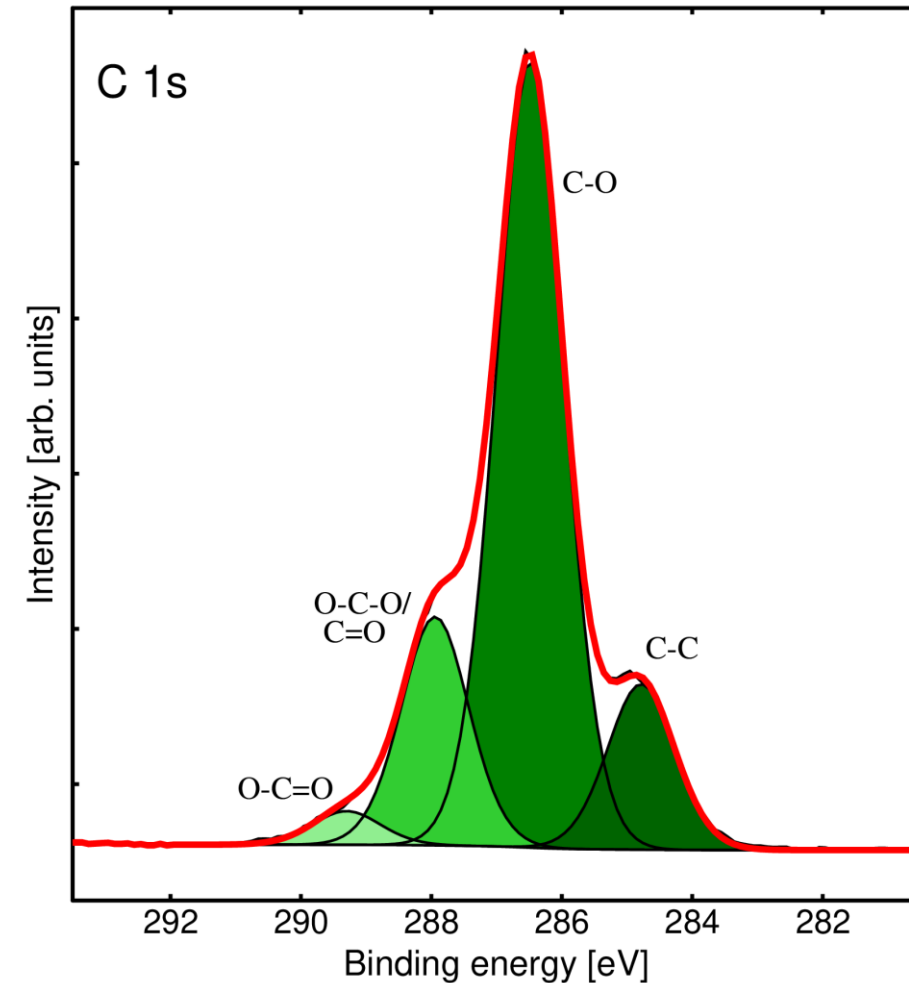
High resolution spectra:

- C 1s
- More components than a single Gaussian



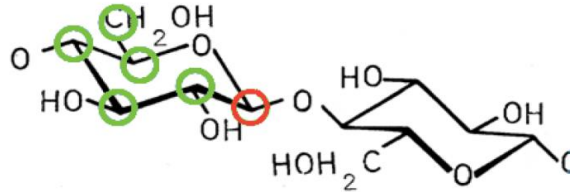
Understanding the material greatly improves the analysis

- Locating peaks
- Assigning peak energies



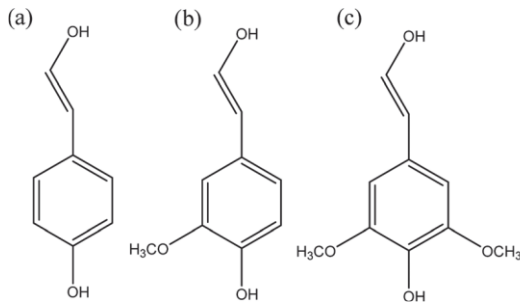
Cellulose vs lignin

Cellulose:



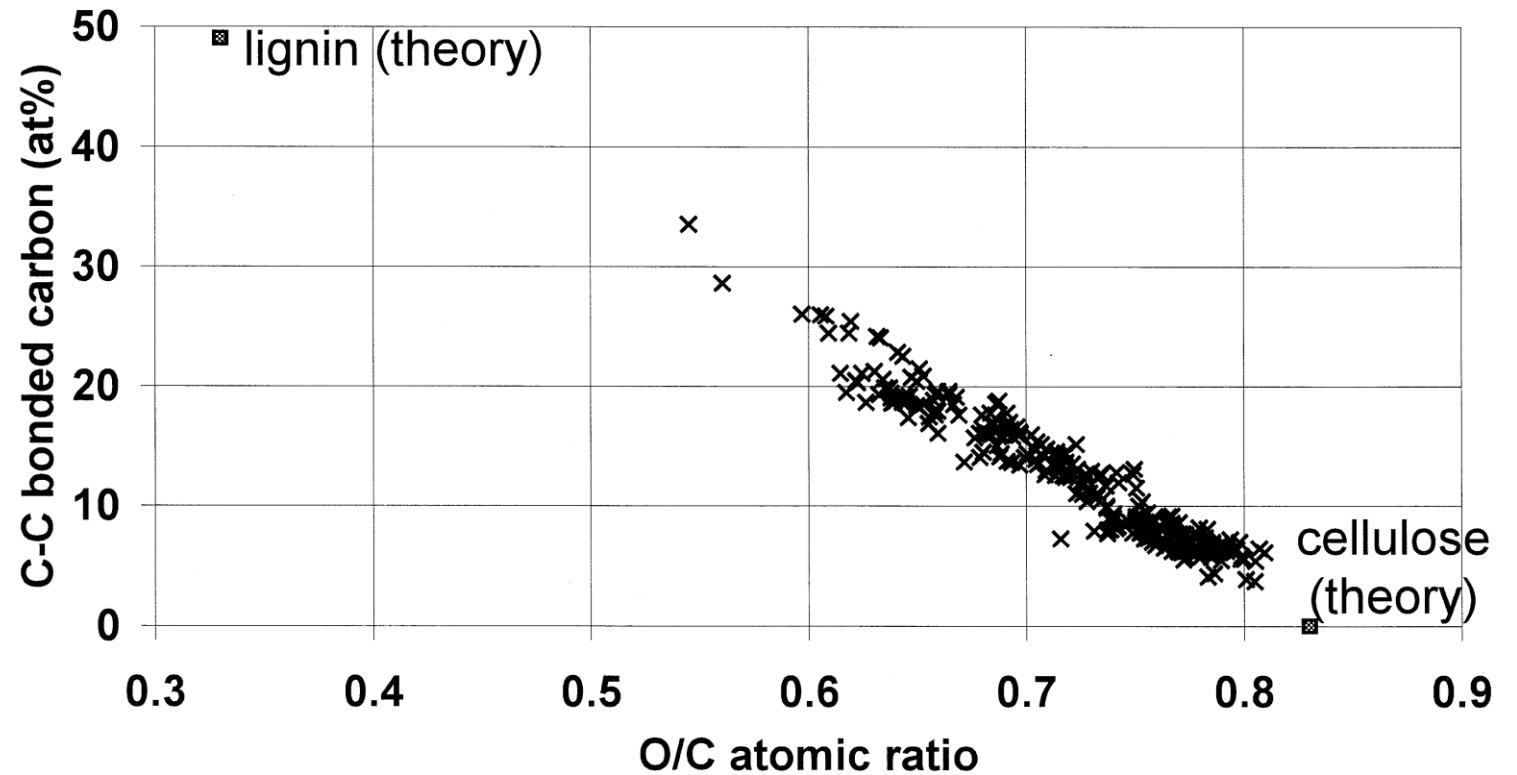
- O/C atomic ratio: 0.83
- C-C at.%: 0 %

Lignin (monolignols):



- O/C atomic ratio: 0.33
- C-C at.%: 49 %

O/C vs. C_1/C_{tot} for 254 measurements



[L.-S. Johansson, et al., *Appl. Surf. Sci.* 144-145 (1999) 92-95.]

XPS

X-Ray Photoelectron Spectroscopy

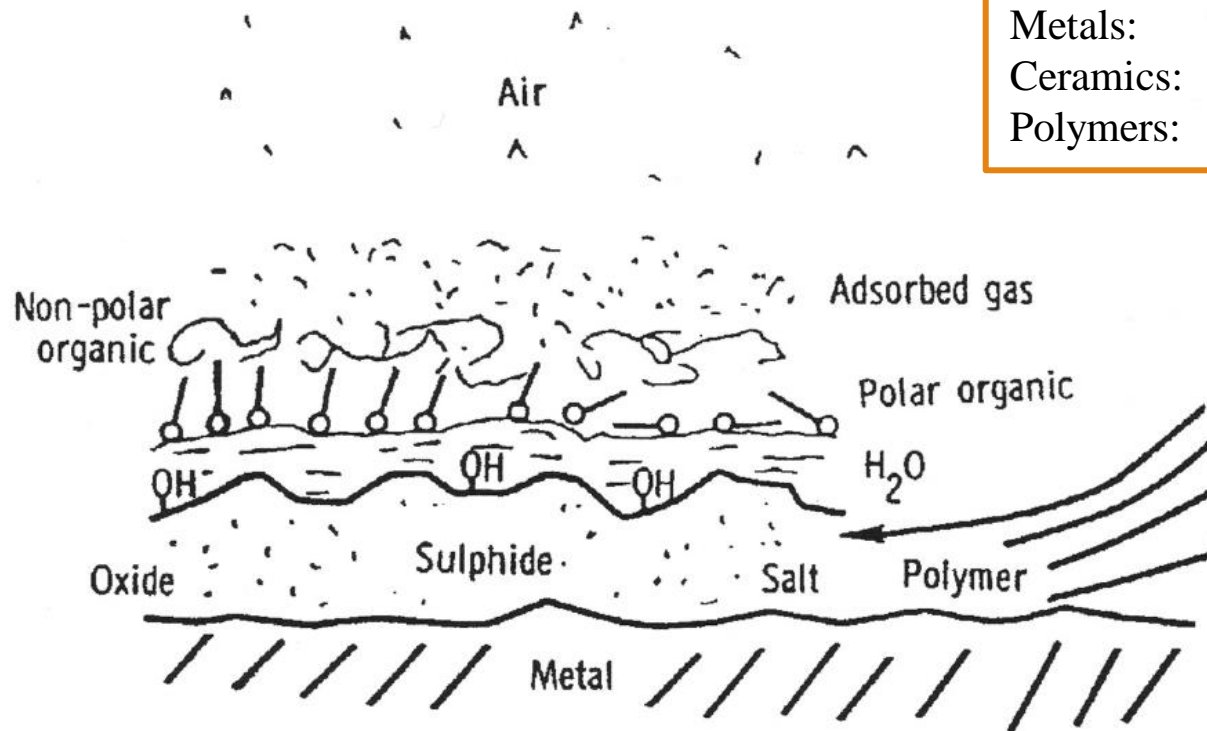
OUTLINE:

1. Background
 1. Phenomenon
 2. Instrumentation
2. Typical measurement data
 1. Qualitative analysis & spectral features
 2. Peak identification
3. Analysis and results
 1. Quantitative analysis & effects of sample
 2. Chemical environment & peak fitting
4. Technical issues & Auxiliary features
 1. Ion beam sputtering & depth profiling
 2. Angle resolved XPS
 3. Surface charging & energy calibration
 4. Small area analysis and imaging

Surface contamination

Ambient C (at.-%):

Metals: 40 – 60 %
Ceramics: 20 – 40 %
Polymers: 1 – 10 %



Surface contamination is always a big problem

- Oxidation
- Advantageous carbon

Carbon contamination

- Exists on all samples that have not been prepared in vacuum!

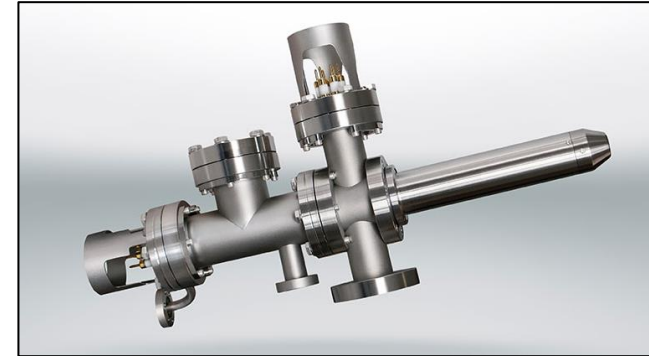
Sources:

- Organic molecules in air
- *In situ*:
 - Contamination due to pumping oil
 - Desorption from other samples in chamber

Ion beam sputtering

Ar-ion guns are often included in XPS-analysis chambers

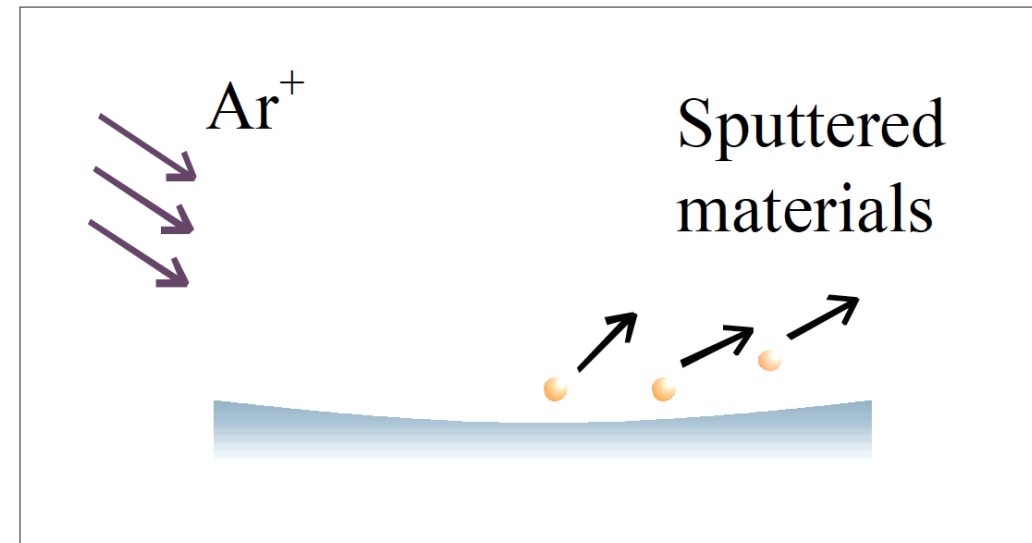
- Ion energies usually 0-10 keV



Removal of surface layers:

- Surface contamination
- Oxide removal
- Depth analysis

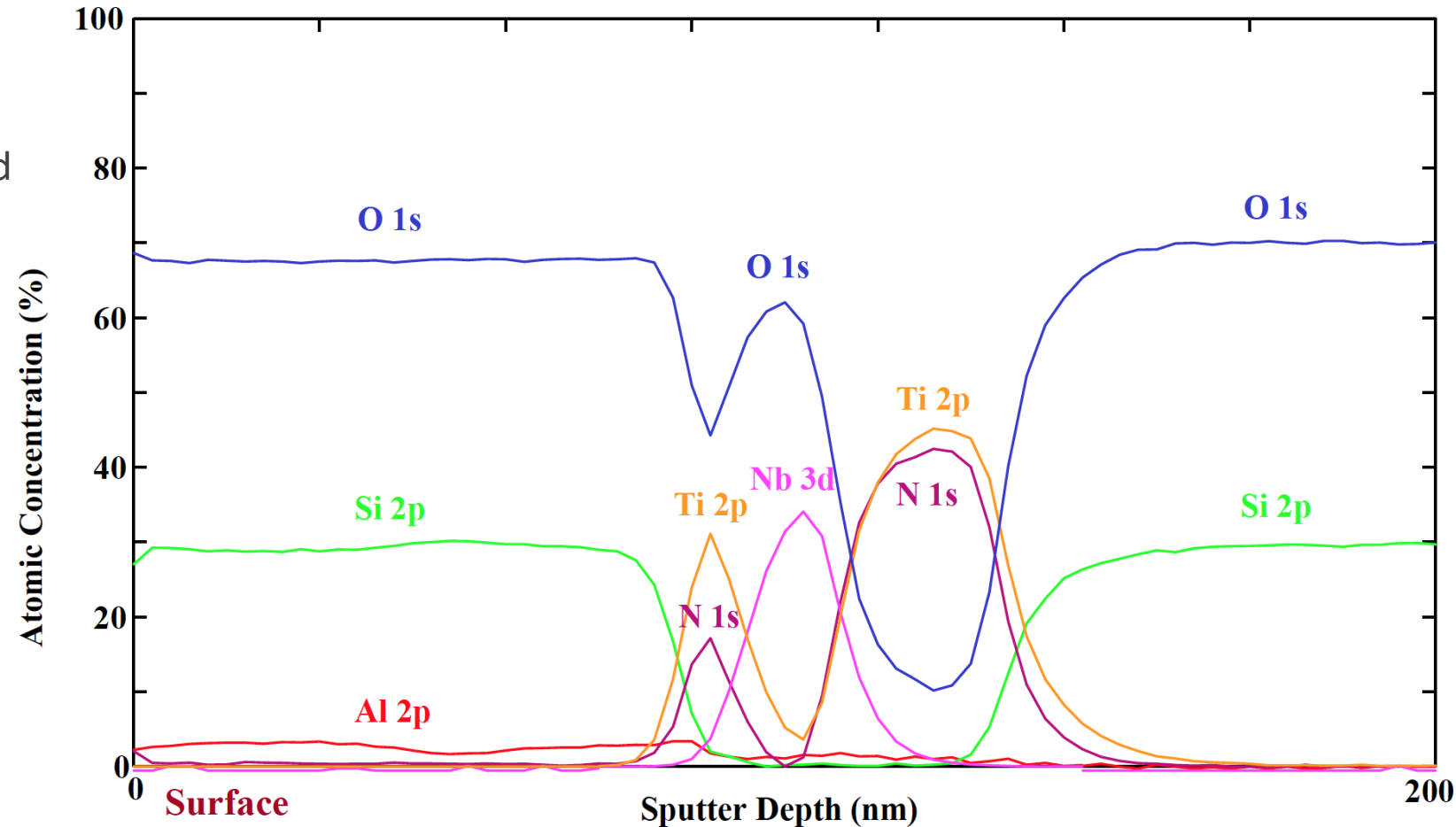
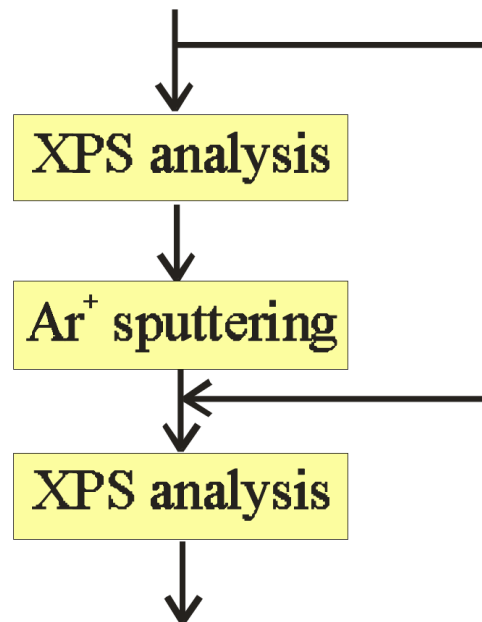
- NOTE: May affect surface chemistry and composition of materials
- Not always a good idea for XPS



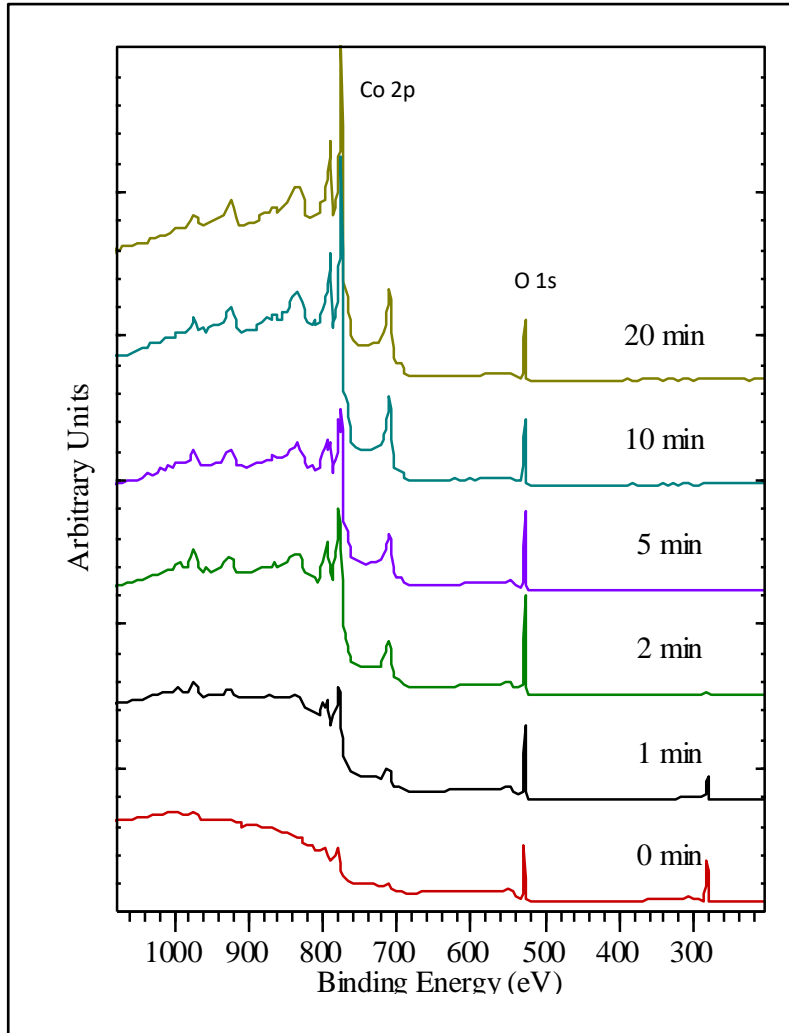
Depth profiling

Depth profiling with sputtering

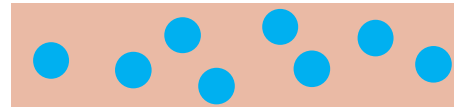
- Consecutive sputter + xps cycles
- Sputtering rate can be determined from time to sputter through a layer of material with known thickness



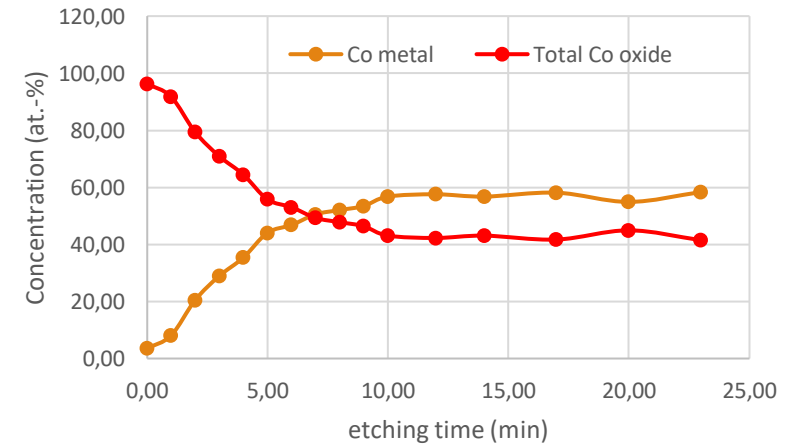
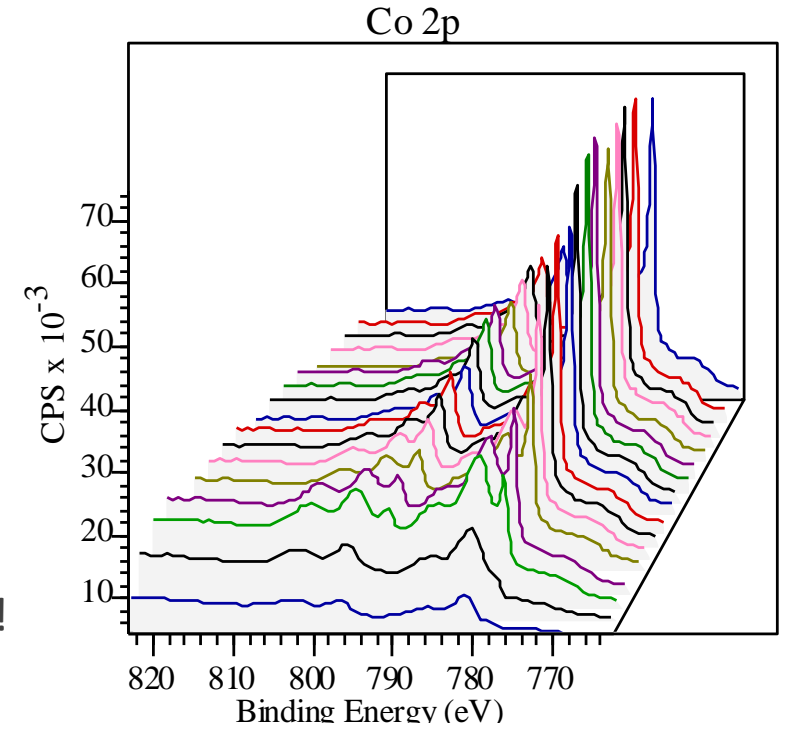
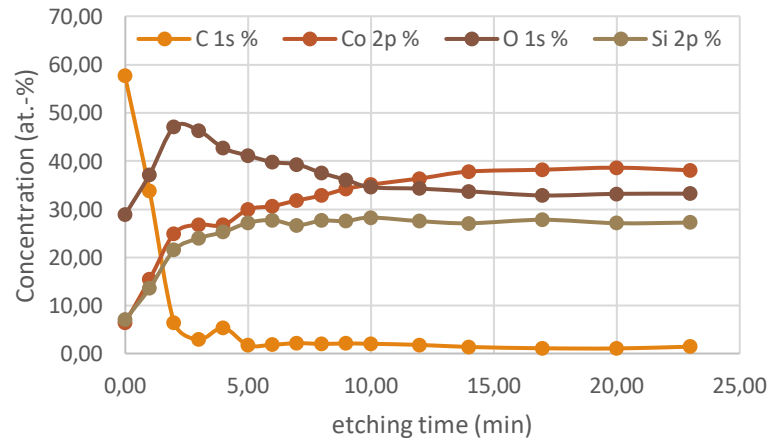
Example case



- Sample: SiO_x + embedded Co clusters



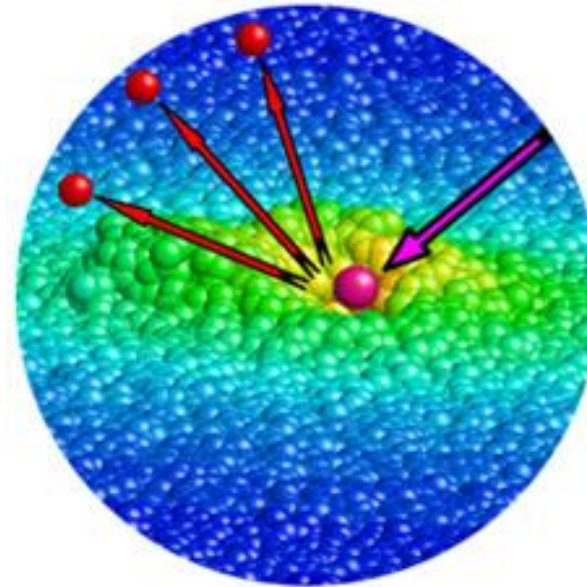
- Elemental depth profile
- Co 2p high-res shows dramatic changes!
- Oxidation level changes at different depths!



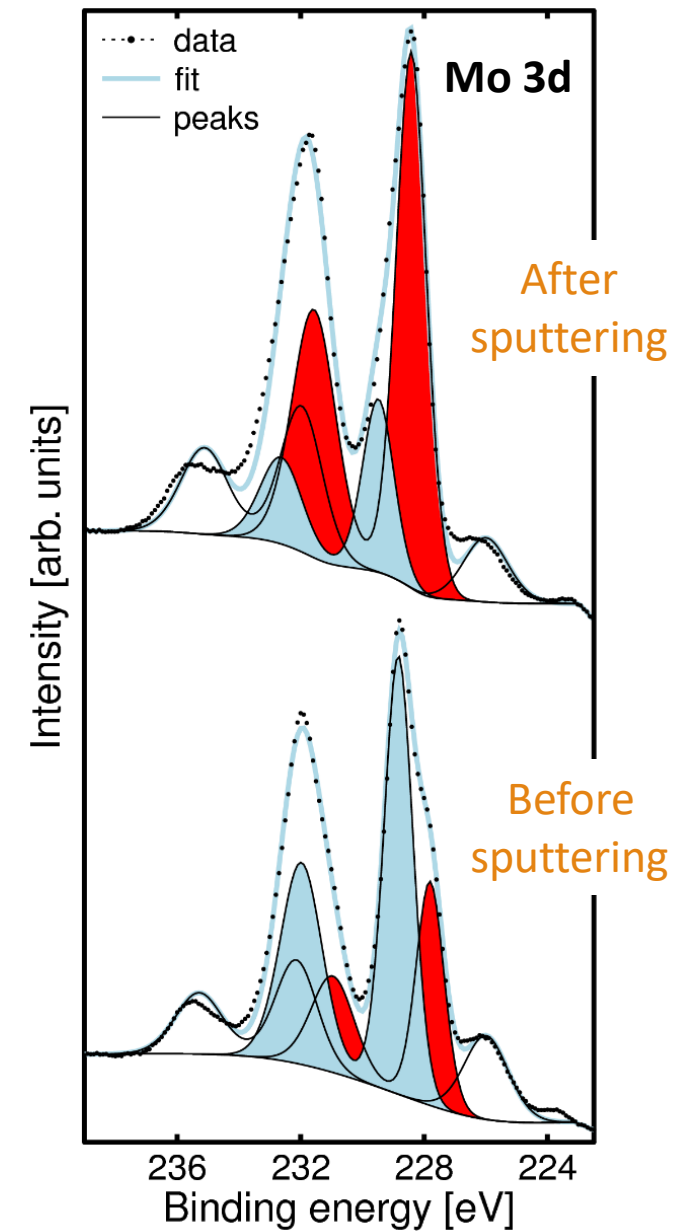
Radiation induced effects

Several factors affect accuracy and depth resolution when using ion beams:

- Non-uniform ion beam intensity/impurity ions
- Re-deposition of sputtered species
- Adsorption of residual gases
- Surface roughness (original and ion-induced)
- Crystalline structure and defects
- Preferential sputtering
- Atomic mixing in layered materials
- Ion implantation
- Decomposition of compounds



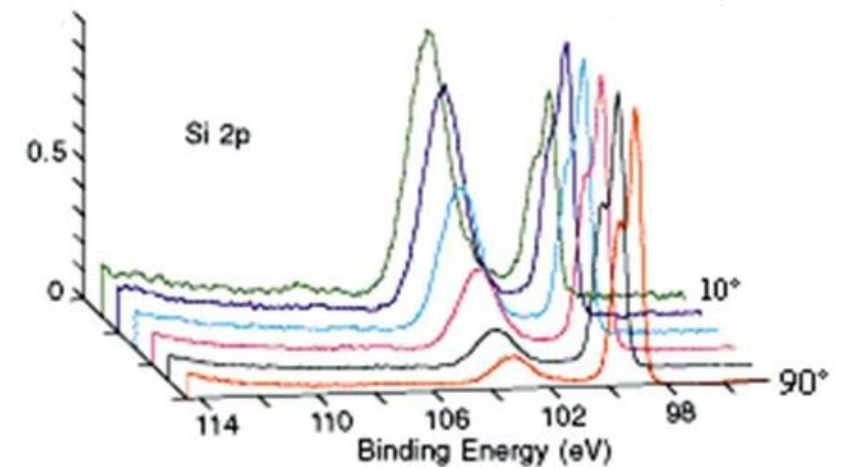
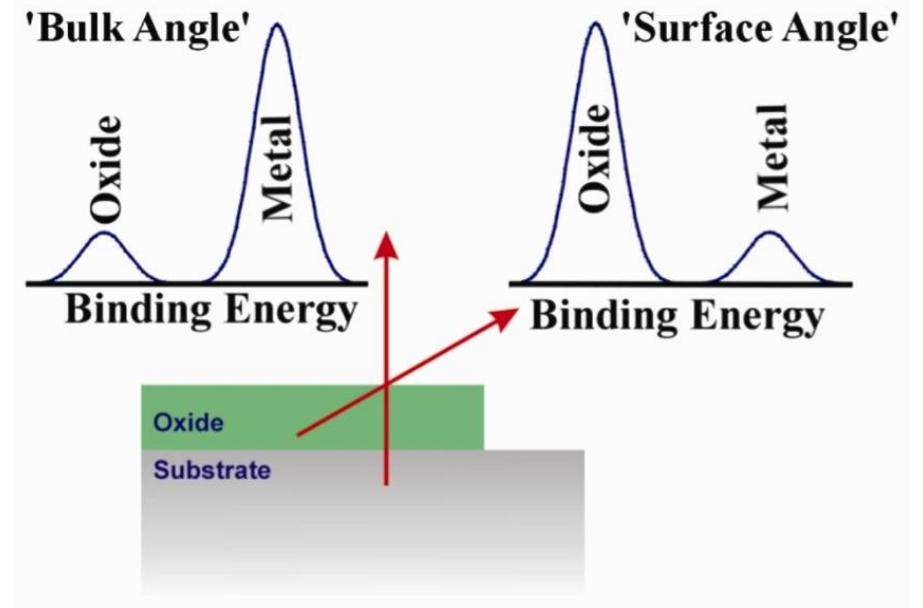
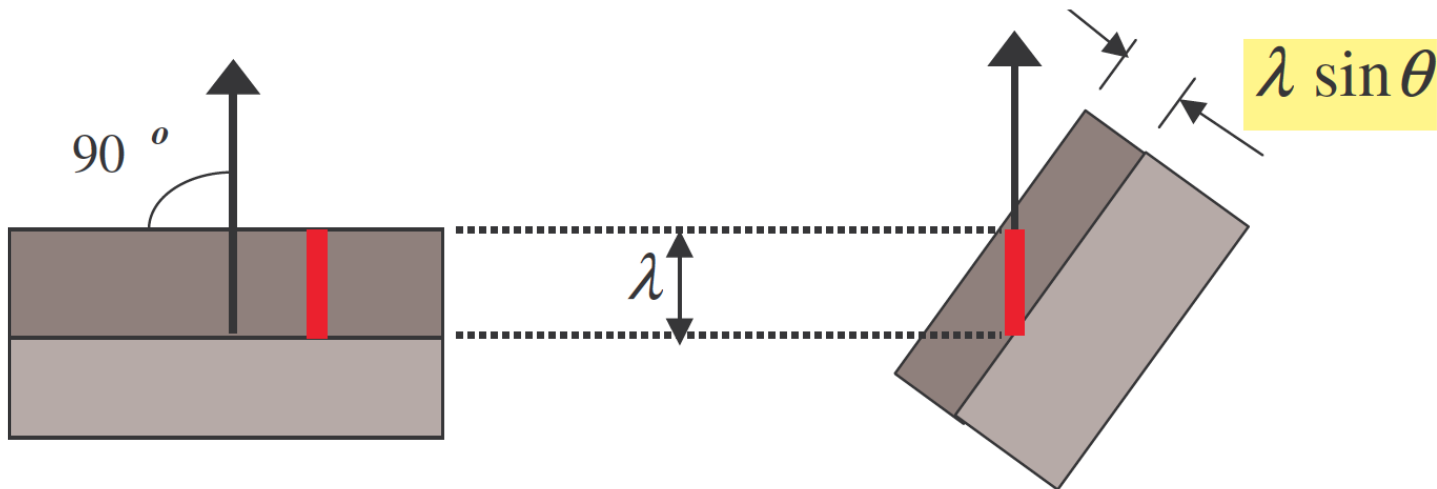
Energy from ion impacts can be distributed over a large volume in the sample



Angle resolved XPS

Alternative means for depth profiling:

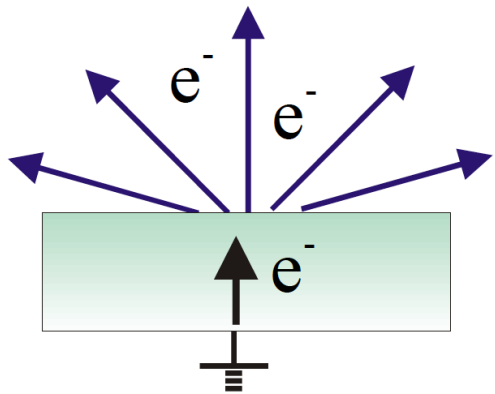
- Consecutive XPS measurements are done while tilting the sample at increasing angles
- Escape depth for electrons decreases with increasing angle
- Higher surface sensitivity
- Reliable results only if surface is smooth enough!



Surface charging

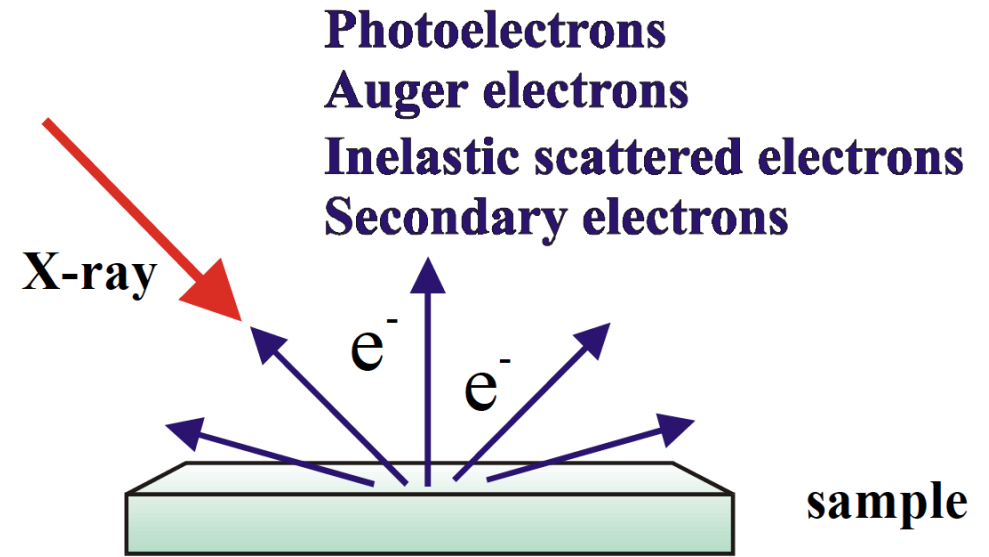
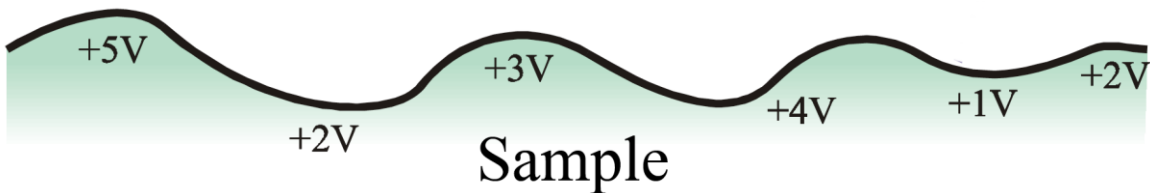
Electrons are continuously removed from the surface of the sample:

- Metals: electron loss is compensated
- Insulators: surface will collect (non-uniform) charge



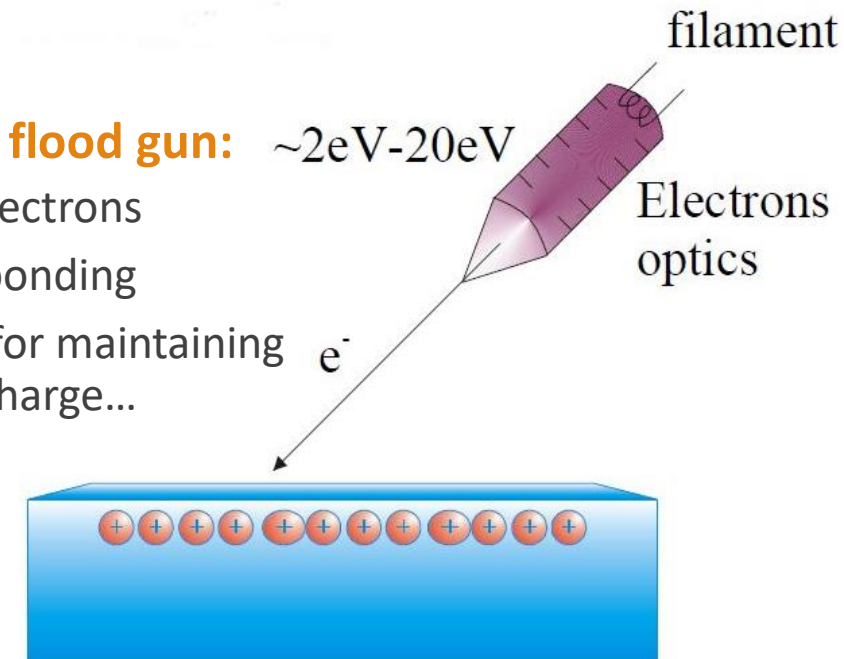
Surface charging:

- Broadening of peaks
- Shift in peak energies



Low energy electron flood gun: $\sim 2\text{eV}-20\text{eV}$

- Introduces excess electrons
- May affect surface bonding
- Not always reliable for maintaining a constant surface charge...



Energy calibration

Reference peaks can be used for calibration of peak positions on insulating samples

- All spectra can be shifted to align a certain peak with known binding energy

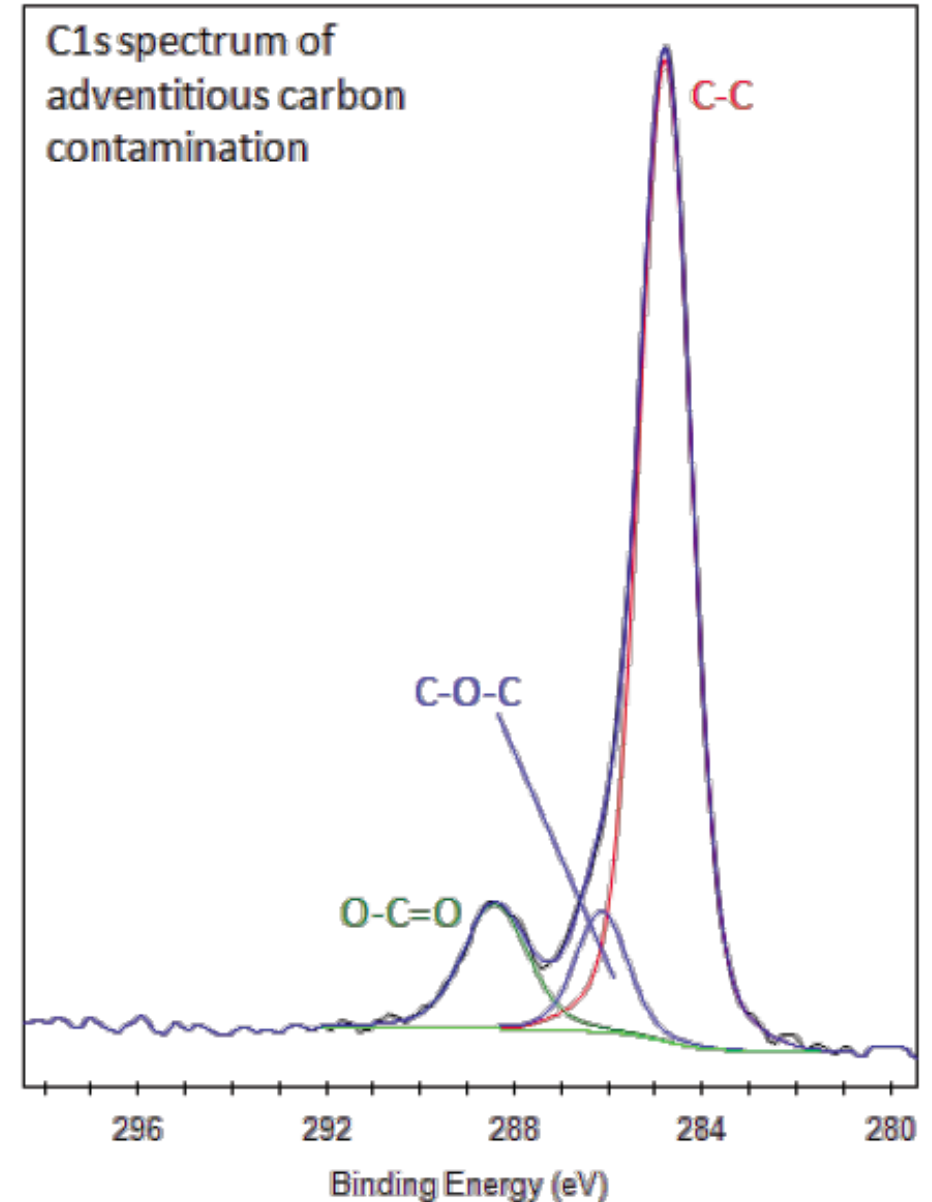
Adventitious carbon:

- C-C bonding in C 1s spectrum: 284.8 eV

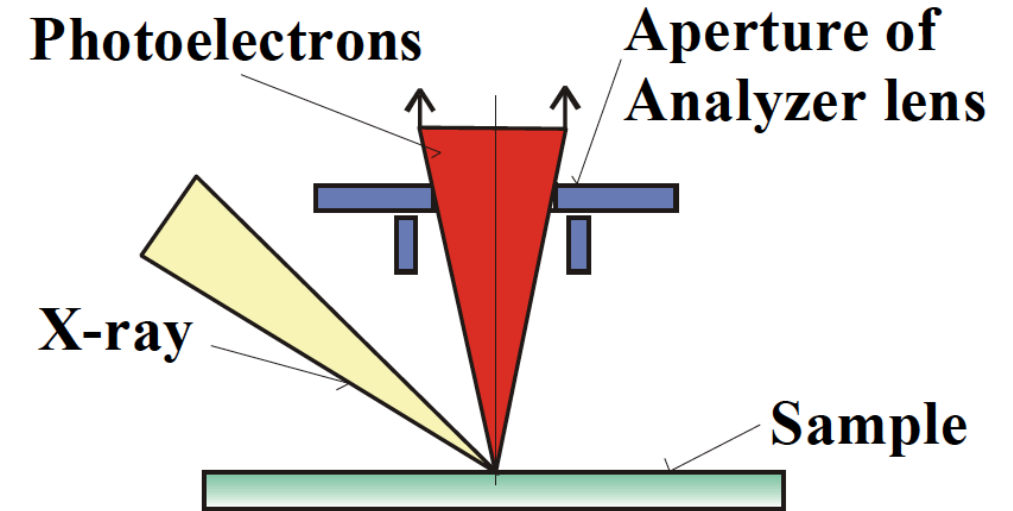
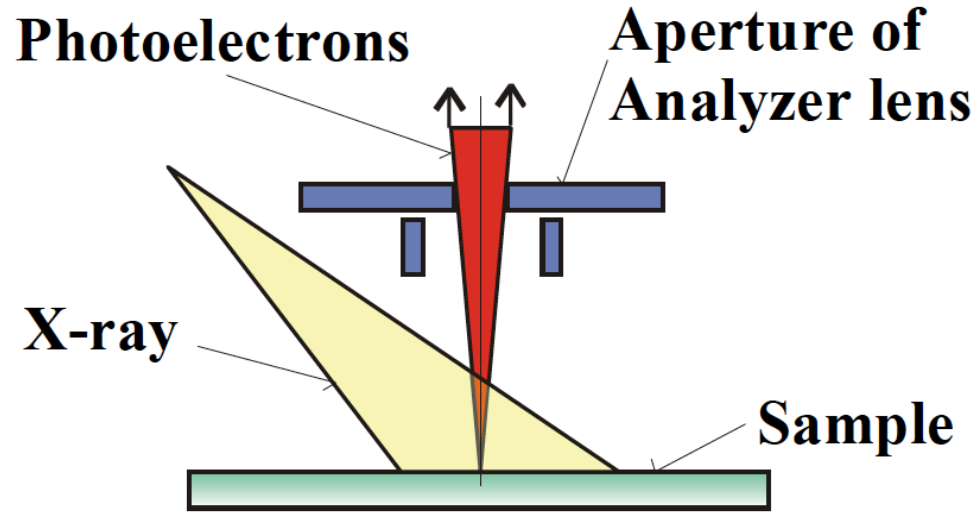
Gold surface:

- Au 4f_{7/2}: 84.0 eV

Other peaks with known position in sample



Small area analysis and imaging



Spot size determined by the analyser

Spot size determined by the x-ray beam

**Both monochromated and dual anode
x-ray sources can be used**

Imaging methods

(1) Moving sample stage

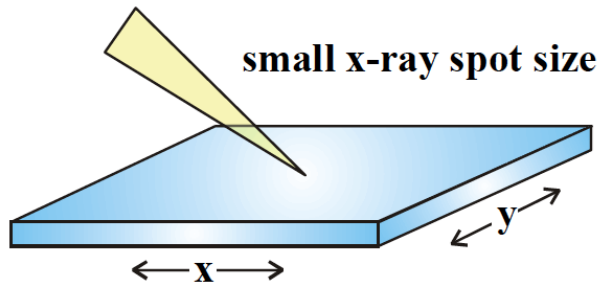


Image:

- x,y position vs photoelectron intensity
- Resolution: $\sim 50 \mu\text{m}$

(2) Use of scanning plates

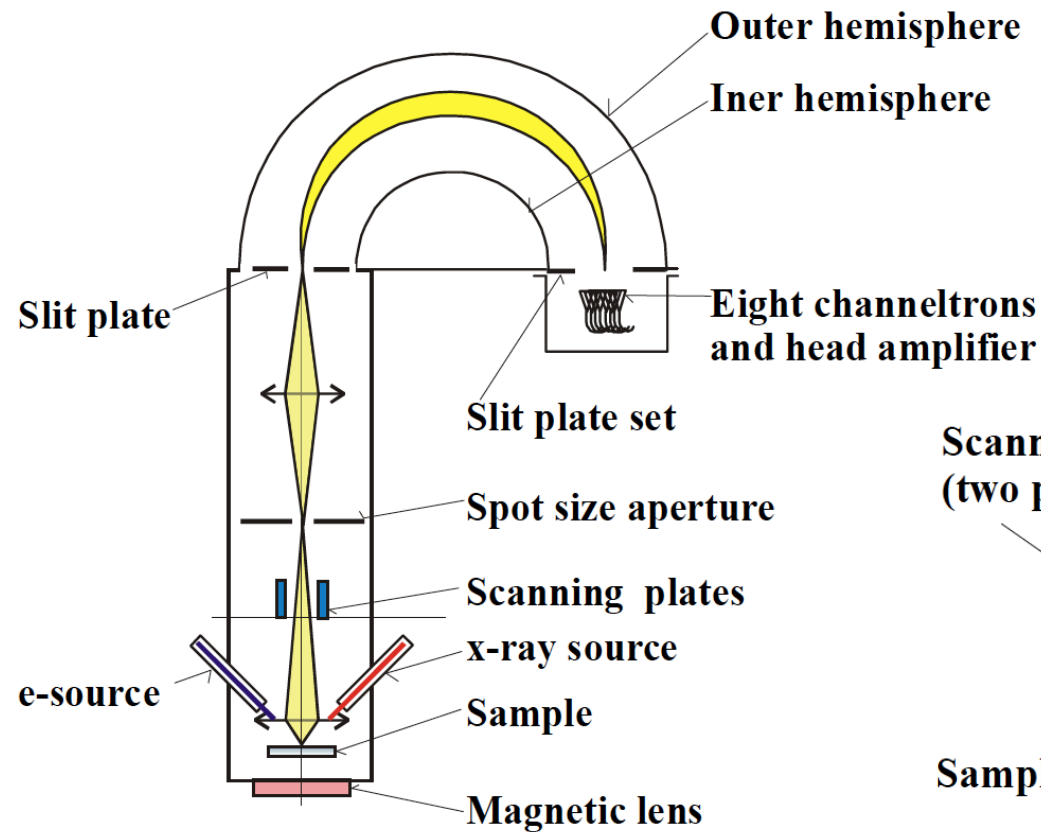
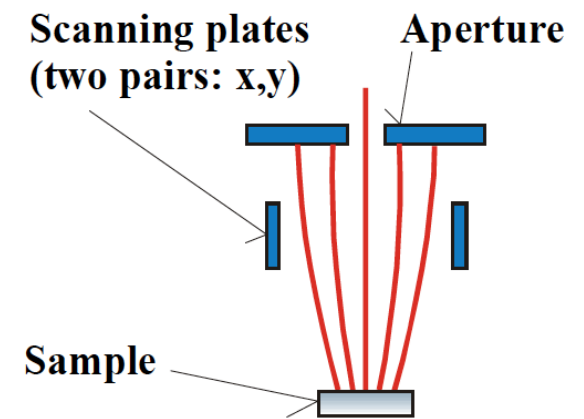
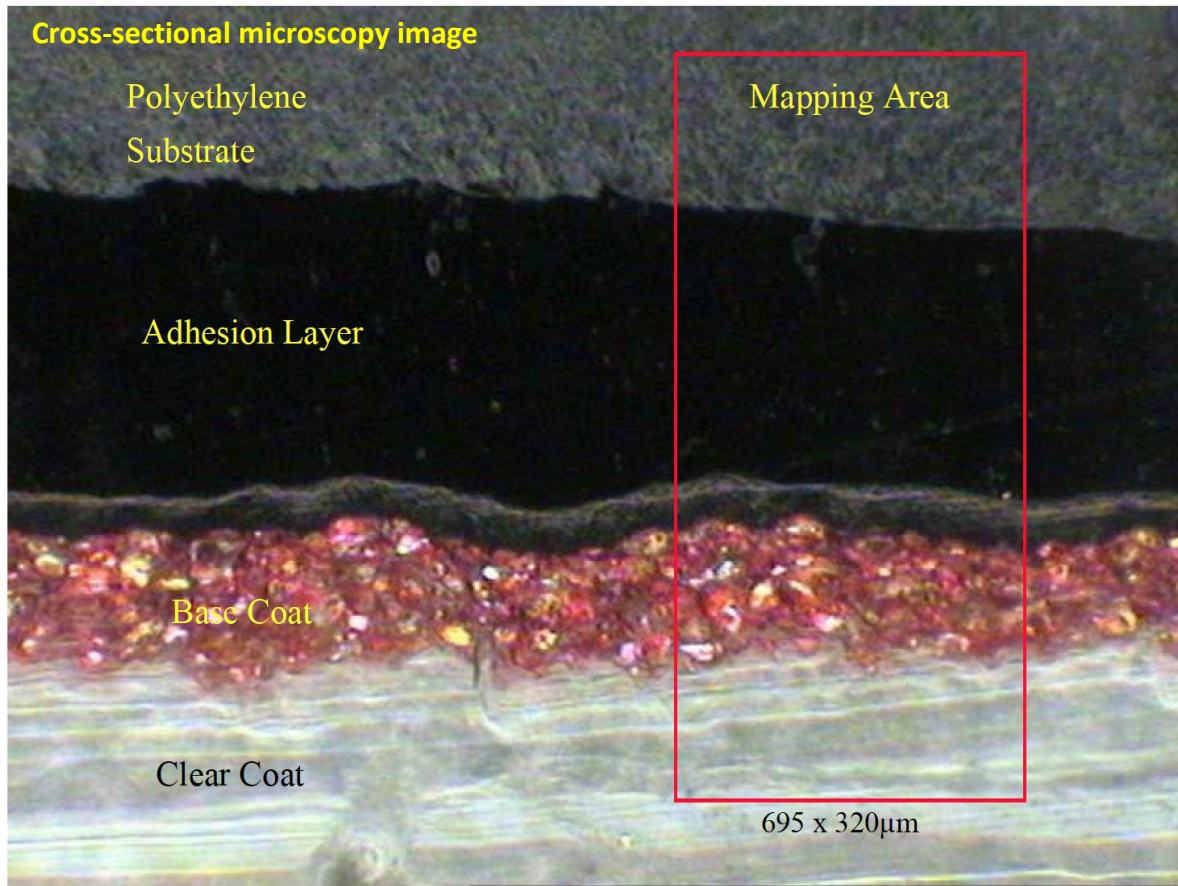


Image:

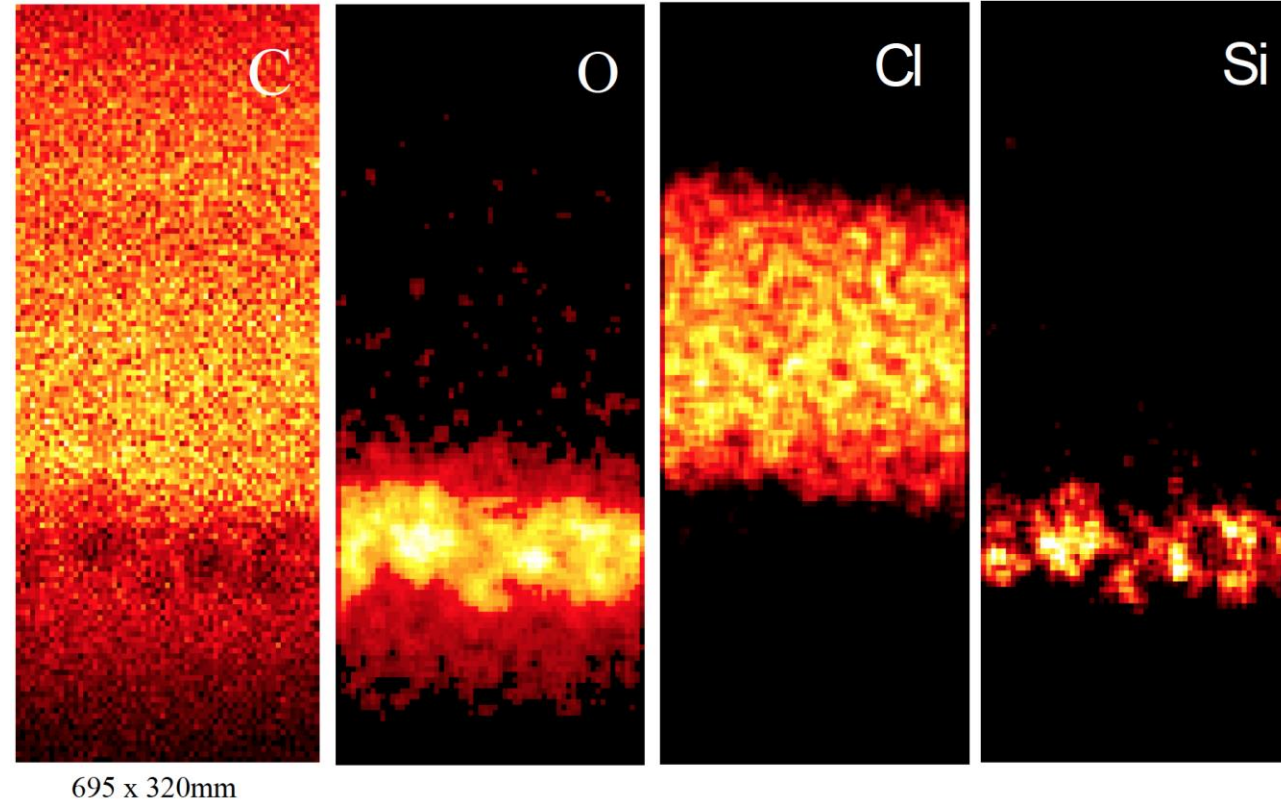
- Voltages V_x and V_y scanned
- Photointensity collected from different points in time sequence
- Resolution: $\sim 10 \mu\text{m}$



XPS study of paint

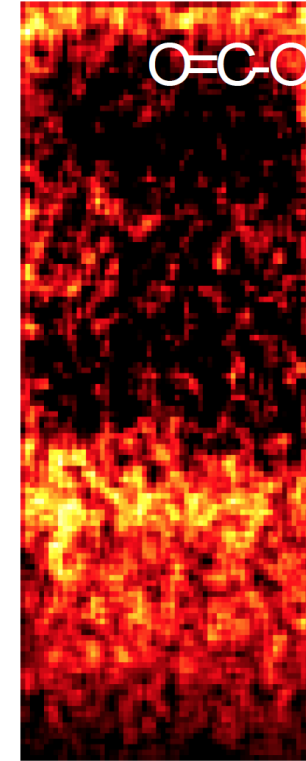
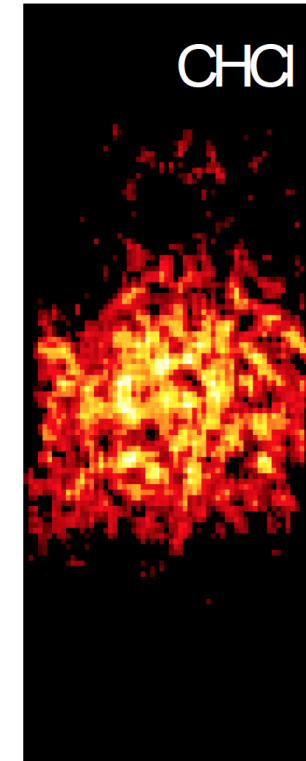
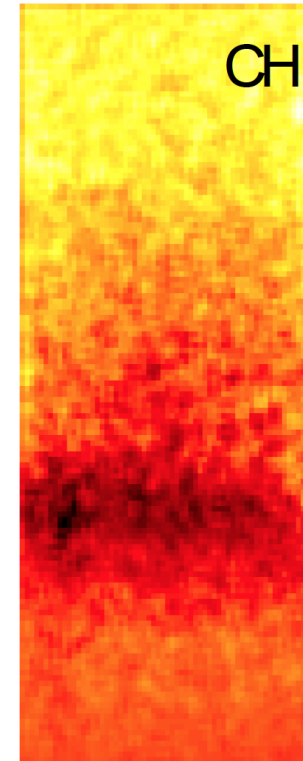
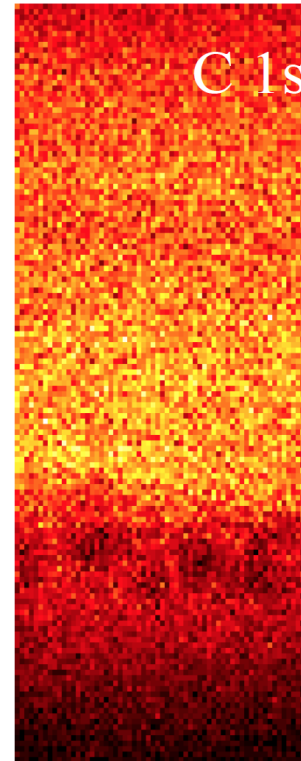
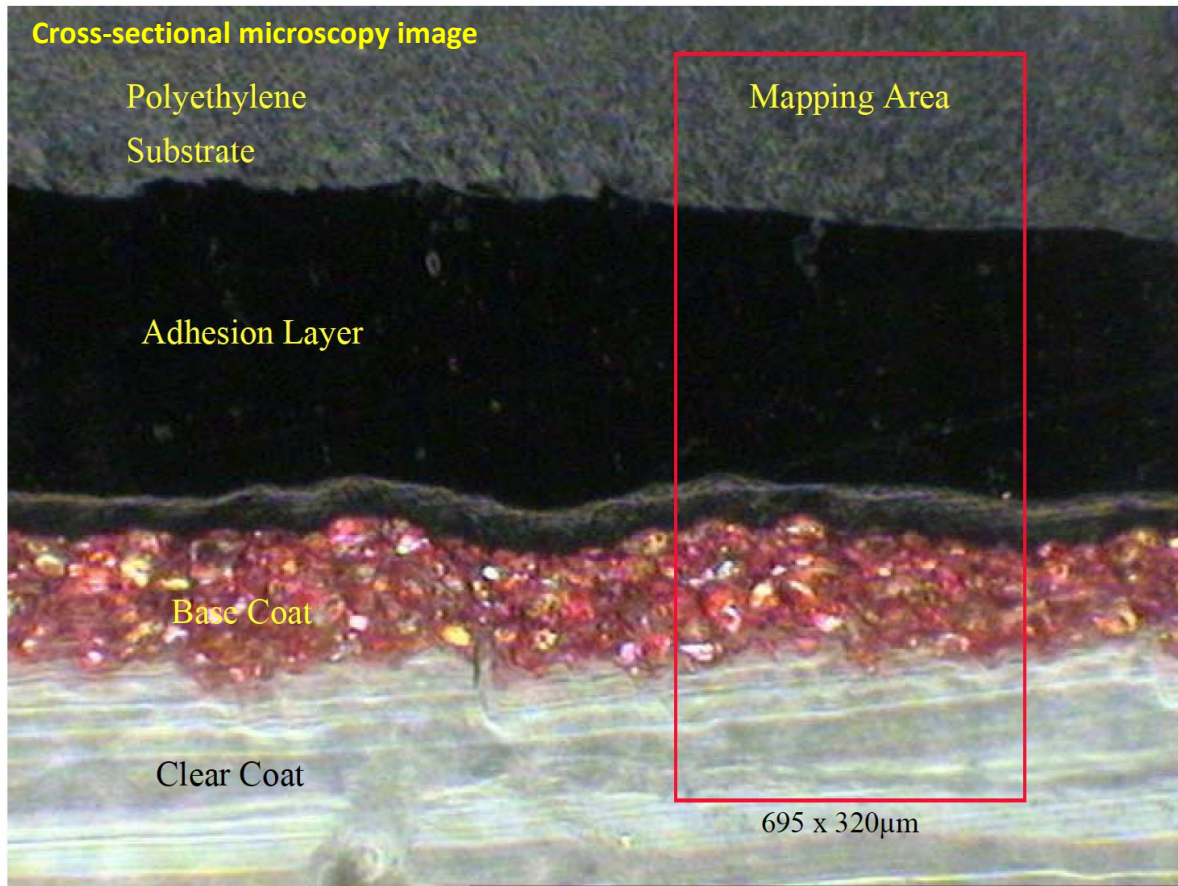


Elemental maps using C 1s, O 1s, Cl 2p, and Si 2p signals.



XPS study of paint – chemical state

C 1s chemical state maps.



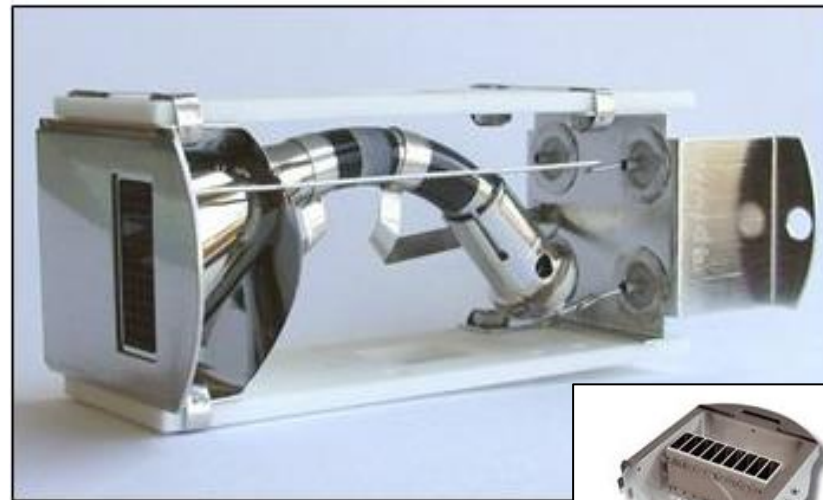
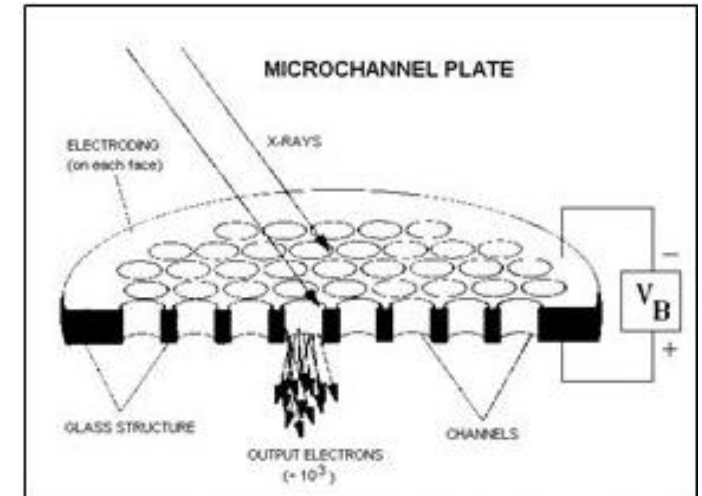
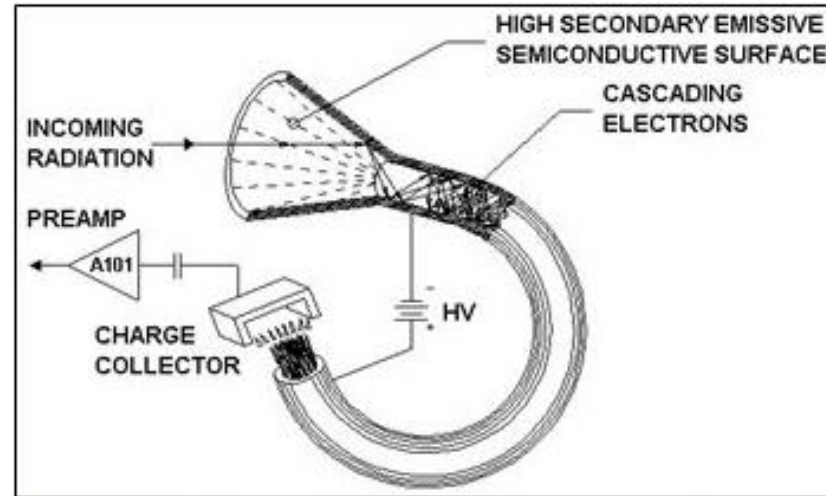
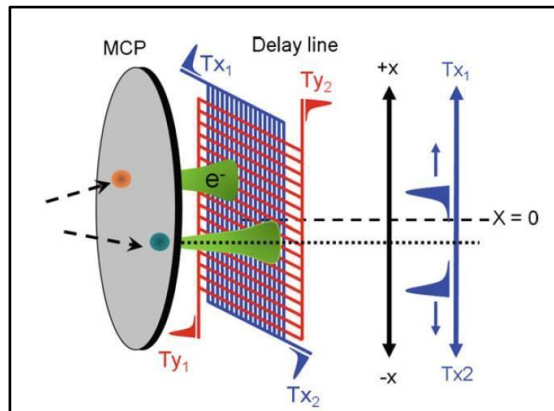
2D-detectors

Types:

- Channeltron (CEM)
- Microchannel plate (MCP)

Position sensitivity:

- Channeltron array
- MCP+CCD (Charge-Coupled Device)
- DLD (Delay-Line Detector)



Imaging methods

(3) Use of multichannel plate

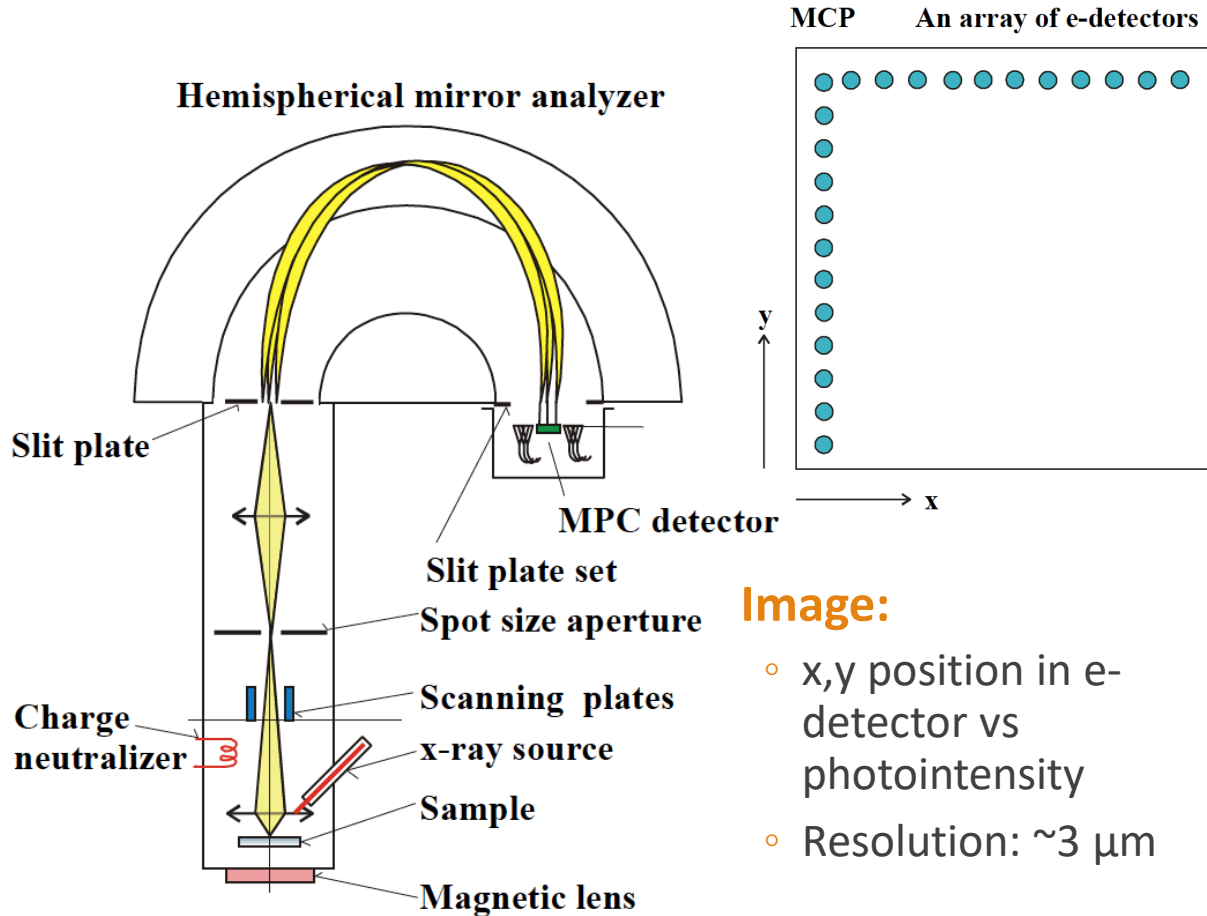
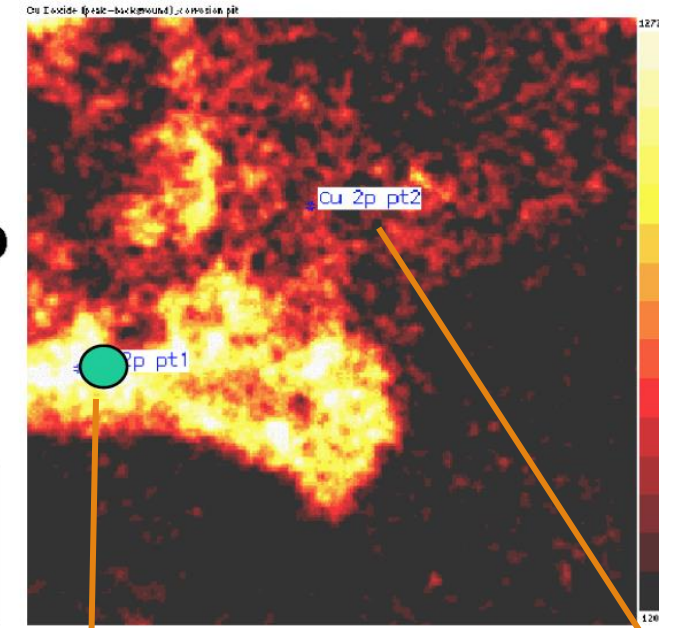


Image:

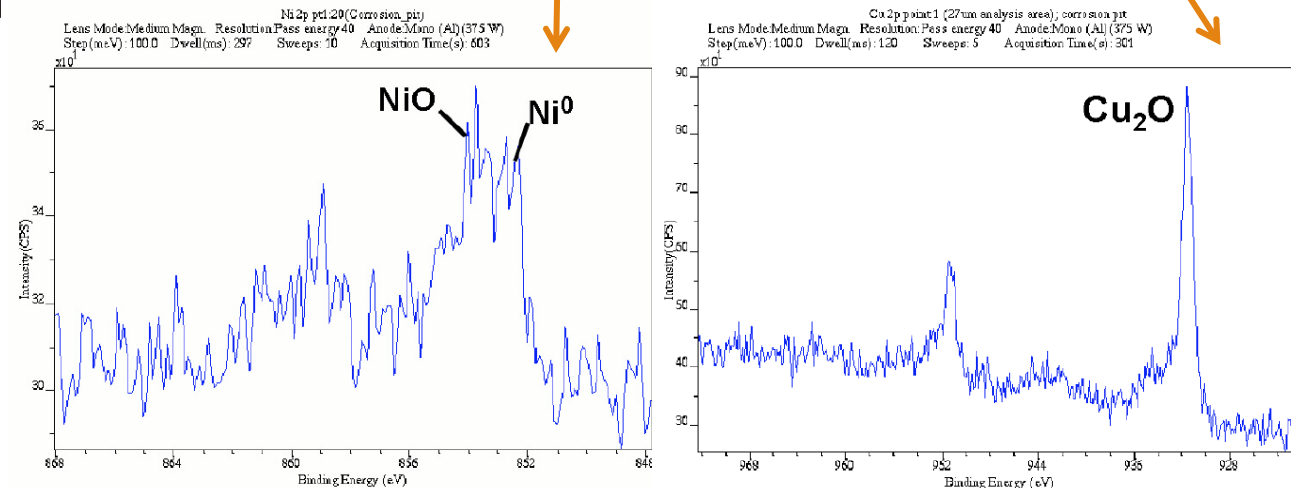
- x,y position in e-detector vs photointensity
- Resolution: $\sim 3 \mu\text{m}$

Cu₂O Map

100 microns



- Chemical state can be identified for each “spot” in image



Synchrotron sources

- High intensity and resolution, energy tunability, polarization, pulsed beam, focused beam
- Big facilities: **high cost** – shared facilities

